# TIMING MODELS FOR EFFICIENT CHARACTERIZATION OF NANOSCALE VLSI SINGLE STAGE STANDARD CELLS

Ph.D THESIS

by

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DEPARTMENT OF ELECTRONICS AND COMMUNICATION ENGINEERING INDIAN INSTITUTE OF TECHNOLOGY ROORKEE ROORKEE-247667, INDIA SEPTEMBER, 2014

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### A THESIS

Submitted in partial fulfilment of the requirements for the award of the degree

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by

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### CANDIDATE'S DECLARATION

I hereby certify that the work which is being presented in the thesis entitled "TIMING MODELS FOR EFFICIENT CHARACTERIZATION OF NANOSCALE VLSI SIN-GLE STAGE STANDARD CELLS" in partial fulfilment of the requirements for the award of the Degree of Doctor of Philosophy and submitted in the Department of Electronics and Communication Engineering of the Indian Institute of Technology Roorkee, Roorkee is an authentic record of my own work carried out during a period from December, 2009 to September, 2014 under the supervision of **Dr. Anand Bulusu**, Associate Professor and **Dr. Sanjeev Manhas**, Associate Professor, Department of Electronics and Communication Engineering, Indian Institute of Technology Roorkee, Roorkee.

The matter presented in this thesis has not been submitted by me for the award of any other degree of this or any other Institute.

### (BALJIT KAUR)

This is to certify that the above statement made by the candidate is correct to the best of our knowledge.

(Anand Bulusu) Supervisor (Sanjeev Manhas) Supervisor

Date:

#### ABSTRACT

In nanometer range VLSI technologies, semi-custom chip design approach using predesigned and pre-characterized standard cells is popular because of increasing complexity. For efficient circuit design, these standard cells are pre-characterized for delay, transition times, terminal capacitances, power dissipation, noise and area using SPICE simulations. The traditional Non Linear Delay Models (NLDM) based Lookup Table (LUT) approach for standard cell characterization and Static Timing Analysis (STA) is facing serious challenges in nanometer technologies, because it does not account for the nature of input and output terminal voltage transitions. Because of voltage dependent values of effective capacitances of device and interconnects, it becomes important to consider the nature of output transition. To overcome these limitations, researchers introduced Current Source Modeling (CSM), in which for a given value of load capacitance, the value of output voltage and equivalent circuit parameters of the standard cell are given as a function of input voltage. This increases the complexity of the model and the amount of data to be stored for standard cell characterization.

To solve these issues, vendors found the models as a middle path (between NLDM and CSM), known as vendor CSM formats. These vendor CSM formats are Effective CSM (ECSM) and Composite CSM (CCSM). For a given input transition time  $(T_R)$  and load capacitance  $(C_l = C_{eff})$  values, ECSM stores the times at which the output voltage waveform crosses certain predefined threshold points, whereas CCSM stores the output current values at specified voltage level points. Both the vendor models are equivalent and one can be derived from the other. Vendor CSMs use Lookup Table (LUT) based format for representing characterization data. The major issue with ECSM characterization is that it requires re-characterization of standard cells with variation in cell size, layout dependent parameters, temperature, supply voltage and device model updates. This recharacterization is highly time consuming. Therefore, there is a need for a model which is more efficient in standard cell characterization, thus saving time and effort. In this thesis, we undertake a detailed study of existing timing/delay models of CMOS inverter and NAND gate standard cells. We find that these delay models are unsuitable for use in standard cell characterization, because the region of validity in  ${\cal T}_R$  ,  ${\cal C}_l$  space is not clear. Apart from this cell size, layout dependent parameters, power supply voltage and temperature variations are also not inputs to such models. In addition, it is seen that the intermediate node voltage transition of the series stack nMOS devices of a NAND gate, which plays an important role in sub-nanometer technology nodes, has not been considered appropriately in earlier models. We show that considering these issues in standard cell characterization, the re-characterization effort would increase significantly.

For an efficient ECSM characterization, we developed the timing models for CMOS inverter and 2-input NAND gate (therefore, for 2-input NOR gate also), to reduce the re-characterization effort. All the multistage combinational cells can be derived from these basic cells. Firstly, we propose the analytical timing models relating all the Threshold

Crossing Points (TCPs) of output transition with  $T_R$ ,  $C_l$  values, for CMOS inverter and 2-input NAND gate. We then identify the region of validity of the model in  $T_R$ ,  $C_l$  space used in characterization LUTs. It makes the timing models useable in reducing the HSPICE simulations in ECSM library characterization. Further, we identify the relationships of model coefficients with cell size, process induced mechanical stress, temperature and supply voltage variation. Our NAND gate timing models are robust because of an appropriate and detailed consideration of voltage transition at the intermediate node of the series stack of nMOS devices. For this, we consider the input to intermediate node capacitive coupling effect, parasitic capacitances at the intermediate node and the regions of operation of the two nMOS devices placed in series stack. We present the timing models for 2-input NAND gate, considering the following two cases : 1) When upper nMOS transistor in the series stack switches; and 2) When lower nMOS transistor in the series stack switches. In this thesis, we show that the use of these models in standard cell characterization reduces the number of SPICE simulations by 50% and 67% for CMOS inverter and 2-input NAND gate, respectively. We also show that our timing models remain valid with PVT variations. This would help in reducing the re-characterization effort significantly (nearly 85% reduction in SPICE simulations) for standard cell libraries. Further, we present an analytical overshoot timing model for CMOS inverter and NAND gate for accurate timing analysis. For NAND gate overshoot modeling, we see that an inclusion of intermediate node voltage transition with appropriate assumptions lead to accurate estimation (max. error is 2.5% with respect to HSPICE simulations) of overshoot timing values for Case 1 and 2, respectively.

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## Abbreviations and Symbols

CCSM	Composite Current Source Model
CSM	Current Source Model
DELVT0	Threshold Voltage Shift
ECSM	Effective Current Source Model
LUT	Lookup Table
MFGSs	Multi-Fingered Gate Structures
MULU0	Mobility Multiplier
NF	Number of Fingers
NF NLDM	Number of Fingers Non-Linear Delay Model
NLDM	Non-Linear Delay Model
NLDM PTM	Non-Linear Delay Model Predictive Technology device Model
NLDM PTM PVT	Non-Linear Delay Model Predictive Technology device Model Process, Voltage and Temperature

### Chapter 1

### Introduction

### 1.1 Motivation

Due to aggressive technology scaling, the number of logic gates in VLSI chips continue to grow fast. A semi-custom design with pre-designed and pre-characterized standard cell library is essential in this scenario. In this regard, it is prerequisite to characterize basic standard cells, such as inverter, NAND, NOR, latch, flip-flop etc. The objective of cell characterization is to design a high quality model that accurately and efficiently predicts the cell behavior of a standard cell library. Digital design tools use these characterization models for different purposes. Generally, the characterization of standard cells is for parameters related to timing, area and power [5].

In nanometer range technologies, digital design tools need to account for several complex phenomena such as short channel effects, input to output coupling capacitance, interconnect coupling, power supply noise and process variations, etc. Because of the smaller delays and transition times of nanometer range technology standard cells, a minor variation due to these effects influences timing parameters significantly [6]. This increases the need for re-characterization of standard cell library at different process, voltage and temperature corners. Therefore, designing high performance VLSI standard cell library and its characterization has become more challenging than ever in deep sub-micron era. The following two methods are used to measure delays and thus eliminate timing violations in a data path :

1. Circuit simulations using SPICE can be used to estimate the delay of a circuit accurately. However, SPICE simulations need large CPU times to process an entire circuit having large number of transistors. SPICE takes few seconds to process individual transistors in a circuit, so the processing of an entire circuit takes large time [7].

2. An alternative method to measure delay is Static Timing Analysis (STA) method. STA makes use of the simple gate delay models to find the delay of the entire data path, hence takes lesser time [8].

In order to find the delay of an entire combinational circuit using STA, we must determine the delay of its logic gates. This delay is expressed as a function of the load

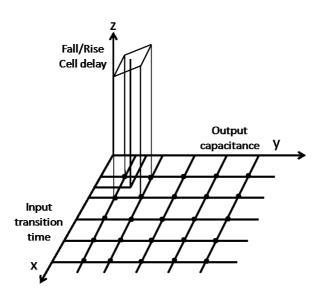


Figure 1.1: Variation of cell delay with input transition time and output capacitance [1].

capacitance  $(C_l)$  and input transition time  $(T_R)$  of logic gates. These gate delay models are classified as:

- 1. Analytical Delay Models: The delay of a logic gate is found from the output voltage transition of logic gate across the load capacitance. They make use of the current equation of the MOSFET. The accuracy of these models depends on accuracy of the current equation. Alpha power law delay model is a typical example [9].
- 2. Empirical Delay Models: These models are based on the curve fitting on the simulation data obtained using SPICE. Scalable polynomial delay model is a typical example [10].
- 3. Look Up Table (LUT) Method: Here we have representation of the delay variation with  $T_R$  and  $C_l$  values. Having known  $T_R$  and  $C_l$  values, we can pick the delay of that particular gate from the table. A typical example is Synopsys ".lib" format Non-Linear Delay Model (NLDM) representation [5, 1], shown in Fig. 1.1.

Conventionally, NLDM based standard cell library characterization was used in STA. In this, delay is a non-linear function of  $C_l$  and  $T_R$  and it is expressed in an LUT with respect to several values of  $C_l$  and  $T_R$ . However, NLDM doesn't capture the nature of terminal voltage transition and variation of capacitance with terminal voltage [11, 12]. To address these issues, recently Current Source Model (CSM) has become important in the standard cell characterization and STA [13]. CSMs ideally support arbitrary input waveforms and output loads since their model parameters are waveform and load independent[14]-[17]. However, vendor CSMs presently impose some more constraints; they provide CSM data for a set of  $T_R$  and effective load capacitance  $C_{eff}$ . Two popular vendor CSMs are known as Effective CSM (ECSM) and Composite CSM (CCSM). For a given set of values of  $T_R$ 

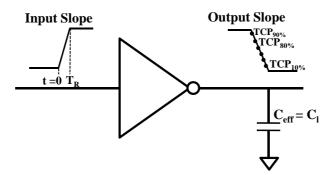


Figure 1.2: ECSM characterization overview.

and  $C_{eff}$ , ECSM stores the time at which the output voltage waveform crosses certain predefined  $\alpha$ % Threshold Crossing Points (TCPs) (shown in Fig.1.2) while CCSM stores the output current values at different threshold crossing points [13]. Both the vendor models are equivalent and one can be derived from the other. In ECSM, LUT of threshold crossing points for several values of  $C_l$  and  $T_R$  is used.

	Input Transition Time (T <sub>R</sub> )				
C <sub>1</sub>	T <sub>R1</sub>	T <sub>R2</sub>		•	T <sub>Rn</sub>
C <sub>n</sub>	<b>V</b> <sub>11</sub>	V <sub>21</sub>			V <sub>n1</sub>
C <sub>12</sub>	V <sub>12</sub>	V <sub>22</sub>			V <sub>n2</sub>
•					
•					
C <sub>In</sub>	V <sub>1n</sub>	V <sub>2n</sub>			V <sub>nn</sub>

Figure 1.3: An LUT of ECSM vectors. For each set of  $C_l$  and  $T_R$ , the characterization data is represented as vector V consisting of time of TCPs.

An LUT used for STA is a two dimensional table (shown in Fig.1.3), in which parameter to be characterized is stored for various  $C_l$  and  $T_R$  values. To minimize the storage, values of parameter to be extracted is stored for limited set of  $C_l$  and  $T_R$  and linear interpolation is used to obtain delay or time of a TCP for other values of  $C_l$ ,  $T_R$ . ECSM characterization is a computationally tedious task. In addition, Process, Voltage and Temperature (PVT) variations and frequent device model updates require a lot of re-characterization. In this work, we address the problem of reducing the number of SPICE simulation in ECSM library characterization. We consider the input to output coupling capacitance effect for CMOS inverter and NAND gate to accurately measure the timing values for ECSM characterization.

### 1.2 Previous Work

Several delay models have been proposed to characterize the behavior of CMOS logic

gates. Some commonly used delay models are discussed here.

The lumped RC delay model is proposed by Ousterhout [18]. In this model, the delay is computed by lumping all of the resistances and capacitances together through a stage. All of the resistances are summed separately, as are all the capacitances, and the product gives the delay through the stage as

$$delay = \left(\sum R\right) \left(\sum C\right) \tag{1.1}$$

The drawback of this model includes overestimation of delay due to lumping of resistance and capacitance values. It does not take into account the influence of input waveform on delay since it is limited to the step input waveform only. Later on, Hedenstierna and Jeppson [19] presented an analytical delay model for CMOS inverter, derived using Shockley's model [20]. The model included the input waveform slope effect. Although it is quite simple to use, but the model proved to be unsuccessful for short channel devices [9]. It does not consider the short channel effects dominating at sub-65nm technology nodes. Sakurai *et al.* [9] proposed an alpha power law model. This model is an extension of Shockley's model considering the velocity saturation effect in short channel devices. The model remains valid for the fast input ramp where input slope crosses one-third of the output slope [21]. In [21], authors reported that the  $\alpha$ -power law model is not valid for slow input ramps and presented an analytical delay model for both fast and slow input rise time.

In 1998, Sutherland *et al.* [22] presented a logical effort method to measure the delay efficiently. This model enables us to find the least delay of the circuit. It finds that how many stages would then be required and what should be size of the transistors in the gates to get the least delay. The method is quite useful for optimizing the circuit speed. The author presented the delay of a logic gate as

$$d = f + p \tag{1.2}$$

Where, f represents the effort delay proportional to the gate's output load and p represents the parasitic delay. The parasitic delay is fixed for a logic gate and independent of cell size and load capacitance it drives. The model is very simple to use but it neglects the input transition time effects and secondary effects like velocity saturation, body effect etc. Traditional method (empirical model) to characterize delay is to use an equation of the form  $k_1C_l + k_2$ , where  $k_1$  is the input transition slope and  $k_2$  is the intrinsic delay. In [10], researchers working with Synopsys presented the Scalable Polynomial Delay Model (SPDM) to characterize the cell delay. The model uses a product of polynomials to fit the delay data. For example, to characterize the delay for two parameters  $C_l$  and  $T_R$ , a product of  $m^{th}$  order polynomial in  $C_l$  with an  $n^{th}$  order polynomial in  $T_R$  may be used in the following form:

$$delay = (a_0 + a_1C_l + \dots + a_mC_l^m)(b_0 + b_1T_R + s\dots + b_nT_R^n)$$
(1.3)

To overcome this complexity, people in industry are now making use of LUTs to obtain

the delay of a logic gate. LUTs with delays tabulated for several values of  $T_R$  and  $C_l$  values are today used in STA. These LUTs are popular due to limitations of analytical and polynomial delay models as discussed above. LUT used for STA is a 2-D table, where the standard cell delay is characterized with several  $T_R$  and  $C_l$  values. There are several problems with the existing LUTs, for example  $T_R$  and  $C_l$  values are selected in an ad-hoc manner, need of re-characterization due to PVT variations, accuracy of the delay values obtained depends on the size of the LUT.

All the aforementioned delay models measure only the propagation delay. These models do not consider the PVT variations and input to output coupling capacitance which are very important at nanometer range technologies. To address the variation in delay values in presence of PVT variations, several delay models are reported [23]-[45]. However, they did not derive the model coefficients considering PVT variation with physical reasoning for the same. While considering process variations, they considered the change in process parameters such as oxide thickness, threshold voltage, doping concentration, gate length, etc. However, they didn't consider the effect of mechanical induced stress as a function of Number of Fingers (NF) on the timing values while the stress engineering is widely being incorporated at nanometer range technologies to enhance the device performance. In this work, we show the dependence of timing values on cell size, load capacitance, input slew, process (mechanical induced stress as a function of NF), voltage and temperature variations. Beside this, we also investigated the importance of overshoot modeling in accurate timing analysis. We found that there are very few researchers who worked on overshoot timing models [46, 47, 48, 49]. In [49], authors show that the conventional delay models [9, 21, 50, 51, which ignore overshoot effect face serious issues of accuracy at these technology nodes. Huang et al. [49] proposed an analytical overshoot model at nanometer technology node. This work gives an overshoot time  $(t_{ov})$  expression according to which  $t_{ov}$  is a function of the logic gates capacitance  $C_l$ . The authors assumed that a linearly time varying current discharges (charges)  $C_l$ . This model has been verified for only large values of input transition time  $T_R$  and  $C_l$ . The minimum value of  $C_l$  used in [49] are typically fanout 100. They also assume that  $t_{ov}$  varies with  $C_l$  which is not validated by the simulation results shown in their reported research work.

- 1. Therefore, the delay models which can be used in nanometer range technologies are either inaccurate or fully empirical and cumbersome to use.
- 2. They neither consider PVT variations through physical reasoning nor the important second order phenomenon such as overshoot due to gate to drain coupling capacitance  $(C_{gd})$ .
- 3. They are not amenable to be used easily in standard cell characterization for STA.

### **1.3** Problem Definition

The aim of this thesis is to propose the timing models to reduce the computational effort in characterization of single stage standard cells at nanometer range technologies. Such a work can easily be extended to multistage standard cells. In order to accomplish this, following approach have been taken:

- Derivation of timing models and their region of validity as a function of  $T_R$  and  $C_l$  for standard cell CMOS inverter
- Verification of the model coefficients' behavior with cell size and technology node for standard cell CMOS inverter
- Derivation of timing models and their region of validity with PVT variability for standard cell CMOS inverter
- Derivation of timing models and their region of validity as a function of  $T_R$  and  $C_l$  for 2-input CMOS NAND gate
- Verification of the model coefficients' behavior with cell size for NAND gate
- Derivation of timing models and their region of validity with PVT variability for NAND gate
- CMOS inverter and NAND gate overshoot modeling

### 1.4 Contributions

The objective of this thesis is to develop an accurate timing model for ECSM characterization of all the TCPs of output voltage at nanometer range technologies. For this, we first develop a timing model for CMOS inverter at 32nm technology node. The model is formulated based on current equations considering velocity saturation. All the factors which affects delay, namely: cell size,  $T_R$  and  $C_l$  are considered in the model. The proposed model matches with the HSPICE simulated results closely for all the TCPs. The model remains valid with the technology scaling.

At nanometer technology node, there is a need for library re-characterization due to onchip PVT variations. To improve the performance, it is important to accurately measure the timing values in circuits while considering voltage, temperature and process induced variability. We derive relationships of the coefficients of our ECSM timing models with PVT variation. For voltage variability, we consider  $\pm 10\%$  variation in nominal supply voltage. For temperature variability, we vary the temperature range from 298K to 423K. For stress variability, we consider the variation in device channel mechanical stress as a function of NF in inverter layout. This is because, often the size of inverter cell is increased by increasing NF, therefore the consequent variation in channel mechanical stress is important. Stress induced in the channel of pMOS (nMOS) using various sources like Compressive/Tensile Etch Stop Liner (c/t-ESL), embedded SiGe (eSiGe) and Stress Memorization Technique (SMT) [52] has been considered in this work.

We derive the timing models for 2-input CMOS NAND gate, considering single input switching and also derive their region of validity in  $T_R$ ,  $C_l$  space. We observe that the improper consideration of intermediate node voltage transition leads to significant percentage error in delay/timing values (we later discuss this in detail). Based on this observation, we consider the intermediate node voltage transition for accurate timing analysis. Further, we determine the relationships of the model coefficients with the cell size, power supply voltage, carrier mobility, threshold voltage and temperature. We also consider layout dependent effects due to mechanical stress in deriving these relationships.

Next, we propose an analytical overshoot timing model for very wide range of  $T_R$  values for CMOS inverter and 2-input NAND gate. For NAND gate standard cell, it becomes important to consider the intermediate node voltage transition in accurate timing analysis. Therefore, we first model the behavior of intermediate node voltage for large values of  $T_R$ . Later on, we derive the relationships of overshoot time with cell size,  $T_R$  and  $C_l$  values. We find that the proposed model is independent of cell size and  $C_l$  values.

The proposed model reduces the number of HSPICE simulations in ECSM characterization of CMOS inverter and NAND gate standard cell by nearly 50% and 67%, respectively. The need to re-characterize the timing models with PVT variation, has thus been reduced.

### 1.5 Thesis Organization

This thesis is organized into 7 chapters as follows:

**Chapter 1:** In this chapter, an introduction to the standard cell characterization and challenges it faces due to the need for more accurate cell characterization are presented.

**Chapter 2:** This chapter provides a detailed literature review on propagation delay models, overshoot timing models, along with the need of an efficient timing model. Technical gaps in the existing literature on timing models and digital circuit performance are discussed. The chapter is concluded with a brief summary of technical gaps to be addressed in the thesis.

**Chapter 3:** This chapter focuses on modeling of timing values of threshold crossing points  $(t_{TCP}s)$  as a function of  $T_R$  and  $C_l$  for a minimum sized CMOS inverter. Further, the region of validity of the model in  $T_R$ ,  $C_l$  space is derived. The relationship between cell size and model coefficient is also derived. We also analyzed, the impact of technology scaling on these model coefficients. The results depict that the proposed model is in good agreement with HSPICE simulations with a maximum error of 2.5%. The contribution of these models in reducing the number of HSPICE simulations in ECSM characterization of the inverter standard cell is nearly half. **Chapter 4:** In this chapter, we consider the impact of process parameters (mechanical induced stress as a function of Number of Fingers (NF)), supply voltage and temperature variations on the proposed  $(t_{TCP})$  models. We derive the relationships of model's coefficients and their region of validity with the process, supply voltage and temperature variations in  $T_R$ ,  $C_l$  space. Therefore, the models considering PVT variation helps in reducing the re-characterization effort in standard cell library characterization. In this chapter, we demonstrate that the inclusion of PVT variation in our  $t_{TCP}$  models reduces the number of HSPICE simulations by about half.

**Chapter 5:** This chapter focuses on modeling of  $t_{TCPS}$  as a function of  $T_R$  and  $C_l$  for 2-input CMOS NAND gate. The NAND gate ECSM characterization done for the following two cases.

- Case 1: When the upper nMOS transistor in series-stack switches
- Case 2: When the lower nMOS transistor in series-stack switches

The region of validity of the  $t_{TCP}$  models in both the cases of 2-input NAND gate is derived. The relationship between cell size and model coefficient is also derived. Further, the impact of PVT variation on the model coefficient's is observed. The results depict that the proposed models are in good agreement with HSPICE simulations with a maximum error of 3%.

**Chapter 6:** This chapter focuses on overshoot timing model for CMOS inverter and 2-input NAND gate. For NAND gate, the boundary conditions are identified based on operating regions of the nMOS series-stack transistors. The relationship between cell size and model coefficient is also derived. The results depict that the overshoot time is independent of  $C_l$  and proportional to  $T_R$ . The proposed model gives a highly accurate estimation of delay values at nanometer range technologies.

**Chapter 7:** Finally, a summary of the presented research work along with the major conclusions of the work and future scope are presented in this chapter.

### Chapter 2

### Literature Review

### 2.1 Overview

This chapter starts with the study of existing delay models of CMOS inverter and NAND gate standard cell. There are several delay/timing models used in digital system design, some are briefly mentioned in the previous chapter. Further, we discuss the technical gaps present in the existing models. We also discuss the reason for their unsuitability in standard cell characterization.

### 2.2 Introduction

Semi-custom design approach at sub nanometer technologies requires efficient computeraided design tools. Designers need to consider several aspects of the chip design such as timing, area and power. In this regard, designers need an accurate and efficient timing model in order to adequately optimize the standard cell based designs. For this an accurate and efficient method for characterizing standard cells is required. In this context, we discuss the limitations of the existing delay models in the following section.

### 2.3 Literature survey on existing delay models

As we discussed in previous section, down scaling and high performance circuits demand accurate timing analysis at sub-nanometer regime. At such technology nodes, a minor variation due to several factors like short channel effects, input to output coupling capacitance, power supply noise and process variations, etc. influences timing parameters significantly [6]. Standard cell or logic gate timing characterization must therefore account for all these parameters. Therefore, designing accurate and high performance circuits has become more challenging than ever in deep sub-micron era, in semi-custom domain. This section presents a brief description of past researcher's timing models for CMOS combinational logic gates.

The first delay model for CMOS inverter was introduced by Burns [53]. The model presented the differential equation based closed-form expression for the output waveform of CMOS inverter using a step input. Burns also derived a closed-form expressions for the

rise and fall time of CMOS inverter. Later on, the lumped RC delay model was proposed by Ousterhout [54]. In this model, the delay is computed by lumping all of the resistances and capacitances together through a stage. But, this model gives an overestimation of the delay due to lumped resistances and capacitances. And the major drawback of this model is that it doesn't deal with the shape of input waveform. To improve the delay analysis, Hedenstierna and Jeppson [19] presented an analytical delay model derived using Shockley's model [20], that includes the input waveform slope effect. Since, the Shockley's model is quite simple and has been used by many researchers. However, the model is not suitable for short channel devices as it does not consider the second order effects.

In [55], Jeppson presented an improved semi-empirical delay model by considering gateto-drain coupling capacitance. Soon, Nabavi *et. al* [56] presented an empirical model for computing the inverter delay. In [56], authors discussed the transient behavior for the two extreme cases i.e. very fast and very slow input transition times. For slow inputs, authors assumed that the negligible current flows through the load, whereas for fast inputs, the change in output voltage is negligibly small during the input transition. Hence, they ignored the effect of the output load on the delay for the extremely slow and fast inputs. All the models described above have a limitation that they ignored velocity saturation effect which is prominent at nanometer range technology nodes.

In [9], Sakurai et. al presented the " $\alpha$ - power law delay model" considering the velocity saturation effect for short channel devices. To derive this model authors neglected the short circuit current and gate-to-drain coupling capacitance. And, the model remains valid for fast input ramps only. Using the  $\alpha$ -power law model, Embabi et. al [57] presented the delay model considering the short-circuit current into account. But, the model assumed the output voltage and the currents through the transistors to be piecewise linear. For slow input ramps, Dutta et. al [21] presented a delay model for CMOS inverter, which is an extension of Sakurai's delay model. Soon, Choi et. al [58] presented a delay model for CMOS logic gates to overcome the disadvantage of RC delay model. The model considered the MOSFET as a resistor or current source depending on the input and output voltage of the inverter. For NAND/NOR gate, authors assumed that N number of transistors in the series stack can be modeled as a single transistor. This assumption leads to significant error in the delay values. In [22], Sutherland et al. presented the method of "logical effort" which enables us to choose the topology and also tells us which topology is better for the circuit, how many stages would then be required to get the least delay and what should be size of the transistors in the gates. The method is quite simple and accurate if the input slope effect is ignored. Since, input transition time is one of the important parameters in the standard cell characterization which can not be ignored.

Traditional method (empirical models) to characterize delay is to use an equation of the form  $k_1C_l + k_2$ , where  $k_1$  is the input transition slope and  $k_2$  is the intrinsic delay. Soon, Synopsys [10], presented the Scalable Polynomial Delay Model (SPDM) to characterize the cell delay. The model uses a product of polynomials to fit the delay data. For example, to characterize the delay for two parameters  $C_l$  and  $T_R$ , a product of  $m^{th}$  order polynomial in  $C_l$  with an  $n^{th}$  order polynomial in  $T_R$  may be used in the following form:

$$delay = (a_0 + a_1C_l + \ldots + a_mC_l^m)(b_0 + b_1T_R + s \ldots + b_nT_R^n)$$
(2.1)

Which is a purely empirical expression and has to be extracted for each variation in any parameter affecting circuits. To avoid such complex expressions, industry people are now using LUTs to represent the delay of a logic gate. LUTs with delays tabulated for several values of  $T_R$  and  $C_l$  values are today used in STA. These LUTs are popular due to limitations of analytical and polynomial delay models as discussed above. LUT used for STA is a 2-D table, where the standard cell delay is characterized with several  $T_R$  and  $C_l$ values. Delays for the  $T_R$  and  $C_l$  values which are not listed in the LUTs are obtained using linear interpolation between the nearest two  $T_R$  and  $C_l$  values. There are several problem with the existing LUTs, for example  $T_R$  and  $C_l$  values are selected in an ad-ho c manner, need of re-characterization due to PVT variations, accuracy of the delay values obtained depends on the size of the LUT.

In [59], authors proposed a linear timing model to characterize delay and power dissipation of cells. The 50% delay is used to characterize the linear delay parameters. In [60], Patel presented a method to characterize the cell delay and capacitance parameters. However, these models are inconsistent when a cell drives different type of cell. In [61], authors proposed an LUT based approach to simplify the characterization of complicated cells. The method is particularly useful for the cases when the internal structure of standard cell is known. Further, in [62], Cirit used an LUT based approach to characterize the cells, where a cell being characterized is considered as a black box. It gave us the flexibility to consider any standard cell for characterization whose internal structure is not known. The model uses interpolation method to compute the delay values for those  $T_R$  and  $C_l$  values which are not given in the LUT. It requires software to perform mathematical analysis, thus makes the cell characterization process slow.

There are several delay models [63]-[73], proposed for CMOS inverter, and very few for the NAND gate standard cell. Recently, Gummalla *et al.* [2] presented an analytical timing model for 2-input NAND gate. The authors used Elmore delay model to consider the intermediate node voltage transition of the series stack for the switching of lower nMOS transistor in the series stack of the NAND gate, which may lead to significant error. This is because the upper nMOS transistor in the series stack operates in the saturation region for the  $C_l$  and  $T_R$  values typically found in circuits (explained in detail in Chapter 5). However, since they use Elmore delay model, they assumed it to be operating in linear region which results in a gross underestimation of delay values (as shown in Fig. 2.1).

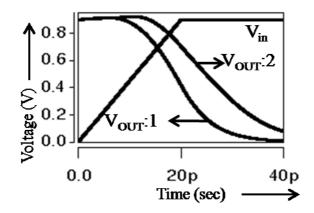


Figure 2.1: Response of the NAND gate for fixed input transition time;  $V_{out}$ : 1 represents the O/P voltage when the upper nMOS transistor is replaced by an equivalent resistor and  $V_{out}$ : 2 represents the O/P voltage for the realistic case where the upper nMOS of 2-input NAND gate is not replaced (For  $V_{out:1}$ , we obtain the equivalent resistance value from the linear current equation (1) of [2]).

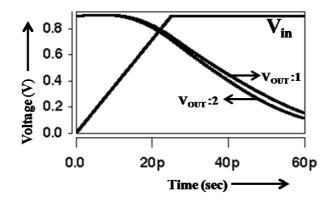


Figure 2.2: Response of the NAND gate for fixed input transition time;  $V_{out}$ : 1 represents the O/P voltage when the pull down part is replaced with the half width single nMOS transistor and  $V_{out}$ : 2 represents the O/P voltage for the conventional 2-input NAND gate.

When upper nMOS transistor in the series stack switches, Gummalla did not consider the effect of intermediate node of the series stack of nMOS transistors and replaced the series stack of nMOS transistors with the half width single nMOS transistor. We observe that this assumption leads to an overestimation of delay values as shown in Fig. 2.2.

Due to simplicity and accuracy, NLDM based on LUT approach is used widely for standard cell characterization by Synopsys. At sub-nanometer technologies, there are limitations of the NLDM in cell characterization which makes it less accurate. These limitations are the inaccurate shape of input waveform, undesirable value of nonlinear capacitance, etc [55]. Therefore, in modern CMOS technology, it becomes increasingly important to model the complex input waveforms, nonlinear capacitance and process variations [74]. In this scenario, the conventional standard cell characterization approach isn't found as an efficient technique to address problems. This conventional technique is useful to model the signal transitions as saturated ramps with known arrival and transition times. Therefore, researchers have introduced an alternative modeling technique known as Current Source Modeling (CSM) which becomes increasingly important for use in standard cell characterization and static timing analysis (STA).

### 2.3.1 CSM based standard cell timing analysis

CSMs ideally support arbitrary input waveforms and output loads since their model parameters are waveform and load independent [75]. A current-based gate model includes a 2-D lookup table  $I_0(V_i, V_0)$  which gives gate output current for a pair of gate input and output voltages, and voltage-controlled capacitor at the gate output. The CSM model proposed by Tutuianu *et al.* [76] is similar to [77, 78]. Croix *et al.* [14], proposed a CSM model which is independent of input waveform and output load as shown in Fig. 2.3. This "Blade" model consists of a voltage-controlled current source, an internal capacitance (Cinternal), and a time shift of the output waveform. The model is essentially a  $V_i - V_o$  based (input voltage, output voltage) current source with transient effects modeled by a linear capacitance at the output. A linear capacitance to model the active input load is assumed because the capacitances have a linear relationship with respect to device dimension for a given technology.

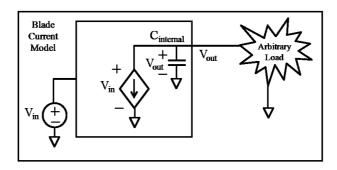


Figure 2.3: The Blade model consists of a voltage-controlled current source with a constant internal capacitance and input waveform time shift driving an arbitrary load.

It was the first CSM of a logic cell in which a pre-characterized current source is utilized to capture the non-linear behavior of the cell with respect to the input and output voltage values. The single output capacitance does not capture non-linearity. The miller effect between input and output nodes was ignored in this model. The ignorance of miller capacitance resulted in an under-estimation of delay. Keller et. al. [15], presented a CSM for the purpose of crosstalk noise analysis. The authors used a pre-characterized current source for the noise analysis. The parasitic components, namely the output and miller capacitances are assumed to be constant regardless of input and output voltage values. In practice, these capacitive effects can vary by orders of magnitude depending on cell input and output voltage values [79, 80].

In [16], Li and Acar has resolved this weakness by introducing a non-linear output capacitance model. Soon, Fatemi et.al. [3] used non-linear input, output and miller capacitances along with an output current source for the delay analysis, these all are function of the input and output voltages as shown in Fig. 2.4.

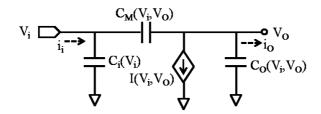


Figure 2.4: Current-based circuit model of a logic cell proposed by [3].

In [81], Kashyap *et. al.* presented a CSM in which input and output pins as well as several chosen internal pins of the cell are modeled with a voltage dependent current source and a non-linear capacitance. Veetil *et. al.* [82], investigated the importance of various modeling decisions on the accuracy and complexity of CSMs. The authors reported the bi-cubic spline based DC current source model for accurate and efficient timing analysis. For transient analysis, authors assumed that a cell can be replaced with simple parasitic capacitance model and a time shift parameter. These models require the precharacterization of standard cells. Its very time consuming and cumbersome, as each parameter is dependent on input and output voltages.

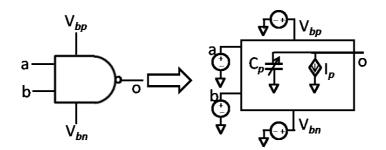


Figure 2.5: Example of a CSM: the output port is modeled as a nonlinear voltage controlled current source, dependent on all input port voltages, in parallel with a nonlinear capacitance [4]).

In 2010, Gupta *et al.* [4] developed a new approach to capture compactly the body bias effects within a mainstream CSM framework (shown in Fig. 2.5). The model is based on Blade model (given in [14]) except that the output port is replaced by a nonlinear voltage controlled current source,  $I_p$ , in parallel with a nonlinear capacitance,  $C_p$ . The mathematical framework for this new approach consists of two key steps. First approach is made by adapting an existing scheme to enable the compact storage of look-up tables for the sensitivities of CSM components to body bias, over the range of allowable values of the body bias. Second approach is on the basis of development of a novel waveform sensitivity model for evaluating the impact of applied body bias that provides accurate waveforms at the output of the cell under any body bias with minimal computation. Challenges of CSM [83] :

1. Each parameter of the cell is dependent on input and output node voltages which results in much larger libraries. Hence, library size has increased due to the development of CSM. 2. The complexity of the models has increased significantly over the NLDM models used for standard cell characterization.

EDA tool vendors found a middle path to solve these issues, known as vendor CSM formats. Two available CSM vendor formats are ECSM [84] and CCSM [85]. For a given input slew and load capacitance  $(C_l=C_{eff})$  values, ECSM stores the times at which the output voltage waveform crosses certain predefined threshold points whereas CCSM stores the output current values at specified voltage level points. Both the vendor models are equivalent and one can be derived from the other. Vendor CSMs use LUT based format for representing characterization data. It overcomes the problems of the voltage-based models which is not compatible with the arbitrary shapes of voltage waveforms and falls short when dealing with crosstalk-induced noisy waveforms. ECSMs have recently received increased attention with major EDA vendors for supporting the noise model or power droop model [77, 78].

# 2.3.2 Overshoot timing Model for CMOS inverter and 2-input NAND gate

With the continuous scaling of devices in nanometer regime, the overshoot time becomes dominating component of gate delay for CMOS inverter standard cell. Due to the inputto-output coupling capacitance, the output voltage of a CMOS gate is beyond the power supply range at the beginning of the transition. This phenomenon is referred as overshoot effect and the time corresponds to the output voltage at power supply range is known as overshoot time. Several researchers [55, 56, 63, 64, 68, 72] accounted for the non linearity induced by the input-to-output coupling capacitance in their proposed gate delay model. Earlier, Turgis et al. [86] and Rossello et al. [72] estimated the power consumption of CMOS buffers under the consideration of the influence of input-to-output coupling capacitance in sub-micrometer technologies. Several empirical models have also been proposed to estimate overshoot time. In [63], the authors derived a closed form expression to compute the CMOS gate delay time. Using an empirical model, Rossello et al. [72] analyzed the CMOS gate power consumption. Recently, Huang et al. [49] modeled the overshoot effect of CMOS inverter delay in nanometer technologies. The proposed model accurately takes into account the input-to-output coupling capacitance of the CMOS inverter. The authors have verified the proposed model with 32nm PTM high-k/metal gate model [87, 46]. The overshoot effect in multi-input CMOS gate is also an important issue in current nanometer regime technologies. Recently, the authors in [46], presented the overshoot timing model for multi-input gate (NAND and NOR) taking the miller capacitance into consideration. The overshoot timing models presented in [49, 46], for CMOS inverter and multi-input gates are dependent on the load capacitance according to their model equation. But it is not validated by their own simulation results.

## 2.4 Technical Gaps

Based on literature survey, the importance of efficient and accurate delay model on device performance with technology scaling is observed. However, the accuracy of delay models is highly dependent on shape of waveform, parasitic capacitances, load capacitance and input transition time. Though, to enhance the circuit performance in standard cell characterization, extensive work has been done by the several authors, but the following major gaps and important issues are still there which have not been addressed.

- 1. Using NLDM or ECSM/CCSM based standard cell characterization, industry people extract all the delay point in  $C_l$ ,  $T_R$  space using fully HSPICE generated characterization LUT. This approach takes a lot of time to obtain all the delay values in given  $C_l$ ,  $T_R$  space. However, none of the above authors reported the region of validity of their proposed model.
- 2. Now a days, LUT based NLDM being used for standard cell characterization. To consider the PVT variations at such technology node, there is need of re-characterization of these LUTs resulting in huge characterization effort and time as well. None of the above author, addressed the method to reduce this re-characterization effort.
- 3. Below 65nm technology node, stress engineering is being incorporated to enhance the device performance. None of the above author reported the delay model which can be used in standard cell characterization, considering the variation in device channel mechanical stress as a function of NF.
- 4. There are several delay models for CMOS inverter (as we discussed above), but very few for the NAND gate. The latest model for NAND gate is reported by Gummalla [2]. The model considers the intermediate node voltage transition to obtain the propagation delay. The author makes use of Elmore delay model to consider the intermediate node voltage transition. This assumption leads to significant percentage error in delay values.
- 5. There are very few overshoot timing models, recently Huang *et al.* reported the overshoot timing model for CMOS inverter and multi-input gates (NAND, NOR). They reported in the paper that overshoot time is function of  $C_l$ , which it is not validated by their own results. No one has reported earlier that overshoot time is independent of  $C_l$ .

# Chapter 3

# Timing model for CMOS inverter standard cell and its region of validity

### 3.1 Overview

This chapter focuses on modeling of  $t_{TCP}s$  as a function of  $T_R$  and  $C_l$  for a CMOS inverter. Further, the region of validity of the model in  $T_R$ ,  $C_l$  space is derived. The relationship between cell size and model coefficients are also derived. While developing the model, we make appropriate assumptions and later justify the use of all our assumptions. Further, the impact of technology scaling on these model coefficients is considered. The results depict that the proposed model is in good agreement with HSPICE simulations with a maximum error of 2.5%. We then propose a method to use our  $t_{TCP}$  models in reducing the number of HSPICE simulations in ECSM characterization of standard cells. The contribution of these models in reducing the number of HSPICE simulations in ECSM characterization of the inverter standard cell is nearly half.

The chapter is organized as follows. In Section 6.2, we describe our simulation setup. In Section 3.3, we derive our  $t_{TCP}$  models. In Section 3.4, we use these models to reduce the number of simulations for ECSM characterization. In Section 3.5, we verify the validity of proposed models with respect to technology node.

# 3.2 Simulation Setup

In this chapter, we use HSPICE simulations at 32nm CMOS technology node. In these simulations, we use BSIM 4.0 Predictive Technology device Model (PTM)<sup>1</sup>. We keep  $W_p/W_n = 2.5$  to obtain equal inverter's rise and fall transition times. Therefore,  $W_n$  can represent the size of inverter standard cell. We verify our models with technology scaling using HSPICE simulations at 22nm CMOS technology node. In this chapter, the value of parasitic capacitance ( $C_p$ ) of CMOS inverter, is extracted using the integral of the difference of the currents through the sources of pMOS and nMOS for 80%-20% of output transition.

 $<sup>^{1}</sup>Obtained from http://ptm.asu.edu/$ 

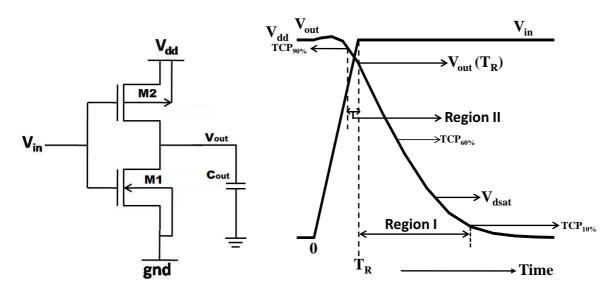


Figure 3.1: CMOS inverter with input and output waveform.

In this chapter, we represent the  $0 - V_{dd}$  input transition as  $T_R$  and 20 - 80% of  $V_{dd}$  of input transition as  $T_{Rin}$ . When rising input transition starts to increase, respective time is represented as t = 0.

## 3.3 Timing model for CMOS inverter standard cell

In this section, we first develop a timing model for CMOS inverter. We assume the rising input transition for the derivation of TCPs model, similar analysis is valid for falling input transition. For our derivation, we classify the TCPs into two regions (shown in Fig. 3.1):

- Region I: When  $V_{in} = V_{dd}$  (for  $t_{TCPs} > T_R$ )
- Region II: When  $V_{in} < V_{dd}$  (for  $t_{TCPs} < T_R$ )

#### 3.3.1 Derivation of the model in Region I

In this subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  values and size of inverter  $(W_n)$  for Region I. As we depict in Fig. 3.1, Region I contain all the TCPs having value  $V_{TCP}$  smaller than  $V_{out}(T_R)$ . The proposed model remains valid for all the cases where  $V_{out}(T_R) \geq V_{dsat}$ , where  $V_{dsat}$  is the for the inverter's (discharging) nMOS device<sup>2</sup>. The output discharge comprises of two regions: First, when the input transitions from 0 to  $V_{dd}$ and second, when the input voltage reaches  $V_{dd}$ .

In this derivation, we assume that the discharging nMOS operates either in saturation or in linear region. To derive the model, we first integrate the saturation current through the nMOS during the input transition  $V_{in}(t) = V_{dd}(\frac{t}{T_R})$  for  $0 \le t \le T_R$ . We equate this

<sup>&</sup>lt;sup>2</sup>We assume that the value of  $V_{dsat}$  is very weakly dependent on the values of  $V_{ds}$ , as in [9].

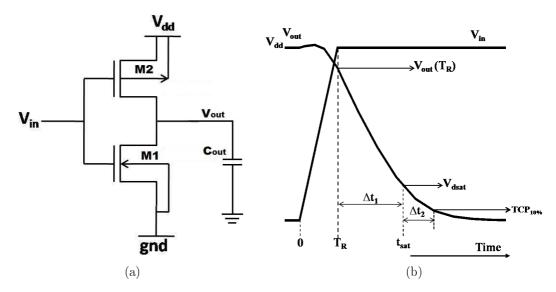


Figure 3.2: (a) CMOS inverter schematic. (b) I/O waveform of CMOS inverter for Region I.

integral to  $(C_l + C_p)(V_{dd} - V_{out}(T_R))$  to obtain  $V_{out}(T_R)$ . The output voltage discharge  $\triangle Q(T_R)$  from 0 to  $T_R$  is given as (refer Fig. 3.2):

$$\Delta Q(T_R) = \int_0^{T_R} I_{M1} dt = (C_l + C_p)(V_{dd} - V_{out}(T_R))$$
(3.1)

Where,  $C_l$  is the load capacitance and  $C_p$  is the parasitic capacitance. The values of  $I_{ON}$ ,  $I_{lin}$ ,  $V_{dsat}$  and R used in this model are obtained from alpha power law model [9] as:

$$I_{ON} = v_{sat} W_n P_s \left( V_{gs} - V_{th} \right)^{\alpha} \tag{3.2}$$

$$I_{lin} = \mu \frac{W_n}{L_{eff}} P_l \left( V_{gs} - V_{th} \right)^m V_{ds}$$
(3.3)

$$V_{dsat} = \frac{v_{sat} P_s (V_{gs} - V_{th})^m L_{eff}}{\mu P_l}$$
(3.4)

$$R = \frac{1}{\mu \frac{W_n}{L_{eff}} P_l (V_{gs} - V_{th})^m}$$
(3.5)

Where  $P_s$ ,  $P_l$  are technology dependent parameters,  $v_{sat}$  is the saturation velocity and  $\mu$  is the mobility of the nMOS device. The exponents m and  $\alpha$  are velocity saturation indices, which are also technology dependent. In our case, we use  $m = \alpha = 1$ , which we verify through HSPICE simulations. We now explain our derivation of  $t_{TCP}$  in Region I:

- 1. We integrate the saturation current through the nMOS from t = 0 to  $T_R$  and equate this integral to  $(C_l + C_p)(V_{dd} - V_{out}(T_R))$  to find the expression of  $V_{out}(T_R)$ .
- 2. Next, we proceed as follows:

- If  $V_{TCP} > V_{dsat}$ , we integrate the discharging nMOS current,  $I_{ON}$  ( $V_{gs} = V_{dd}$ ), from  $t = T_R$  to  $t = t_{TCP}$ . We equate the sum of these integrals to  $(C_l + C_p)(V_{out}(T_R) V_{TCP})$  to obtain  $t_{TCP}$ .
- If  $V_{TCP} < V_{dsat}$ , we integrate the discharging nMOS current,  $I_{ON}$  ( $V_{gs} = V_{dd}$ ), from  $t = T_R$  to  $t = t_{sat}$ , represented as  $\Delta t_1$  in Fig. 3.2, (where  $t = t_{sat}$  when  $V_{out} = V_{dsat}$ ). We equate the sum of these integrals to  $(C_l + C_p)(V_{out}(T_R) - V_{dsat})$  to obtain  $\Delta t_1$ . From  $t = t_{sat}$  to  $t = t_{TCP}$ , represented as  $\Delta t_2$ , shown in Fig. 3.2, where, the nMOS transistor operates in linear region. We find that  $\Delta t_2$  proportional to time constant RC. We add  $\Delta t_1$  and  $\Delta t_2$ , to obtain the  $t_{TCP}$  model.

From  $t = t_{sat}$  to  $t = t_{TCP}$ , the nMOS device acts as a resistance (R) (given in (3.5)) and its value is obtained by differentiating the linear region current equation of  $M_1$  with  $V_{ds}$ , equating  $V_{gs} = V_{dd}$ . Therefore, the time duration from  $t_{sat}$  to  $t_{TCP}$  is proportional to time constant  $R(C_l + C_p)$ .

We observe that the same assumptions are valid for all the TCPs under Region I if the constraint  $V_{out}(T_R) \geq V_{dsat}$  is followed. We derive the model for  $t_{TCP_{10\%}}$  (because,  $t_{TCP_{10\%}} > T_R$ ), since it lies somewhere in the time span  $\Delta t_2$  (refer to Fig. 3.2). The term  $t_{TCP_{10\%}}$  defines the time at which output waveform crosses a voltage level of  $0.1V_{dd}$ . Thus, the  $t_{TCP_{10\%}}$  model would be a representative for all the TCPs when the nMOS device goes into linear region.

To derive the  $t_{TCP_{10\%}}$  model, we follow the procedure, as discussed in the previous paragraph. We need to find out the expressions for  $\Delta t_1$  and  $\Delta t_2$ . The timing model for  $t_{TCP_{10\%}}$  can be written as:

$$t_{TCP10\%} = T_R + \Delta t_1 + \Delta t_2 \tag{3.6}$$

Please note that we measure the  $t_{TCPs}$  from  $t = \frac{V_{th}}{V_{dd}}T_R$  to  $t = t_{TCP10\%}$ , as we assume that nMOS starts operating in saturation region at  $t = \frac{V_{th}}{V_{dd}}T_R$ . In (3.6),  $\Delta t_1$  is represented as the time taken by output voltage to discharge from  $V_{out}(T_R)$  to  $V_{dsat}$ . The output voltage discharge  $\Delta Q(t_1)$  from  $V_{out}(T_R)$  to  $V_{dsat}$  is given as:

$$\Delta Q(t_1) = \int_{T_R}^{t_{sat}} I_{M1} dt = (C_l + C_p)(V_{out}(T_R) - V_{dsat})$$
(3.7)

Solving (3.1) and (3.7), we get the expression for  $\Delta t_1$ . As we discussed earlier, from  $t = t_{sat}$  to  $t = t_{TCP}$  *i.e.*  $\Delta t_2$  is proportional to time constant  $R(C_l + C_p)$ . Using all the above equations, we get the  $t_{TCP10\%}$  as:

$$t_{TCP_{10\%}} = K_1 C_l + K_2 T_R + K_3 \tag{3.8}$$

Where,  $K_1$ ,  $K_2$  and  $K_3$  are the coefficients extracted by fitting (4.1) into HSPICE simulated data.

Where,

$$K_1 = \frac{(V_{dd} - V_{dsat})}{I_{ON}} + R$$
(3.9)

$$K_2 = \left[0.8 - \frac{S_T}{I_{ON}}\right] \tag{3.10}$$

Where,

$$S_T = v_{sat} W_n P_s \left(\frac{V_{dd}}{2} - V_{th}\right)$$

$$K_3 = C_p \left[\frac{(V_{dd} - V_{dsat})}{I_{ON}} + R\right]$$
(3.11)

We obtain a linear relationship between  $t_{TCP}$  and  $C_l$  and  $T_R$  as given in (4.1). We observe that the same assumptions are valid for all the TCPs under Region I since the constraint  $V_{out}(T_R) \ge V_{dsat}$  is followed. In this chapter, we show the model validation results for  $t_{TCP60\%}$ , since  $t_{TCP60\%} > T_R$ . Where,  $t_{TCP60\%}$  defines the time at which output waveform crosses a voltage level of  $0.6V_{dd}$ . For  $t_{TCP60\%}$ , the form of model remains same. The coefficient values also remains same, the only difference is that the term R will not be present. The same model (*i.e.*  $t_{TCP60\%}$ ) is valid for  $t_{sat}$ . The following observations have been made from the derivation of (4.1):

- Observation 1:  $K_1$  is a linear function of  $1/W_n$
- Observation 2:  $K_2$  and  $K_3$  both are independent of  $W_n$

As explained earlier, (4.1) is valid if  $V_{out}(T_R) \ge V_{dsat}$ , this imposes the following constraint on the region of validity:

$$\Delta Q(T_R) = S_T T_R \le (C_l + C_p)(V_{dd} - V_{dsat}) \tag{3.12}$$

Where  $\triangle Q(T_R)$  is the output discharge from 0 to  $T_R$ ,  $S_T$  is a constant proportional to  $W_n$ ,  $C_p$  is the inverter's parasitic capacitance proportional to  $W_n$ ,  $V_{dd}$  is the power supply voltage. Further we use the term  $t_{rb}$ , it denotes the maximum value of  $T_R$  which satisfy (3.12). Equation (3.12) shows the linear relationship between  $t_{rb}$  and  $C_l$ . The following observations are made regarding the derived linear relationship:

- Observation 3: Slope of  $t_{rb}$  vs  $C_l$  plot (*i.e.*  $S_{trb}$ ) is proportional to  $1/W_n$
- Observation 4: Intercept is a constant with  $W_n$

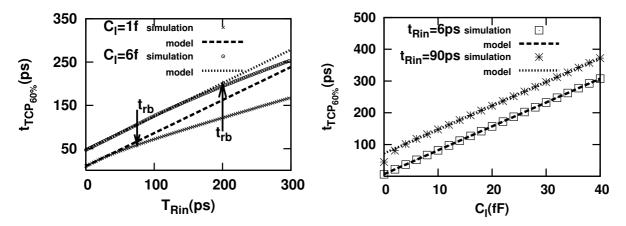


Figure 3.3: Variation of  $t_{TCP_{60\%}}$  with respect to  $T_{Rin}$  and  $C_l$  values.

#### 3.3.1.1 Verification of the model

We verified Observation 1-4 with HSPICE 32nm BSIM PTM shown in Fig. 3.4 to Fig. 3.5. Fitting (4.1) on the simulated values of  $t_{TCP_{60\%}}$  (as shown in Fig. 3.3), we extracted the coefficients  $(K_1, K_2, K_3)$  of (4.1).

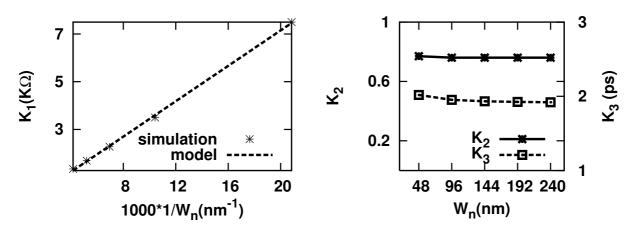


Figure 3.4: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with  $W_n$ .

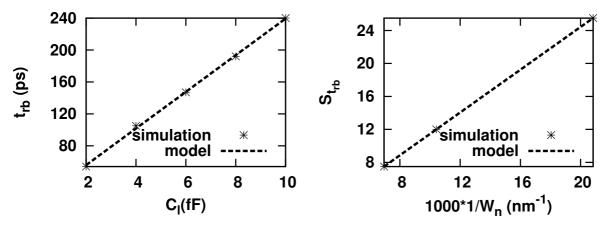


Figure 3.5:  $S_{trb}$  variation with  $W_n$ .

Here, the points are the simulated data and the discontinuous lines are the curve fitting

of the proposed model. The  $t_{TCP}$  model given by (4.1) for Region I has thus been verified using HSPICE simulated data for  $TCP_{60\%}$ .

#### 3.3.2 Derivation of the model in Region II

In this section, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and size of inverter  $(W_n)$  for Region II when  $V_{out}(T_R) \geq V_{dsat}$  (Refer to Fig. 3.6). As a representative, we derived model for  $t_{TCP_{90\%}}$  shown in Fig. 3.6. This is because  $t_{TCP_{90\%}} < T_R$  in the whole  $T_R$ ,  $C_l$  space used in characterization LUTs.

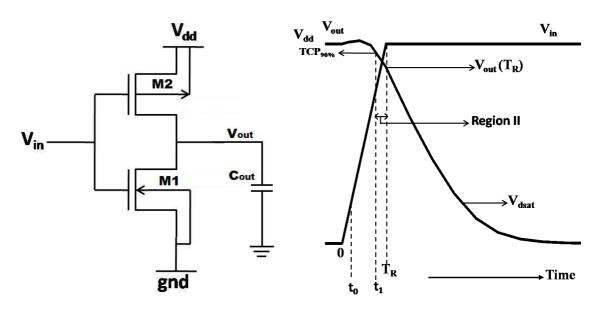


Figure 3.6: I/O waveform of CMOS inverter for Region II.

We assume the rising input transition for the derivation of  $t_{TCP90\%}$  model and it is given as;

$$V_{GS} = \frac{V_{dd}}{T_R} \times t \qquad for (0 \le t \le T_R)$$
$$= V_{dd} \qquad for (t > T_R)$$
(3.13)

Where  $V_{GS}$  is the gate source voltage of inverter's nMOS device, t is the time and  $T_R$ is the transition time of input rising from 0 to  $V_{dd}$ . In this derivation, we assume that the discharging nMOS operates in velocity saturation, respective current is represented as  $I_{ON}$  given in (3.3) derived from alpha power law model [9]. The output voltage discharge  $\Delta Q(t_1)$  through nMOS device from  $t_0 = \left(\frac{V_{th}}{V_{dd}}T_R\right)$  to  $t_1(=t_{TCP90\%})$  (refer to Fig. 3.6) is:

$$\Delta Q(t_1) = \int_{t_0}^{t_1} I_{M1} dt \tag{3.14}$$

The value of  $\left(\frac{V_{th}}{V_{dd}}\right)$  is much smaller than 1 in CMOS technology. In our case it is 0.2V.

$$\frac{\Delta Q(t_1)}{\beta_s} = \int_{t_0}^{t_1} \left(\frac{V_{dd} \cdot t}{T_R} - V_{th}\right) dt \qquad (3.15)$$

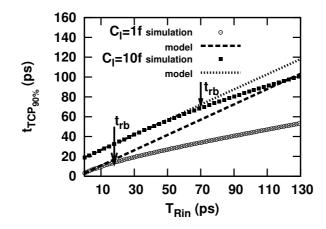


Figure 3.7: Variation of  $t_{TCP_{90\%}}$  with respect to  $T_{Rin}$ .

Where, for  $t_{TCP90\%}$ ,  $\Delta Q(t_1) = 0.1 V_{dd}(C_l + C_p)$  and  $\beta_s = v_{sat} W_n P_s$ . Solving (3.15), we get an expression for  $t_1$  as follows:

$$t_{TCP90\%} = A_1 T_R + A_2 \sqrt{T_R} \tag{3.16}$$

Where,

$$A_1 = \left(\frac{V_{th}}{V_{dd}}\right) \tag{3.17}$$

and

$$A_2 = \left(\sqrt{\frac{0.2(C_l + C_p)}{\beta_s}}\right) \tag{3.18}$$

Where,  $t_{TCP_{90\%}}$  defines the time at which output waveform crosses a voltage level of  $0.9V_{dd}$  and  $A_1$ ,  $A_2$  are the model's coefficients (extracted by fitting (4.2) into HSPICE simulated data). The following observations have been made from the (4.2) :

- Observation 5:  $A_1$  is independent of  $W_n$  and  $C_l$
- Observation 6:  $A_2$  is proportional to  $\sqrt{C_l}$
- Observation 7:  $A_2$  is a linear function of  $\sqrt{\frac{1}{W_n}}$

Similar to subsection 3.3.1, the region of validity of proposed model for Region II is:

$$\Delta Q(T_R) = S_T T_R > (C_l + C_p)(V_{dd} - V_{dsat}) \tag{3.19}$$

Equation (5.20) shows a linear relationship between  $t_{rb}$  and  $C_l$ . Therefore, Observation 3 and 4 remains valid for the proposed model in Region II. The same assumptions (as discussed in this subsection) are valid for all the *TCPs* under Region II since the constraint  $V_{out}(T_R) \geq V_{dsat}$  is followed.

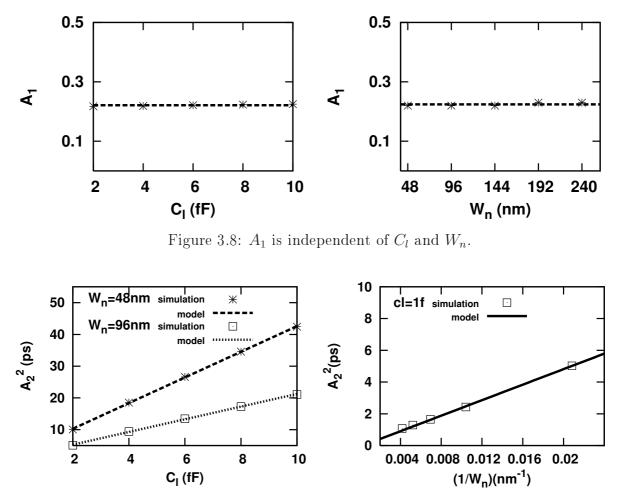


Figure 3.9:  $A_2$  varies with  $C_l$  and  $\frac{1}{W_n}$  as predicted by (4.7).

#### 3.3.2.1 Verification of the model

We verify Observation 5-7 using HSPICE simulations of 32nm BSIM PTM. The  $t_{TCP}$  model given by (4.2) for Region II has also been verified using HSPICE simulated data for  $TCP_{90\%}$ . Please note that we have not included the inverse narrow width effects in the proposed work. However, the corresponding changes in the values of model's coefficients can be predicted using well known equations in [88] and our models.

## 3.4 Efficient ECSM Characterization

In this section, we use the models derived in Section 3.3 to reduce the number of HSPICE simulations required in ECSM (or CCSM) characterization of an inverter standard cell. Using (4.1) and (4.2), within their regions of validity, we can get the values of all  $t_{TCPS}$ without simulations. Hence, it saves HSPICE simulations in standard cell characterization. On the other hand, the  $t_{TCP}$  values which are out of validity bound in Region I and II, will be calculated from HSPICE simulations. For an inverter standard cell, we first extracted the values of  $K_1$ ,  $K_2$  and  $K_3$  for TCPs in Region 1 using 7 HSPICE simulations and  $A_1$ ,  $A_2$  using 4 HSPICE simulations. Later on, we calculate the values of  $t_{TCPS}$  (entries shown by numeric values in Table 3.1 and 3.4) for  $C_l$ ,  $T_R$  values lying within the region of validity

$C_{l}\left( \mathbf{fF}\right)$	$\mathbf{T_{R}}\left( \mathbf{ps} ight)$								
	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	14.35	15.57	18.26	24.17	HSPICE	HSPICE	HSPICE		
2.28	20.14	21.36	24.05	29.96	42.97	HSPICE	HSPICE		
3.45	28.89	30.11	32.79	38.70	51.72	HSPICE	HSPICE		
5.22	42.10	43.32	46.01	51.92	64.93	93.57	HSPICE		
7.88	62.07	63.29	65.98	71.89	84.90	113.54	HSPICE		
11.91	92.25	93.47	96.16	102.07	115.08	143.72	206.74		
18.00	137.86	139.08	141.77	147.68	160.69	189.33	252.34		

Table 3.1: LUT of  $TCP_{60\%}$  for minimum size CMOS inverter using our Region I model.

Table 3.2: LUT of  $TCP_{60\%}$  for minimum size CMOS inverter obtained using HSPICE simulations.

$C_{l}\left( \mathbf{fF} ight)$	$\mathbf{T_{R}}\left(\mathbf{ps} ight)$								
$\mathbf{O}_{\mathbf{I}}(\mathbf{I}\mathbf{r})$	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	14.49	15.70	18.37	24.32	37.48	61.71	106.50		
2.28	20.30	21.51	24.18	30.11	43.43	70.28	118.65		
3.45	29.09	30.30	32.98	38.89	52.09	81.07	134.17		
5.22	42.36	43.58	46.25	52.15	65.28	94.65	153.74		
7.88	62.42	63.64	66.31	72.21	85.26	114.34	178.27		
11.91	92.72	93.94	96.62	102.52	115.52	144.40	209.10		
18.00	138.52	139.74	142.41	148.31	161.29	190.03	254.07		

of (4.1) and (4.2).

Table 3.3: Percentage error in proposed model's LUT with respect to fully HSPICE generated ECSM LUT of  $TCP_{60\%}$  for CMOS inverter. Entries shown by '×' correspond to the values obtained from HSPICE simulations (not through our models).

$\mathbf{C}_{l}\left(\mathbf{fF}\right)$	$\mathbf{T_{R}}\left(\mathbf{ps} ight)$									
	2.20	4.84	10.66	23.46	51.62	113.60	250.00			
1.51	0.97	0.83	0.60	0.62	×	×	×			
2.28	0.79	0.70	0.54	0.50	1.06	×	×			
3.45	0.69	0.63	0.58	0.49	0.71	×	×			
5.22	0.61	0.60	0.52	0.44	0.54	1.14	×			
7.88	0.56	0.55	0.50	0.44	0.42	0.70	×			
11.91	0.51	0.50	0.48	0.44	0.38	0.47	1.13			
18.00	0.48	0.47	0.45	0.42	0.37	0.37	0.68			

In Table 3.1 and Table 3.4,  $t_{TCPs}$  values (shown by 'HSPICE') of  $C_l$ ,  $T_R$  which are out of region of validity for (4.1) and (4.2), will be extracted by HSPICE simulations. Table 3.2 and Table 3.5 shows the  $t_{TCPs}$  values obtained using conventional HSPICE simulations. Whereas Table 3.3 and 3.6 shows percentage error in LUT generated by proposed models with respect to fully HSPICE generated ECSM LUT of  $TCP_{60\%}$  and  $TCP_{90\%}$  for CMOS inverter. For inverter standard cells having a different size, we use the relationships of  $K_1$ ,  $K_2$ ,  $K_3$  and  $A_1$ ,  $A_2$  with  $W_n$  (discussed in Section 3.3) to re-generate TCP LUTs as discussed above. Thus, for these cells with a different size, we need not extract the model's

$\mathbf{C}_{l}\left(\mathbf{fF}\right)$	$\mathbf{T_{R}}\left(\mathbf{ps} ight)$								
	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	HSPICE	HSPICE	8.48	13.54	22.21	37.61	66.06		
2.28	HSPICE	HSPICE	9.88	15.63	25.30	42.20	72.87		
3.45	HSPICE	HSPICE	HSPICE	18.19	29.10	47.84	81.23		
5.22	HSPICE	HSPICE	HSPICE	21.34	33.77	54.77	91.51		
7.88	HSPICE	HSPICE	HSPICE	HSPICE	39.51	63.28	104.15		
11.91	HSPICE	HSPICE	HSPICE	HSPICE	46.57	73.76	119.68		
18.00	HSPICE	HSPICE	HSPICE	HSPICE	HSPICE	86.63	138.78		

Table 3.4: LUT of  $TCP_{90\%}$  for minimum size CMOS inverter using our Region II model.

coefficients using simulations.

Table 3.5: LUT of  $TCP_{90\%}$  for minimum size CMOS inverter obtained using HSPICE simulations.

$C_{l}(\mathbf{fF})$	$\mathbf{T_{R}}\left( \mathbf{ps} ight)$								
$\mathbf{U}_{1}(\mathbf{I}\mathbf{r})$	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	5.05	6.26	8.70	13.86	22.25	37.20	64.86		
2.28	6.40	7.62	9.10	15.79	25.19	41.65	71.51		
3.45	8.45	9.66	12.34	18.21	28.84	47.14	79.79		
5.22	11.54	12.75	15.42	21.33	33.34	53.89	89.99		
7.88	16.2	17.42	20.09	25.98	38.91	62.20	102.50		
11.91	23.24	24.46	27.13	33.03	46.04	72.45	117.84		
18.00	33.88	35.10	37.77	43.67	56.65	85.12	136.67		

Table 3.6: Percentage error in proposed model's LUT with respect to fully HSPICE generated ECSM LUT of  $TCP_{90\%}$  for CMOS inverter. Entries shown by '×' correspond to the values obtained from HSPICE simulations (not through our models).

$\mathbf{C}_{l}\left(\mathbf{fF}\right)$	$\mathbf{T_{R}}\left(\mathbf{ps} ight)$								
	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	×	×	2.50	2.31	0.18	1.10	1.85		
2.28	×	×	2.40	1.01	0.44	1.32	1.90		
3.45	×	×	×	0.11	0.90	1.48	1.80		
5.22	×	×	×	0.05	1.29	1.63	1.69		
7.88	×	×	×	×	1.54	1.74	1.61		
11.91	×	×	×	×	1.15	1.81	1.56		
18.00	×	×	×	×	×	1.77	1.54		

Table 3.7 shows the percentage saving in HSPICE simulations using our method of generating LUTs explained above. We find that the values of  $t_{TCPs}$  in our LUTs differ by a maximum of 2.5% from those in fully HSPICE generated conventional LUTs. In Table 3.7, we see a 50% saving in required number of HSPICE simulations for  $TCP_{90\%}$ . Therefore, we observe that standard cell characterization can be done with a significantly lesser number

		Number of	matrix elements obtained using	
TCPs	LUT's size	Proposed	HSPICE	% saving
		model		
	$7 \times 7$	40	9	81.63
$TCP_{60\%}$	8×8	52	12	81.25
	$9 \times 9$	65	16	80.25
	$7 \times 7$	26	23	53.06
$TCP_{90\%}$	8×8	32	32	50.00
	$9 \times 9$	42	39	51.85

Table 3.7: Percentage saving in HSPICE simulation for ECSM characterization using our models.

of HSPICE simulations (approximately 50% reduction).

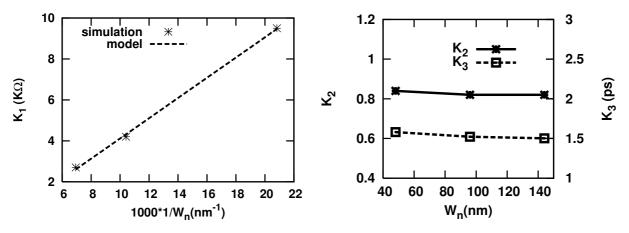


Figure 3.10: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with  $W_n$  at 22nm CMOS technology node.

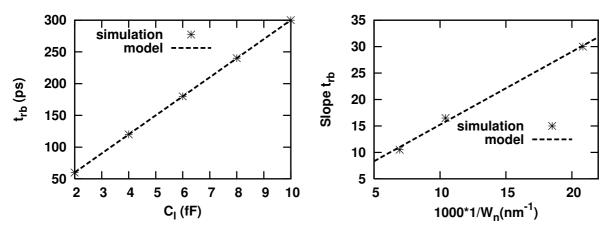


Figure 3.11:  $S_{trb}$  variation with  $W_n$  at 22nm CMOS technology node.

# 3.5 Impact of technology scaling on timing models

For a timing model to be used in standard cell characterization, it should be valid as well as accurate with respect to technology scaling. In this section, we show that our proposed models remain valid with technology scaling while maintaining its accuracy. For validation, we perform our analysis at 22nm CMOS technology node.

We verified Observation 1-4 with HSPICE 22nm BSIM PTM as shown in Fig. 3.10 and 3.11. The  $t_{TCP}$  model given by (4.1) for Region I has thus been verified using HSPICE simulated data for  $TCP_{60\%}$ . We verified Observation 5-7 with HSPICE 22nm BSIM PTM as shown in Fig. 3.12 and 3.13. The  $t_{TCP}$  model given by (4.1) for Region II has thus been verified using HSPICE simulated data for  $TCP_{90\%}$ .

### 3.6 Summary

In this chapter, we proposed models for  $t_{TCPs}$  of output voltage transition for standard cell CMOS inverter. The  $t_{TCP}$  values are derived in terms of  $T_R$  and  $C_l$ . We also derived the region of validity of these models in  $T_R$ ,  $C_l$  space. The relationship between cell size and model coefficients are also derived. Further, we derived the relationship of model coefficients with the technology scaling. The proposed model are in good agreement with HSPICE simulations with a maximum error of 2.5%. We later used these models to reduce the number of HSPICE simulations by about half in ECSM characterization of standard cell CMOS inverter.

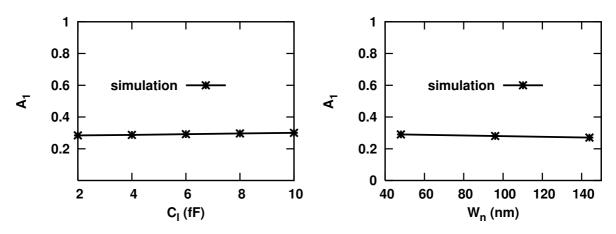


Figure 3.12: Variation of  $A_1$  with  $C_l$  and  $W_n$  at 22nm CMOS technology node.

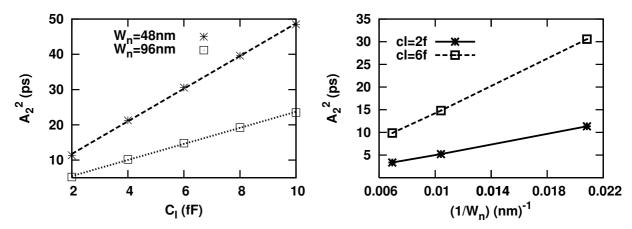


Figure 3.13: Variation of  $A_2$  with  $C_l$  and  $\frac{1}{W_n}$  as predicted by (4.7) at 22nm CMOS technology node.

# Chapter 4

# Efficient ECSM Characterization of CMOS Inverter Standard Cell Considering PVT Variations

# 4.1 Overview

In the previous chapter, we discussed our proposed timing models and its region of validity for efficient characterization of CMOS inverter standard cell. In this chapter, we show that our proposed models remain valid with voltage, temperature and stress variability. We derive relationships of variation of our model coefficients and regions of validity with cell size in mechanical stress enabled CMOS technologies, considering cell layout parameters. We also derive relationships of our model coefficients with on-chip supply voltage and temperature variations. We use these relationships in reducing number of HSPICE simulations in ECSM re-characterization significantly. We show the results of  $t_{TCP60\%}$  as a representative of  $t_{TCP}$  in Region I and  $t_{TCP90\%}$  as a representative of  $t_{TCP}$  in Region II.

The chapter is organized as follows. In Section 6.2, we describe our simulation setup. In Section 4.3, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and NF for two different regions in stress enabled technologies. In Section 4.4, we derive the relationship  $t_{TCPs}$ with  $T_R$ ,  $C_l$  and temperature (T) for two different regions. In Section 4.5, we derive the relationship  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and supply voltage ( $V_{dd}$ ) for two different regions.

### 4.2 Simulation Setup

In this chapter, we use the same simulation setup for standard cell CMOS inverter, as we used in previous chapter. To account for voltage variability, we considered a  $\pm 10\%$  variation in nominal supply voltage. For temperature variability, we vary the temperature range from 298K to 423K. For stress variability, we consider the variation of device channel's mechanical stress as a function of the number of fingers (NF) of device sharing an active

area in an inverter's layout. This is because, often the size of a standard cell is increased by increasing NF, the consequent variation in channel mechanical stress is important. Stress induced in the channel of pMOS (nMOS) using various sources like Compressive/Tensile Etch Stop Liner (c/t-ESL), embedded SiGe (eSiGe) and Stress Memorization Technique (SMT) [52] have been considered in this work.

To emulate the effect of stress in our HSPICE simulations, we model the value of PTM parameters MULU0 (mobility multiplier) and DELVT0 (threshold voltage shift) as a function of the nMOS (pMOS) device's NF in layout. The values of MULU0 and DELVT0 are calculated as a function of average channel stress for a given value of NF, as we explained in [89, 90]. The procedure is as follows:

The device structure, doping profile and I-V characteristics of nMOS (pMOS) devices in our Sentaurus TCAD simulation setup are well calibrated to match those corresponding to an equivalent PTM device model. The value of average channel stress is obtained using TCAD process simulations corresponding to the device structure and NF. Values of MULU0 and DELVT0 for a given value of NF in HSPICE simulation are obtained from TCAD average channel stress value. In Section 4.3 (which address stress induced variability), we use HSPICE simulations at 45nm CMOS technology node. This is because we have calibrated our 45nm BSIM PTM model with our Sentaurus TCAD simulation setup, which considers mechanical stress. In Section 4.4 and 4.5, we verify our models for temperature and supply voltage variability with HSPICE simulations at 32nm CMOS technology node. In this way, we have also verified the validity of our  $t_{TCP}$  models at 45nm CMOS technology node.

# 4.3 TCP models considering stress variability for CMOS inverter standard cell

To circumvent scaling related issues such as large-off state leakage current and mobility degradation due to high channel doping, stress engineering techniques are being used in sub 90nm CMOS technologies [52, 91]. In standard cells, the size of a cell is typically increased by increasing the number of device fingers in a layout since the distance between power supply and ground line is fixed. However, this increase in NF (which represents cell size) leads to a change in average value of stress in the channel [89]. This leads to a stress induced performance variability of standard cells as their size is changed<sup>1</sup>. Therefore, the drive capability of strain-engineered (MFGSs) does not increase linearly with the NFs.

In this section, we derive the change in coefficients in (4.1) and (4.2) as a function of NF in a stress enabled 45nm CMOS technology. First, we recall these models equation derived in previous chapter as:.

$$t_{TCP_{60\%}} = K_1 C_l + K_2 T_R + K_3 \tag{4.1}$$

<sup>&</sup>lt;sup>1</sup>For example, an inverter standard cell FO4 delay would change with its size, which is contrary to conventional expectation

$$t_{TCP90\%} = A_1 T_R + A_2 \sqrt{T_R}$$
(4.2)

Where,

$$K_1 = \frac{(V_{dd} - V_{dsat})}{I_{ON}} \tag{4.3}$$

$$K_2 = \left[0.8 - \frac{S_T}{I_{ON}}\right] \tag{4.4}$$

$$K_3 = C_p \left[ \frac{(V_{dd} - V_{dsat})}{I_{ON}} \right]$$
(4.5)

$$A_1 = \left(\frac{V_{th}}{V_{dd}}\right) \tag{4.6}$$

$$A_2 = \left(\sqrt{\frac{0.2(C_l + C_p)}{\beta_s}}\right) \tag{4.7}$$

The values of  $I_{ON}$ ,  $I_{lin}$  and  $V_{dsat}$  used in this model are derived from alpha power law model [9] such as:

$$I_{ON} = v_{sat} W_n P_s \left( V_{gs} - V_{th} \right) \tag{4.8}$$

$$I_{lin} = \mu \frac{W_n}{L_{eff}} P_l \left( V_{gs} - V_{th} \right) V_{ds}$$

$$\tag{4.9}$$

$$V_{dsat} = \frac{v_{sat} P_s (V_{gs} - V_{th}) L_{eff}}{\mu P_l}$$
(4.10)

Where,  $P_s$ ,  $P_l$  are technology dependent parameters,  $v_{sat}$  is the saturation velocity and  $\mu$  is the mobility of the nMOS device. We also derive the change in region of validity in  $T_R$ ,  $C_l$  space with inverter standard cell size (*i.e.*, NF). As discussed in Section 6.2, the effect of change in channel stress as a function of NF is captured by PTM parameters MULU0 and DELVT0 in our HSPICE simulations.

Now we derive coefficients of (4.1) and (4.2) as a function of NF. We use a set of empirical equations suggested in [89, 92, 93], to relate device level electrical parameters with stress. These equations are:

$$\mu(\sigma) = [P_1 \sigma(NF) + 1] \mu_0 \tag{4.11}$$

$$v_{sat} (\sigma) = [P_1 \sigma(NF) + 1] v_{sat}$$

$$(4.12)$$

$$I_{ON}\left(\sigma\right) = \left[P_1 P_2 \sigma\left(NF\right) + 1\right] I_{ON} \tag{4.13}$$

$$V_{th} (\sigma) = [V_{th} + P_3 \sigma (NF)]$$

$$(4.14)$$

Where,  $\mu(\sigma)$ ,  $v_{sat}(\sigma)$ ,  $I_{ON}(\sigma)$ ,  $V_{th}(\sigma)$  are stress dependent mobility, saturation velocity, drive current and threshold voltage parameters respectively. Whereas,  $\mu_0$ ,  $v_{sat}$ ,  $I_{ON}$ ,  $V_{th}$ are unstressed parameters and  $P_1$  is the piezoresistive coefficient.  $P_2$  and  $P_3$  are technology dependent coefficients extracted by fitting the above equations into HSPICE simulated I-V data, as discussed in [89, 90, 93]. Here  $\sigma(NF)$  represents the average stress in the fingers in MFGSs. As discussed in [89], a relation between this average stress and NF is:

$$\frac{\sigma\left(NF\right)}{\sigma_{ref}\left(NF=1\right)} = M_1 + \frac{M_2}{NF + M_3} \tag{4.15}$$

In (5.25),  $M_1$ ,  $M_2$ ,  $M_3$  are fitting parameters specific to given technology node where,  $M_1$  denotes  $\sigma (NF \to \infty) / \sigma (NF = 1)$ , while  $M_2$  and  $M_3$  control the rate of change of stress as NF is increased (discussed in detail in [89]).

#### 4.3.1 Impact of stress induced variability in Region I

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and NF for Region I in stress enabled technologies. In (4.3)-(4.5),  $\mu$ ,  $v_{sat}$ ,  $I_{ON}$ , and  $V_{th}$  are now given by (5.21)-(5.24). Again we take  $t_{TCP_{60\%}}$  as a representative of all TCPs in Region I and derive a model for  $t_{TCP_{60\%}}$  considering the impact of channel stress, as it lies in Region I. In this derivation, we assume that  $(V_{dd} - V_{th})$  is independent of NF. This is justified since  $V_{th}$  is much smaller than  $V_{dd}$ . From (4.3)-(4.5) and (5.21)-(5.25), we obtain :

$$K_1 = (NF + M_3) \left(\frac{D_1}{NF + D_2}\right)$$
 (4.16)

Where,

$$D_1 = \frac{(V_{dd} - V_{dsat})}{((M_1 P_1 P_2 + 1)I_{ON})}$$
(4.17)

$$D_2 = \left(M_3 + \frac{M_2 P_1 P_2}{(M_1 P_1 P_2 + 1)}\right) \tag{4.18}$$

We observe that (5.26) fits well with HSPICE simulated data as shown in Fig. 5.19. In these HSPICE simulations, MULU0 and DELVT0 vary with NF in accordance with (5.25) (*i.e.* the PTM model incorporates channel stress variability effects).

Likewise, solving (4.5), we found the relation between  $K_3$  and NF as:

$$K_{3} = C_{p} K_{1} = C_{p} \left[ (NF + M_{3}) \left( \frac{D_{1}}{NF + D_{2}} \right) \right]$$
(4.19)

Where,  $C_p$  is parasitic capacitance (due to gate-drain overlap, drain-bulk junction capacitance etc.) which is linearly related to NF in MFGS. This can be seen in the inset of Fig. 5.19. We observe that (5.29) fits well with HSPICE simulated data as shown in Fig.

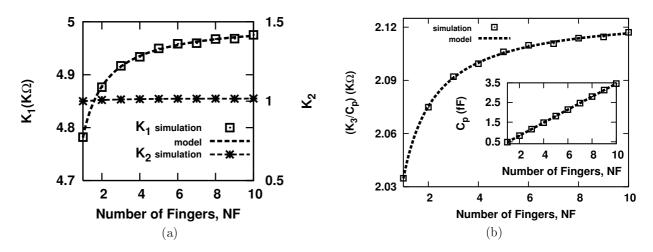


Figure 4.1:  $K_1$ ,  $K_2$  and  $K_3$  as a function of NF (which also represents to channel stress).

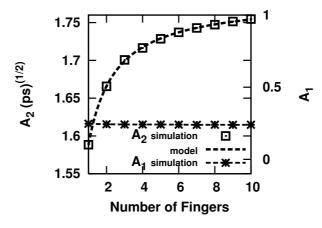


Figure 4.2:  $A_1$  and  $A_2$  as a function of NF.

5.19. Thereafter, we observe that  $K_2$  is independent of NF (because  $S_T$  and  $I_{ON}$  are both proportional to NF) as shown in Fig. 5.19. In Fig. 5.19,  $K_2$  is normalized with value of  $K_2$ at NF = 1. In this subsection, we observe that our model in Region I is valid with respect to stress variability.

#### 4.3.2 Impact of stress induced variability in Region II

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and NF for Region II in stress enabled technologies. In (4.6) and (4.7),  $v_{sat}$ ,  $V_{th}$  are now given by (5.22) and (5.24). Again we take  $t_{TCP_{90\%}}$  as a representative of all TCPs in Region II and derive a model for  $t_{TCP_{90\%}}$  considering the impact of channel stress, as it lies in Region II. From (4.6), (4.7) and (5.22), (5.24), (5.25), we obtain that  $A_1$  is independent of  $V_{th}(\sigma)$ . We have verified through simulations that variation in  $V_{th}(\sigma)$  with NF is very small (in our TCAD calibrated simulations variation in  $V_{th}(\sigma)$  with NF is less than 3%). This small variation in  $V_{th}(\sigma)$  has also been reported in [94]. Therefore,  $A_1$  is independent of  $\sigma(NF)$  as shown in Fig. 4.2.

We find the relationship between  $A_2$  and NF as:

$$A_2 = \sqrt{\left(\frac{S_1(NF + M_3)}{(NF + S_2)}\right)}$$
(4.20)

Where,

$$S_1 = \left(\frac{0.2(C_l + C_p)}{W_n P_s \, v_{sat} \, (M_1 P_1 + 1)}\right) \tag{4.21}$$

$$S_2 = \left(\frac{1}{M_3 + \frac{P_1 M_2}{(M_1 P_1 + 1)}}\right) \tag{4.22}$$

We observe that (5.31) fits well on our stress aware HSPICE simulation data as shown in Fig. 4.2. In this subsection, we observe that our model in Region II is valid with respect to stress variability.

#### 4.3.3 Efficient stress aware ECSM characterization

In this subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of inverter standard cells would need significantly lesser number of HSPICE simulations. We generated 7 × 7 LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$  values for different inverter cell sizes (represented by NF). Conventionally, this would require 343 HSPICE simulations for cell sizes corresponding to NF=1 to 7. However, using our models only 88 HSPICE simulations (including simulations to extract the model coefficients) were needed to generate the same LUT.

For computing the remaining values of  $t_{TCP60\%}$ , we used our model. In this way, we saved 255 HSPICE simulations to generate the 7 × 7 LUTs for NF=1 to 7. Therefore, proposed model can be used to save  $\simeq 74\%$  HSPICE simulations for all TCPs in Region I. Likewise, to generate the 7 × 7 LUTs for NF=1 to 7 in Region II, the proposed model can be used to save  $\simeq 45\%$  HSPICE simulations for all TCPs in Region II. We then compare the LUTs for  $t_{TCPs}$  generated using our above approach with conventional fully HSPICE generated ECSM LUTs. We observe that the values of our LUT's  $t_{TCPs}$  are different from the conventional LUT by a maximum of 2.5%.

# 4.4 TCP models considering temperature variability for CMOS inverter standard cell

In present day CMOS technologies one of the major sources of circuit performance variability is on-chip temperature variation. It can cause significant change in electron and hole mobility as well as in threshold voltage [95]. An increase in temperature results in lowering the mobility thereby reducing ON current which in turn increases the delay values. Therefore, a re-characterization of standard cells for several values of temperature becomes necessary that requires a huge computational effort and time.

In this section, we derive the change in coefficients in (4.1) and (4.2) as a function

of temperature at 32nm CMOS technology. In this work, we take a realistic range of temperature variation due to on-chip heating from 298K (room temperature) to 423K. In this work, we use an empirical expression suggested in [23, 29], to consider the impact of temperature variability on carrier mobilities. The expression is given as:

$$\mu(T) = \mu(T_0) \left(\frac{T}{T_0}\right)^{-\theta}$$
(4.23)

Where,  $\mu(T)$  is the temperature dependence of mobility, T is the temperature,  $T_0$  is the nominal temperature *i.e.* 298 K and  $\theta$  is technology dependent temperature coefficient. For our PTM CMOS technology, we extract the value of  $\theta = 2.3$  by maximum transconductance  $(g_m)$  method. We use the empirical relation (given in [29]) between carrier saturation velocity and temperature as:

$$v_{sat}(T) = v_{sat}(T_0) - \eta (T - T_0)$$
(4.24)

Where,  $v_{sat}(T)$  is the temperature dependence of saturation velocity and  $\eta$  is the temperature coefficient. The threshold voltage of devices also gets affected by an increase in temperature due to change in fermi level location and band gap energy [96]. In [96], the temperature dependence of threshold voltage is given by:

$$V_{th}(T) = V_{th}(T_0) - \kappa (T - T_0)$$
(4.25)

Where,  $\kappa$  is the temperature dependence coefficient of threshold voltage. The value of  $\eta$  and  $\kappa$  can be extracted from simulated HSPICE *I-V* data for a given CMOS technology. We verified the validity of (5.34), (5.35) and (5.36) using Sentaurus TCAD device simulations. In TCAD simulations, we use 25nm drawn gate length nMOS and pMOS devices. We now discuss our approach for deriving temperature variation aware  $t_{TCP}$  models.

#### 4.4.1 Impact of temperature variability in Region I

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and temperature T for Region I of CMOS inverter standard cell. In (4.3)-(4.5),  $v_{sat}$ ,  $\mu$  and  $V_{th}$  are now given by (5.34), (5.35) and (5.36). Again we take  $t_{TCP_{60\%}}$  as a representative of all TCPs in Region I and derive a model for  $t_{TCP_{60\%}}$  considering the impact of temperature variability, as it lies in Region I. In this derivation, we assume that  $(V_{dd} - V_{th})$  is independent of T. This is justified since  $V_{th}$  is much smaller than  $V_{dd}$ . From (4.3)-(4.5) and (5.34), (5.35), we obtain :

$$K_1 = \left(R_1 T^{2.3} + R_2 T + R_3\right) \tag{4.26}$$

Where,

$$R_{1} = \left[ \frac{\left(\frac{L_{eff}}{W_{n}P_{l}}\right)}{\left(\mu(T_{0})\left(\frac{1}{T_{0}}\right)^{-2.3}\right)} \right]$$
(4.27)

$$R_{2} = \left[\frac{V_{dd}}{W_{n} P_{s} \left(V_{gs} - V_{th}\right)} \frac{\eta}{v_{sat} \left(T_{0}\right)^{2}}\right]$$
(4.28)

$$R_{3} = \left[\frac{V_{dd}}{W_{n} P_{s} \left(V_{gs} - V_{th}\right)} \frac{\left(1 - \eta T_{0}\right)}{v_{sat} \left(T_{0}\right)^{2}}\right]$$
(4.29)

We observe that (5.37) fits well on HSPICE simulated data as shown in Fig. 4.3. Likewise, solving (4.5), we find the relation between  $K_3$  and T as:

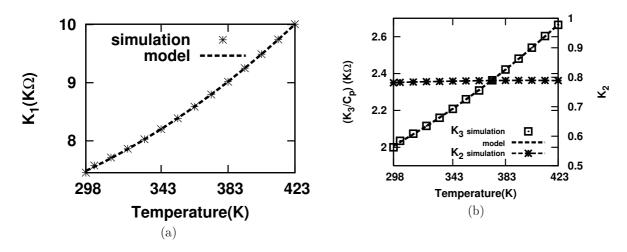


Figure 4.3: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with temperature.

$$K_3 = C_p K_1 = C_p \left( R_1 T^{2.3} + R_2 T + R_3 \right)$$
(4.30)

Where,  $C_p$  is parasitic capacitance. We observe using HSPICE simulations that change in  $C_p$  with T varying from 298K to 423K is negligibly small. We observe that (5.41) fits well with HSPICE simulated data as shown in Fig. 4.3. Thereafter, solving (4.4), we observe that  $K_2$  is independent of T as shown in Fig. 4.3 (because  $S_T$  and  $I_{ON}$  both are the function of T). In this subsection, we observe that our model in Region I is valid with respect to temperature variability.

#### 4.4.2 Impact of temperature variability in Region II

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and T for Region II of CMOS inverter standard cell. In (4.6), (4.7)  $v_{sat}$  and  $V_{th}$  are now given by (5.35) and (5.36). Again we take  $t_{TCP_{90\%}}$  as a representative of all TCPs in Region II and derive a model for  $t_{TCP_{90\%}}$  considering the impact of temperature variability as it lies in Region II.

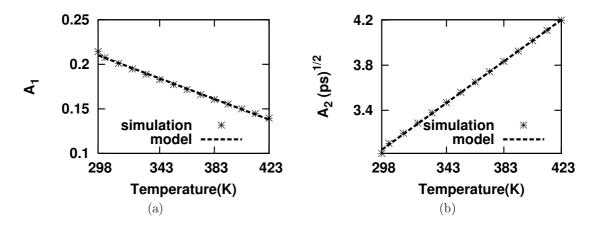


Figure 4.4: Variation of  $A_1$  and  $A_2$  with temperature.

From (4.6), we observe that  $A_1$  is dependent on  $V_{th}$  only. From (5.36), we expect  $A_1$  to reduce linearly with T, which we verify through HSPICE simulations in Fig. 4.4.

We obtain the relationship between  $A_2$  and T as:

$$A_{2} = \left[ \left( \sqrt{\frac{0.2(C_{l} + C_{p})}{W_{n}P_{s} v_{sat}(T_{0})}} \right) \left( 1 + \frac{\eta \left(T - T_{0}\right)}{2 v_{sat}(T_{0})} \right) \right]$$
(4.31)

We observe that (5.42) fits well on our HSPICE simulation data with temperature variability as shown in Fig. 4.4. In this subsection, we observe that our model in Region II is valid with respect to temperature variability.

# 4.4.3 Efficient temperature variation aware ECSM characterization

In this subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of inverter standard cells would need significantly lesser number of HSPICE simulations. We generated 7 × 7 LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$  values for different temperature values . Conventionally, this would require 343 HSPICE simulations for 7 different values of temperature T from 298K to 423K. However, using our models only 77 HSPICE simulations (including simulations to extract the model coefficients) were required to generate the same LUT. For computing the remaining values of  $t_{TCP60\%}$ , we use our models. In this way, we saved 266 HSPICE simulations to generate the 7 × 7 LUTs for T = 298K to 423K. Therefore, proposed model can be used to save  $\simeq$  78% HSPICE simulations for all TCPs in Region I.

Likewise, to generate the  $7 \times 7$  LUT for 7 different values of temperature T from 298K to 423K in Region II, the proposed model can be used to save  $\simeq 50\%$  HSPICE simulations for all TCPs in Region II. We then compare the LUTs for  $t_{TCPs}$  generated using our above approach with conventional fully HSPICE generated ECSM LUTs. We observe that the values of our LUT's  $t_{TCPs}$  are different from the conventional LUT by a maximum of 2.5%.

# 4.5 TCP models considering supply voltage variability for CMOS inverter standard cell

At nanometer range technologies, power supply noise dominates due to a significant increase in the ratio of peak noise voltage to the ideal supply voltage [97]. This effect becomes more pronounced with technology scaling. Problems with power supply voltage level drop in the on-chip power distribution network also becomes pronounced at these technology nodes [98]. As a result, voltage fluctuation of  $\pm 10\%$  from the nominal power supply levels is considered acceptable [98]. This results in re-characterization of standard cell libraries at several values of power supply voltages.

In this section, we derive a power supply voltage variation aware  $t_{TCP}$  models which we use to reduce the re-characterization effort significantly. We consider the  $\pm 10\%$  change in power supply voltage  $(V_{dd})$  from the its nominal value of  $V_{dd} = 0.9V$ .

#### 4.5.1 Impact of supply voltage variability in Region I

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and  $V_{dd}$  for Region I of CMOS inverter standard cell. Again we take  $t_{TCP_{60\%}}$  as a representative of all TCPs in Region I and derive a model for  $t_{TCP_{60\%}}$  considering the impact of supply voltage variability, as it lies in Region I. From (4.3), we obtain the expression for  $K_1$  as :

$$K_{1} = \frac{V_{dd}}{v_{sat} W_{n} P_{s} \left(V_{dd} - V_{th}\right)} - \frac{L_{eff}}{W_{n} P_{l} \mu}$$
(4.32)

We observe that (4.32) fits well with HSPICE simulated data as shown in Fig. 5.23. We now discuss the variation of  $K_3$  with  $V_{dd}$ . In (4.5),  $C_p$  includes the voltage dependent junction capacitance which is given by [94] as:

$$C_j(V) = \frac{A.C_{j0}}{\sqrt{\left(1 + \frac{V}{\phi_0}\right)}}$$
(4.33)

Where, A indicates the junction area,  $C_{j0}$  is zero-bias junction capacitance per unit area, V is the reverse bias voltage and  $\phi_0$  is built-in potential. Using (4.5) and 4.33, we obtain the expression for  $K_3$  as :

$$K_{3} = \left(\frac{A.C_{j0}}{\sqrt{\left(1 + \frac{V}{\phi_{0}}\right)}}\right) \left[\frac{V_{dd}}{v_{sat} W_{n} P_{s} \left(V_{dd} - V_{th}\right)} - \frac{L_{eff}}{W_{n} P_{l} \mu}\right]$$
(4.34)

We observe that (4.34) fits well with HSPICE simulated data as shown in Fig. 5.23. Using (4.4) and (4.8), the expression for  $K_2$  will get reduced to :

$$K_2 = \frac{(a_7 * V_{dd} + a_8)}{(V_{dd} + a_9)} \tag{4.35}$$

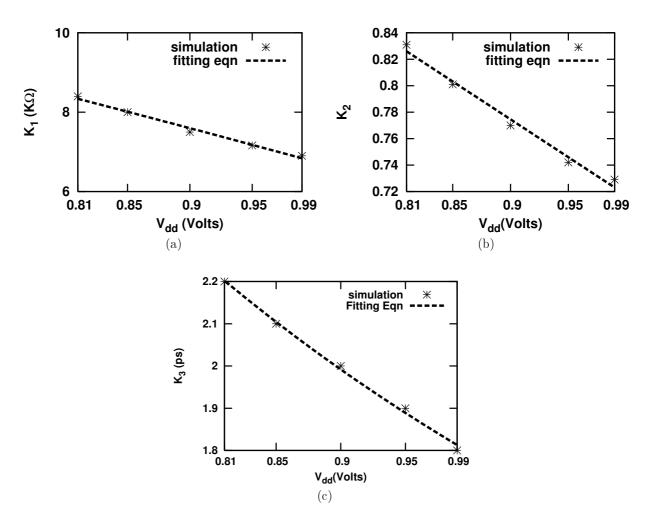


Figure 4.5: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with supply voltage.

Where,  $a_7 = 0.3$ ,  $a_8 = 0.2V_{th}$  and  $a_9 = -V_{th}$ . We observe that (4.35) fits well with HSPICE simulated data as shown in Fig. 5.23. In this subsection, we observe that our model in Region I is valid with respect to supply voltage variability.

#### 4.5.2 Impact of supply voltage variability in Region II

In this subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and  $V_{dd}$  for Region II of CMOS inverter standard cell. Again we take  $t_{TCP_{90\%}}$  as a representative of all TCPs in Region II and derive a model for  $t_{TCP_{90\%}}$  considering the impact of supply voltage variability, as it lies in Region II. In (4.6),  $A_1$  is inversely proportional to supply voltage which is also verified through HSPICE simulations as shown in Fig. 4.6.

In (4.7), we can see that only  $C_p$  is supply voltage dependent term which decreases with supply voltage. Therefore, expression for  $A_2$  will get reduced to:

$$A_2^2 = b_1 + \frac{b_2}{\sqrt{(b_3 + V_{dd})}} \tag{4.36}$$

Where,

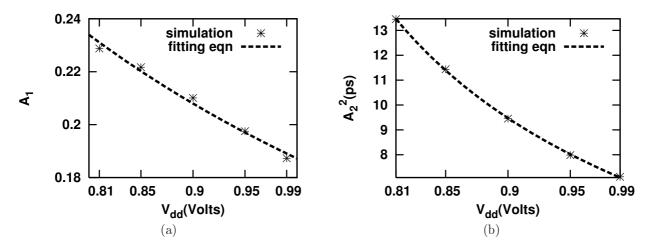


Figure 4.6: Variation of  $A_1$  and  $A_2$  with supply voltage.

$$b_1 = \frac{0.2C_l}{W_n P_s \nu_{sat}} \tag{4.37}$$

$$b_2 = \frac{0.2}{W_n P_s \nu_{sat}} \left( A.C_{j0} \sqrt{\phi_0} \right) \tag{4.38}$$

and

$$b_3 = \phi_0 \tag{4.39}$$

We observe that (4.36) fits well with HSPICE simulated data as shown in Fig. 4.6. In this subsection, we observe that our model in Region II is valid with respect to voltage variability.

# 4.5.3 Efficient supply voltage variation aware ECSM characterization

In this subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of inverter standard cells would need significantly lesser number of HSPICE simulations. We generated 7 × 7 LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$  values for different supply voltages. Conventionally, this would require 343 HSPICE simulations for 7 different values of supply voltage  $V_{dd}$  from 0.81V to 0.99V. However, using our models only 84 HSPICE simulations (including simulations to extract the model coefficients) were required to generate the same LUT. For computing the remaining values of  $t_{TCP60\%}$ , we used our model. In this way, we saved 259 HSPICE simulations to generate the 7 × 7 LUTs for  $V_{dd} = 0.81V$  to 0.99V. Therefore, the proposed model can be used to save  $\simeq 76\%$  HSPICE simulations for all TCPs in Region I.

Likewise, to generate the 7×7 LUTs for 7 different values of supply voltage  $V_{dd}$  from 0.81V to 0.99V in Region II, the proposed model can be used to save  $\simeq 50\%$  HSPICE simulations for all TCPs in Region II. We then compare the LUTs for  $t_{TCPs}$  generated using our above

approach with conventional fully HSPICE generated ECSM LUTs. We observe that the values of our LUT's  $t_{TCPs}$  are different from the conventional LUT by a maximum of 2.5%.

# 4.6 Summary

In this chapter, we derived the relationship of model coefficients with voltage, temperature and stress variability. We derived the relationships of model coefficients and their regions of validity with cell size in mechanical stress enabled CMOS technologies, considering cell layout parameters. We also derived the relationships of model coefficients with on-chip supply voltage and temperature variations. We later used these relationships to reduce the number of HSPICE simulations by nearly half for standard cell CMOS inverter in ECSM re-characterization significantly. We observed that the proposed models are in good agreement with HSPICE simulations with a maximum error of 2.5%.

# Chapter 5

# Timing model for 2-input NAND gate standard cell considering PVT variation

### 5.1 Overview

This chapter focuses on modeling of  $t_{TCPs}$  as a function of  $T_R$  and  $C_l$  for a 2-input CMOS NAND gate. Further, the region of validity of the model in  $T_R$ ,  $C_l$  space is derived. We then derive the relationships of the model coefficients with the NAND gate size,  $V_{dd}$ and temperature. We also consider layout dependent effects due to mechanical stress in deriving these relationships.

The chapter is organized as follows. In section 6.2, we describe our simulation setup. In Section 5.3, based on the switching of the input of series stack of 2-input NAND gate, we categorize the timing models into two cases. In this chapter, Case 1 corresponds to the switching of the upper transistor of the series stack, whereas, Case 2 corresponds to the switching of the lower transistor of the series stack. In Section 5.4 and 5.6, we derive the  $t_{TCP}$  models and their region of validity as a function of  $T_R$  and  $C_l$  for Case 1 and 2, respectively. Later, we use these models to reduce the number of HSPICE simulations for ECSM characterization. In Section 5.5 and 5.7, we derive the relationships of the model coefficients with mechanical stress, temperature and  $V_{dd}$  variability for Case 1 and 2, respectively.

## 5.2 Simulation Setup

In this work, we use 32nm Predictive Technology device Model (PTM)<sup>1</sup> for HSPICE simulations. The widths of nMOS and pMOS devices are chosen to obtain equal output rising and falling transition using the procedure discussed in  $[22](\frac{W_p}{W_n} = \frac{120nm}{96nm}^2)$ . The channel lengths are kept at their minimum allowed value. Since width ratios of all transistors for standard cell of a given type (say, 2-input NAND gate) is fixed, the value of  $W_n$  also represents the cell size. Throughout this work, we consider the case of rising input transition as

<sup>&</sup>lt;sup>1</sup>Obtained from http://ptm.asu.edu/

 $<sup>^{2}</sup>W_{p}$ : pMOS device width;  $W_{n}$ : nMOS device width

shown in Fig. 5.1; The case of falling input transition can be handled in similar manner. In Fig. 5.1,  $C_{out}$  represents the sum of the parasitic capacitance between node 'Out' and 'gnd' and the external load capacitance  $(C_l)$  appearing at node 'out'. The symbol  $C'_X$  represents the parasitic capacitance between node 'X' and 'gnd'.

To emulate the effect of stress in our HSPICE simulations, we model the value of PTM parameters MULU0 (mobility multiplier) and DELVT0 (threshold voltage shift) as a function of the nMOS (pMOS) device's NF in layout. The values of MULU0 and DELVT0 are calculated as a function of average channel stress for a given value of NF, as we explained in [89, 90]. To account for voltage variability, we considered a  $\pm 10\%$  variation in nominal supply voltage. For temperature variability, we vary the temperature range from 298K to 423K. For stress variability, we consider the variation of device channel mechanical stress as a function of NF in inverter layout (discussed in detail in the simulation setup of Chapter 4).

# 5.3 Timing model for 2-input NAND gate standard cell

This chapter focuses on modeling of timing values of TCPs as a function of  $T_R$  and  $C_l$  for 2-input CMOS NAND gate. The NAND gate ECSM characterization done for the following two cases:

- Case 1: When upper nMOS transistor in series-stack switches
- Case 2: When lower nMOS transistor in series-stack switches

In this work, we derive physics based models for TCPs as a function of  $T_R$  and  $C_l$ . We consider the intermediate node voltage transition of the series stack of the 2-input NAND gate. The region of validity of the model in both cases (Case 1 and 2) is derived. The relationship between cell size and model coefficient is also derived. Further, we derive the relationships of model coefficients with mechanical induced stress as a function of the NF, temperature and supply voltage variability, for both the cases.

### 5.4 Case 1: Derivation and Validation of $t_{TCP}$ model

In this section, we derive the  $t_{TCP}$  model for the switching of the upper nMOS transistor in the series stack of 2-input NAND gate. We derive the relationship of  $t_{TCP}s$  with the  $T_R$ ,  $C_l$  and cell size. We also derive the region of validity of these models in  $T_R$ ,  $C_l$  plane. The model remains valid for the case when  $V_{out}(T_R) \ge V_{dsat}$ , where  $V_{dsat}$  is the saturation drainsource voltage  $(V_{ds})$  at which velocity saturation occurs for the NAND gate's upper nMOS device. In this derivation, we assume the  $t_{TCP}$  models for 2-input NAND gate remains same as for CMOS inverter (discussed in Chapter 3), because the lower nMOS transistor

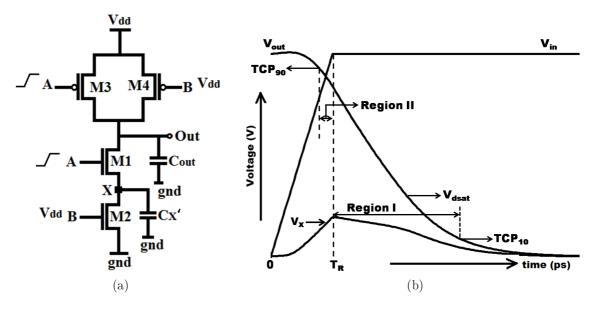


Figure 5.1: Case 1: (a) 2-input NAND gate schematic (b) its I/O waveform.

 $(M_2)$  in the series stack adds some resistance to the source of upper nMOS transistor  $(M_1)$ . In this work, we ignore the negligibly small current flowing through pMOS transistor (max. current  $\approx 3\mu A$ ). We classify the TCPs into two regions:

- Region I: When  $V_{in} = V_{dd}$  (for  $t_{TCP}s > T_R$ )
- Region II: When  $V_{in} < V_{dd}$  (for  $t_{TCP} s < T_R$ )

In this section, we derive the timing model of  $TCP_{10\%}$  in Region I and timing model of  $TCP_{90\%}$  in Region II (as shown in Fig. 5.1b).

#### 5.4.1 Derivation of the model in Region I

In this subsection, we derive the model for the NAND gate shown in Fig. 5.1a. Region I contains all the TCPs having values  $V_{TCP}$  smaller than  $V_{out}(T_R)$ , as we depict in Fig. 5.1b. In this derivation, we assume that the upper nMOS (discharging) device operates either in saturation or in linear region and lower nMOS (discharging) device always operates in linear region when  $V_{TCP} < V_{out}(T_R)$ .

To find the  $t_{TCP10\%}$  model, we first integrate the saturation current through  $M_1$  during the input transition  $V_{in-A}(t) = V_{dd}(\frac{t}{T_R})$  for  $0 \le t \le T_R$ . Then integrate the discharging current  $I_{ON}(V_{in-A} = Vdd)$  through  $M_1$ , from  $t = T_R$  to  $t = t_{TCP}$ . We equate the sum of these integrals to  $(C_l + C_p)(V_{out}(T_R) - V_{TCP})$  to obtain  $t_{TCP}$ . Here  $C_l$  is the load capacitance,  $C_p$  is the parasitic capacitance between node 'Out' and 'gnd'. If the  $V_{TCP} <$  $V_{dsat}$ , we integrate  $I_{ON}$  through  $M_1$  from  $t = T_R$  to  $t = t_{sat}$  (where  $t_{sat}$  represents the time when  $V_{out} = V_{dsat}$ ). We equate the sum of these integrals to  $(C_l + C_p)(V_{out}(T_R) - V_{dsat})$  to obtain  $t_{sat}$ . From  $t = t_{sat}$  to  $t = t_{TCP}$ , both the series stacked nMOS devices operate in linear region. These devices act as a resistance where the value of the resistance  $R_1$ and  $R_2$  can be obtained by equating  $V_{gs1} = V_{gs2} = V_{dd}$ . Therefore, the time duration from  $t_{sat}$  to  $t_{TCP}$  is proportional to time constant  $R_{eq}(C_l + C_p)$ . Where,  $R_{eq}$  represents an equivalent resistance of series stacked nMOS devices. As we discuss later in this section, for  $V_{TCP} < V_{dsat}$  the value of  $V_X$  is so low that the change in  $V_X$  during this RC discharge need not to be considered.

To determine the integral of  $I_{M1}$ , we need  $V_X$ , which is the value of the voltage at node 'X'. This is the source voltage of  $M_1$  and having a non-zero value. To determine  $V_X$ , we apply KCL at node 'X' which gives an expression as follows:

$$I_{M2} = I_{M1} + I_{C_{C1}} + I_{C'_{X}} \tag{5.1}$$

Where,  $I_{C_X}$  is the current flowing out of the parasitic capacitance (of  $M_1$  and  $M_2$ ) between node 'X' and 'gnd'.  $I_{C_{C_1}}$  is the current flowing through gate-to-source coupling capacitance of  $M_1$ , it consists of the gate-to-source overlap capacitance and a part of the gate-to-channel capacitance.  $I_{M_1}$  is saturation current flowing through  $M_1$  and  $I_{M_2}$  is linear current flowing through  $M_2$ , which is given by alpha power law model as follows [9]:

$$I_{M1} = I_{sat} = \nu_{sat} W_n P_s (V_{gs1} - V_{th1})^{\alpha}$$
(5.2)

$$I_{M2} = I_{lin} = \mu_n \frac{W_n}{L_{eff}} P_l (V_{gs2} - V_{th})^m V_{ds}$$
(5.3)

Where,  $\nu_{sat}$  is saturation velocity,  $W_n$  is width of nMOS device,  $\mu_n$  is the mobility of nMOS device and  $P_s$ ,  $P_l$  are the technology dependent parameters. In our case, we have used m and  $\alpha$  values to be 1 and verified this through HSPICE simulations. In this chapter, we use  $\beta_s = \nu_{sat} W_n P_s$  and  $\beta_l = \mu_n \frac{W_n}{L_{eff}} P_l$ . Now, we rewrite (5.1) as:

$$I_{M2} = I_{M1} - (C'_X + C_{C1})\frac{dV_X}{dt} + C_{C1}\frac{dV_{in-A}}{dt}$$
(5.4)

Where,

 $V_{in-A} = V_{dd} \left(\frac{t}{T_R}\right) \text{ for } 0 \le t \le T_R$ 

In this derivation, to simplify the expression, we are taking  $(C'_X + C_{C1}) = C_X$ . Now, we write (5.4) as:

$$\beta_l (V_{dd} - V_{th}) V_X(t) = \beta_s (V_{in-A} - V_X(t) - V_{th1}) - C_X \frac{dV_X}{dt} + C_{C1} \frac{V_{dd}}{T_R}$$
(5.5)

This equation holds true only if  $V_X(t)$  is a linear function of time. As  $M_1$  is in saturation region, therefore  $I_{M1}$  is a function of  $V_{gs1}$  only (from (5.2)). From (5.2) and (5.5), we observe that  $V_X$  follows the change in  $V_{in-A} = V_{dd} \left(\frac{t}{T_R}\right)$ . Therefore,  $C_X \frac{dV_X}{dt}$  would be a constant, we represent this constant term as  $I_X$  which is proportional to  $W_n$ .

After solving (5.5), we find the expression for  $V_X$  as:

$$V_X = \frac{\left(\beta_s \frac{V_{dd}}{T_R}\right) t}{\left[\beta_l (V_{dd} - V_{th}) + \beta_s\right]} + \frac{\left(C_{C1} \frac{V_{dd}}{T_R} - I_X - \beta_s V_{th1}\right)}{\left[\beta_l (V_{dd} - V_{th}) + \beta_s\right]}$$
(5.6)

As we discussed earlier, to find the  $t_{TCP10\%}$  we first integrate the saturation current through  $M_1$  during the input transition  $V_{in-A}(t) = V_{dd}(\frac{t}{T_R})$  for  $0 \le t \le T_R$ . Then, we integrate the discharging current  $I_{ON}(V_{in-A} = Vdd)$  through  $M_1$ , from  $t = T_R$  to  $t = t_{TCP}$ . We equate the sum of these integrals to  $(C_l + C_p)(V_{out}(T_R) - V_{TCP})$  to obtain  $t_{TCP}$ . From  $t = T_R$  to  $t_{sat}$ , the lower nMOS transistor  $(M_2)$  operates in linear region, therefore we consider  $M_2$  as a linear resistor (represented as  $R_2$ ) which gives the value of intermediate node voltage  $V_X = I_{M1}R_2$ . This  $R_2$  results in the the lowering of saturation current of  $M_1$ by a constant value that is technology independent (since,  $I_{M1} = \frac{I_{ON}}{(1+\beta_s R_2)}$ ). Therefore, in our derivation we represent the same current as  $I_{ON}$  from  $t = T_R$  to  $t_{sat}$ . If  $V_{TCP} < V_{dsat}$ , then we find  $t_{TCP10\%}$  such as  $t_{TCP10\%} = t_{sat} + \Delta t$ . Where  $\Delta t$  represents the time during which both nMOS transistors operate in linear region. Therefore, we add a time constant term ' $R_{eq}(C_l + C_p)$ ' to resultant term obtained till  $t_{sat}$ . It gives the expression for  $t_{TCP10\%}$  as:

$$t_{TCP10\%} = K_1 C_l + K_2 T_R + K_3 \tag{5.7}$$

Where, 
$$K_1 = \frac{(V_{dd} - V_{dsat})}{I_{ON}} + R_{eq}$$
 (5.8)

$$K_2 = -\frac{a_1}{I_{ON}} \tag{5.9}$$

$$K_{3} = \left(\frac{(V_{dd} - V_{dsat})}{I_{ON}} + R_{eq}\right)C_{p} + \frac{a_{2}}{I_{ON}}$$
(5.10)

$$a_{1} = \beta_{s} \frac{Vdd}{2} \left( 1 - \frac{\beta_{s}}{[\beta_{l}(V_{dd} - V_{th}) + \beta_{s}]} \right) + \beta_{s} \left( \frac{I_{X} + \beta_{s} V_{th1}}{[\beta_{l}(V_{dd} - V_{th}) + \beta_{s}]} - V_{th1} \right)$$
(5.11)

$$a_{2} = \frac{C_{C1}V_{dd}\beta_{s}}{[\beta_{l}(V_{dd} - V_{th}) + \beta_{s}]}$$
(5.12)

Where,  $a_1$ ,  $a_2$  are constants proportional to  $W_n$ . For all the  $t_{TCPs}$  which fall under Region I, (5.7) remain valid. The model of (5.7) in Region I has thus been verified using HSPICE simulated data.

As a representative, we show the simulation results of  $t_{TCP_{60\%}}$ . This is because  $t_{TCP_{60\%}} > T_R$  in the whole  $T_R$ ,  $C_l$  space used in characterization LUTs. For  $t_{TCP60\%}$ , the form of model remains same. The coefficient values also remains same, the only difference is that the term  $R_{eq}$  will not be present. For  $t_{TCP60\%}$ , model coefficients  $K_1$  and  $K_3$  will be:

$$K_1 = \frac{(V_{dd} - V_{dsat})}{I_{ON}}$$
(5.13)

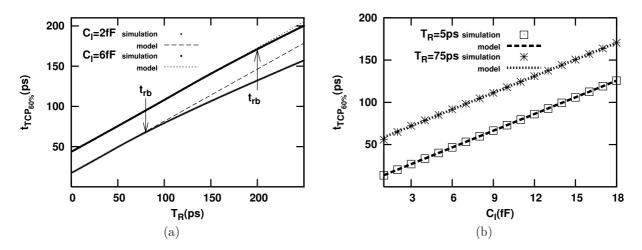


Figure 5.2: Case 1: Variation of  $t_{TCP60\%}$  with respect to  $T_R$  and  $C_l$  values.

$$K_3 = \left(\frac{V_{dd} - V_{dsat}}{I_{ON}}\right)C_p + \frac{a_2}{I_{ON}}$$
(5.14)

So,  $t_{sat}$  would also have same model as a  $t_{TCP60\%}$ . Using curve fitting (as shown in Fig. 5.2) on the simulated values of  $t_{TCP60\%}$ , we extracted the coefficients  $K_1$ ,  $K_2$ ,  $K_3$  of (5.7). From (5.7), we observe:

- Observation 1:  $K_1$  is a linear function of  $1/W_n$
- Observation 2:  $K_2$  is independent of  $W_n$
- Observation 3:  $K_3$  is a linear function of  $1/W_n$

As explained earlier, (5.7) is valid if  $V_{out}(T_R) \ge V_{dsat}$ , this imposes the following constraint on the region of validity:

$$\Delta Q(T_R) = (a_1 T_R - a_2) \le (C_l + C_p)(V_{dd} - V_{dsat})$$
(5.15)

Where,  $\Delta Q(T_R)$  is the output discharge from 0 to  $T_R$  and  $V_{dd}$  is the power supply voltage.  $C_p$  is NAND gate's parasitic capacitance (due to gate-drain over-lap, drain-bulk junction capacitance etc.) between node 'Out' and 'gnd', and it is linearly dependent on  $W_n$ . The maximum value of  $T_R$  which satisfies (5.15), will be represented as  $t_{rb}$ .

Further, we verify Observation 1-3 with HSPICE 32nm PTM. We observe that (5.7) fits well on HSPICE simulation data as shown in Fig. 5.2. We verify the coefficients  $(K_1, K_2 \text{ and } K_3)$  behavior with  $W_n$  (shown in Fig. 5.3a and 5.3b). In this sub-subsection, we observe that our approach in Region I remains valid with variation in cell size.

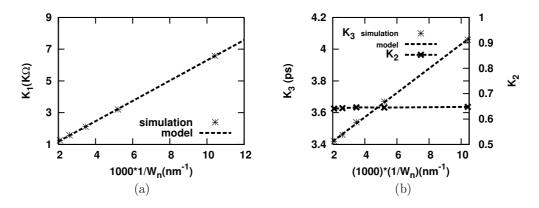


Figure 5.3: Case 1: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with cell size  $(W_n)$ .

## 5.4.2 Derivation of the model in Region II

In this subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and cell size for Region II. Region II contains all the TCPs having value of  $V_{TCP} > V_{out}(T_R)$ , as we depict in Fig. 5.1b. In this derivation, we consider that the discharging nMOS transistor  $(M_1)$ always operates in velocity saturation (since  $V_{ds}(M_1) > V_{dsat}$ ) and  $M_2$  operates in linear region only, when  $V_{out}(T_R) \ge V_{dsat}$  constraint is followed. As a representative, we show the simulation results of  $t_{TCP_{90\%}}$  (shown in Fig. 5.1b). This is because  $t_{TCP_{90\%}} < T_R$  in the whole  $T_R$ ,  $C_l$  space used for characterization of LUTs.

To find the  $t_{TCP90\%}$  model, we integrate the saturation current flowing through  $M_1$ , from  $t = \begin{pmatrix} V_{th} \\ V_{dd} \end{pmatrix} T_R$  to  $t = t_{TCP}$ . We equate this integral to  $(C_l + C_p) (V_{dd} - V_{TCP})$  to obtain the  $t_{TCP}$ . Solving this integral using (5.2), (5.3) and (5.6), we get the expression for  $t_{TCP90\%}$ as:

$$t_{TCP90\%} = A_1 T_R + A_2 \sqrt{T_R} \tag{5.16}$$

Where, 
$$A_1 = \left(\frac{V_1}{V_{dd} \left(1 - \frac{\beta_s}{\left[\beta_l (V_{dd} - V_{th}) + \beta_s\right]}\right)}\right)$$
 (5.17)

$$V_{1} = \left[ V_{th1} - \frac{\left(\beta_{s} V_{th1} - C_{C1} \frac{V_{dd}}{T_{R}} + I_{X}\right)}{\left[\beta_{l} (V_{dd} - V_{th}) + \beta_{s}\right]} \right]$$
(5.18)

$$A_{2} = \sqrt{\frac{0.2 \left(C_{l} + C_{p}\right)}{\beta_{s} \left(1 - \frac{\beta_{s}}{\left[\beta_{l}\left(V_{dd} - V_{th}\right) + \beta_{s}\right]}\right)}}$$
(5.19)

For all the  $t_{TCPs}$  which fall under Region II, (5.16) remains valid. The model of (5.16) in Region II has thus been verified using HSPICE simulated data. Using curve fitting (as shown in Fig. 5.4) on the simulated values of  $t_{TCP90\%}$ , we extracted the coefficients  $A_1$  and  $A_2$  of (5.16). Please note that we have considered the impact of  $V_X$  on the discharge of

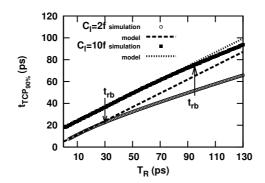


Figure 5.4: Case 1: Variation of  $t_{TCP90\%}$  with respect to  $T_R$ .

node 'Out'.

From (5.16), we observe :

- Observation 4:  $A_1$  is independent of  $W_n$  and  $C_l$
- Observation 5:  $A_2^2$  is a linear function of  $C_l$
- Observation 6:  $A_2^2$  is proportional to  $1/W_n$

As explained earlier, (5.16) is valid if  $V_{out}(T_R) \ge V_{dsat}$ , this imposes the following constraint on the region of validity:

$$\Delta Q(T_R) = (a_1 T_R - a_2) > (C_l + C_p)(V_{dd} - V_{TCP})$$
(5.20)

For a given set of values of  $C_l$ ,  $T_R$  in the LUT, we first verify through (5.20) whether a given  $\alpha\%$  TCP (represented as  $TCP - \alpha\%$ ) falls in Region I. We then use the model of (5.7) to obtain  $t_{TCP-\alpha\%}$ . If  $TCP - \alpha\%$  falls in Region II for this  $C_l$ ,  $T_R$  values, we use the model of (5.16) to obtain  $t_{TCP-\alpha\%}$ . This saves a large number of HSPICE simulations in ECSM (or CCSM) characterization. Next, we verify observations 4-6 against HSPICE simulation data using 32nm PTM model. Using curve fitting (as shown in Fig. 5.4) on the simulated values of  $t_{TCP90\%}$ , we extract the coefficients ( $A_1$  and  $A_2$ ) of (5.16). In Fig. 5.5a and 5.5b, we verify that the model coefficient's ( $A_1$  and  $A_2$ ) behavior with  $W_n$  and  $C_l$  is in accordance with our prediction.

## 5.4.3 Efficient ECSM Characterization

In this subsection, we demonstrate the effectiveness of our models (derived in Subsection 5.4.1 and 5.4.2) in saving the number of HSPICE simulations for ECSM characterization of 2-input NAND gate. Using (5.7) and (5.16), within the regions of their validity, we get the values of all TCPs directly (without any HSPICE simulation). Hence, it saves characterization effort for the standard cell. On the other hand, the TCP values which

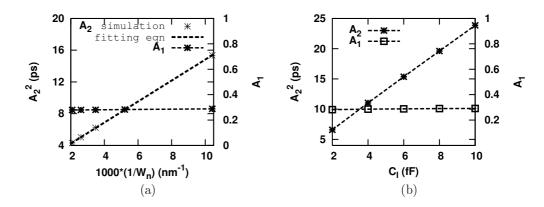


Figure 5.5: Case 1: Variation of  $A_1$  and  $A_2$  with cell size  $(W_n)$  and load capacitance  $(C_l)$ .

are out of the region of validity, would be obtained from HSPICE simulations. For a 2input NAND gate standard cell, we first extract the values of  $K_1$ ,  $K_2$  and  $K_3$  for TCPs in Region I using 7 HSPICE simulations and the values of  $A_1$ ,  $A_2$  for TCPs in Region II using 4 HSPICE simulations. We then calculate the values of  $t_{TCPs}$  (entries shown by numeric values in Table 5.1) for  $C_l$ ,  $T_R$  values lying within the region of validity of (5.7) and (5.16). For 2-input NAND gate standard cells of other sizes, all TCPs (within the region of validity of (5.7) and (5.16)) are obtained using Observation 4 – 6. In Table 5.1,  $t_{TCP60\%}$  values calculated using our model are shown. In Table 5.2,  $t_{TCP60\%}$  values generated using conventional method (*i.e.* fully HSPICE generated) are shown. In Table 5.3, the percentage error in  $t_{TCP60\%}$  values calculated using our model compared to conventional method is shown. In Table 5.1,  $t_{TCP60\%}$  values calculated using our model show some entries as 'HSPICE', it corresponds to the data points (*i.e.*  $t_{TCP60\%}$  values) of  $C_l$ ,  $T_R$ values which are out of region of validity for (5.7). And these values would be generated using HSPICE simulations.

We observe that the percentage saving in HSPICE simulations using our method of generating LUTs explained above is minimum 67.35% and 77.55% for  $TCP_{60\%}$  and  $TCP_{90\%}$ , respectively (including the simulations required to obtain the model coefficients). We find that the values of  $t_{TCPs}$  in our LUTs differ by a maximum of 1.28% (for 7 × 7matrix size of  $t_{TCP60\%}$ ) and 3.08% (for 7 × 7matrix size of  $t_{TCP90\%}$ ) from those in fully HSPICE generated conventional LUTs. Therefore using proposed models, standard cell characterization can be done with a significantly lesser number of HSPICE simulations (approximately 67% reduction in HSPICE simulations). For the  $t_{TCP} < T_R$ , both the Region I and II models are used .

# 5.5 Case 1: Variation aware TCP models

In this section, we consider layout dependent effects due to mechanical stress in deriving the model coefficients. We also derive the relationships of the model coefficients with the temperature (T) and supply voltage  $(V_{dd})$ . We have already discussed the motivation towards the analysis of variation aware (considering process induced mechanical stress,

	$C_l(fF)$		$T_R(ps)$								
		2.20	4.84	10.66	23.46	51.62	113.60	250.00			
	1.51	15.45	17.17	20.95	29.27	HSPICE	HSPICE	HSPICE			
	2.28	20.54	22.26	26.04	34.36	52.67	HSPICE	HSPICE			
	3.45	28.24	29.95	33.73	42.05	60.36	HSPICE	HSPICE			
	5.22	39.86	41.58	45.36	53.68	71.99	112.27	HSPICE			
	7.88	57.43	59.15	62.93	71.25	89.56	129.84	HSPICE			
	11.91	83.99	85.70	89.48	97.80	116.11	156.40	245.06			
	18.00	124.11	125.83	129.61	137.93	156.24	196.52	285.18			

Table 5.1: Case 1: LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate using our model.

Note: Entries shown by 'HSPICE' can be obtained by HSPICE simulation whereas entries shown by numeric values are obtained using our model

Table 5.2: Case 1: ECSM LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate obtained using HSPICE simulations.

C(fE)	$T_R(ps)$								
$C_l(fF)$	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	15.35	17.01	20.69	28.9	47.00	81.89	150.21		
2.28	20.45	22.11	25.80	33.98	52.33	89.56	161.03		
3.45	28.14	29.81	33.50	41.67	59.88	99.41	175.10		
5.22	39.77	41.43	45.12	53.28	71.40	111.95	193.11		
7.88	57.32	58.99	62.68	70.84	88.89	129.11	215.92		
11.91	83.86	85.53	89.22	97.37	115.37	155.34	244.72		
18.00	123.95	125.62	129.31	137.46	155.43	195.22	283.85		

Table 5.3: Case 1: Percentage error in proposed model's LUT with respect to fully HSPICE generated ECSM LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate.

C(fF)	$T_R(ps)$								
$C_l(fF)$	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	0.65	0.94	1.26	1.28	×	×	×		
2.28	0.44	0.68	0.93	1.12	0.65	×	×		
3.45	0.36	0.47	0.69	0.91	0.80	×	×		
5.22	0.23	0.36	0.53	0.75	0.83	0.29	×		
7.88	0.19	0.27	0.40	0.58	0.75	0.57	×		
11.91	0.16	0.20	0.29	0.44	0.64	0.68	0.14		
18.00	0.13	0.17	0.23	0.34	0.52	0.67	0.47		

Note: Entries shown by ' $\times$ ' correspond to the values we obtain using HSPICE simulations in Table 5.1 (not through our models)

supply voltage and temperature variability) TCP models in Chapter 4 of the thesis. Here, we derive and validate the behavior of model coefficients with PVT variations. Later, we use these models and their derived relationships to reduce the number of HSPICE simulations significantly.

## 5.5.1 TCP models considering stress variability

In this subsection, we derive the change in coefficients in (5.7) and (5.16) as a function of NF in a stress enabled 45nm CMOS technology. The novelty of this work is due to the prediction of entire output waveform of the standard cell as a function of channel stress (or NF) for a wide range of  $T_R$  and  $C_l$ . As discussed in Section 6.2, the effect of change in channel stress as a function of NF is captured by PTM parameters MULU0 and DELVT0 in our HSPICE simulations.

Now we derive the model coefficients of (5.7) and (5.16) as a function of NF. We use a set of empirical equations suggested in [89, 92, 93], to relate device level electrical parameters with stress. These equations are:

$$\mu\left(\sigma\right) = \left[P_1 \,\sigma(NF) + 1\right] \mu_0 \tag{5.21}$$

$$v_{sat} (\sigma) = [P_1 \sigma(NF) + 1] v_{sat}$$
(5.22)

$$I_{ON}\left(\sigma\right) = \left[P_1 P_2 \sigma\left(NF\right) + 1\right] I_{ON}$$

$$(5.23)$$

$$V_{th} (\sigma) = [V_{th} + P_3 \sigma (NF)]$$
(5.24)

Where  $\mu(\sigma)$ ,  $v_{sat}(\sigma)$ ,  $I_{ON}(\sigma)$ ,  $V_{th}(\sigma)$  are stress dependent mobility, saturation velocity, drive current and threshold voltage parameters, respectively. Whereas,  $\mu_0$ ,  $v_{sat}$ ,  $I_{ON}$ ,  $V_{th}$ are unstressed parameters and  $P_1$  is the piezoresistive coefficient.  $P_2$  and  $P_3$  are technology dependent coefficients extracted by fitting the above equations into HSPICE simulated I-V data, as discussed in [89, 93]. Here,  $\sigma(NF)$  represents the average stress in the fingers in MFGSs. As we discussed in [89], a relation between this average stress and NF is:

$$\frac{\sigma(NF)}{\sigma_{ref}(NF=1)} = M_1 + \frac{M_2}{NF+M_3}$$
(5.25)

In (5.25),  $M_1$ ,  $M_2$ ,  $M_3$  are fitting parameters specific to given technology node, where  $M_1$  denotes  $\sigma (NF \to \infty) / \sigma (NF = 1)$ , while  $M_2$  and  $M_3$  control the rate of change of stress as NF is increased (as discussed in detail in [89]).

#### 5.5.1.1 Impact of stress induced variability in Region I

In this sub-subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and NF for Region I in stress enabled technologies. In (5.9), (5.13) and (5.14),  $\mu$ ,  $v_{sat}$ ,  $I_{ON}$ , and  $V_{th}$ are now given by (5.21)-(5.24). We derive the model for  $t_{TCP60\%}$  considering the impact of

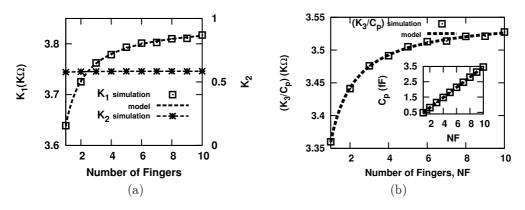


Figure 5.6: Case 1:  $K_1$ ,  $K_2$  and  $K_3$  as a function of NF.

channel stress in Region I. In this derivation, we assume that  $(V_{dd} - V_{th})$  is independent of NF. This is justified since  $V_{th}$  is much smaller than  $V_{dd}$ . From (5.13) and (5.21)-(5.25), we obtain :

$$K_1 = (NF + M_3) \left(\frac{D_1}{NF + D_2}\right)$$
 (5.26)

Where,

$$D_1 = \frac{(V_{dd} - V_{dsat})}{((M_1 P_1 P_2 + 1) I_{ON})}$$
(5.27)

$$D_2 = M_3 + \frac{M_2 P_1 P_2}{(M_1 P_1 P_2 + 1)}$$
(5.28)

We observe that (5.26) fits well with HSPICE simulated data as shown in Fig. 5.6a. In these HSPICE simulation MULU0 and DELVT0 vary with NF in accordance with (5.25) (*i.e.* the PTM model incorporates channel stress variability effects). Likewise, solving (5.14), we found the relation between  $K_3$  and NF as:

$$(K_3/C_p) = K_1 + \frac{a_2(\sigma)}{C_p I_{ON}(\sigma)} = \left[ (NF + M_3) \left( \frac{D_3}{NF + D_2} \right) \right]$$
(5.29)

Where,

$$D_3 = \left[ \left( V_{dd} - V_{dsat} \right) + a_2 \right] \frac{1}{\left( \left( M_1 P_1 P_2 + 1 \right) I_{ON} \right)}$$
(5.30)

Where,  $C_p$  is parasitic capacitance (due to gate-drain overlap, drain-bulk junction capacitance etc.) which is linearly related to NF in MFGS. This can be seen in the inset of Fig. 5.6b. We observe that (5.29) fits well with HSPICE simulated data as shown in Fig. 5.6b. Thereafter, from (5.9), we observe that  $K_2$  is independent of NF (because  $a_1$  and  $I_{ON}$  are both proportional to NF) as shown in Fig. 5.6a.

#### 5.5.1.2 Impact of stress induced variability in Region II

In this sub-subsection, we derive the relationships of  $t_{TCP}s$  with  $T_R$ ,  $C_l$  and NF for

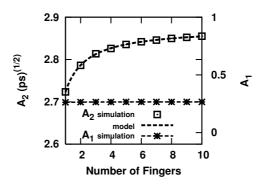


Figure 5.7: Case 1:  $A_1$  and  $A_2$  as a function of NF.

Region II in stress enabled technologies. In (5.17) and (5.19),  $\mu$ ,  $v_{sat}$ ,  $I_{ON}$  and  $V_{th}$  are now given by (5.21)-(5.24). We derive a model for  $t_{TCP90\%}$  considering the impact of channel stress in Region II. From (5.17) and (5.21)-(5.25), we obtain that  $A_1$  is independent of  $V_{th}(\sigma)$ . We have verified through simulations that variation in  $V_{th}(\sigma)$  with NF is very small (in our TCAD calibrated simulations variation in  $V_{th}(\sigma)$  with NF is less than 3%). This small variation in  $V_{th}(\sigma)$  has also been reported in [94]. Therefore,  $A_1$  is independent of  $\sigma(NF)$  as shown in Fig. 5.7. Using (5.19), (5.22) and (5.25), We find the relationship between  $A_2$  and NF as:

$$A_2 = \sqrt{\left(\frac{S_1(NF + M_3)}{(NF + S_2)}\right)}$$
(5.31)

Where,

$$S_1 = \left(\frac{0.2\left(C_l + C_p\right)}{\beta_s \left(1 - \frac{\beta_s}{\left[\beta_l\left(V_{dd} - V_{th}\right) + \beta_s\right]}\right)}\right)$$
(5.32)

$$S_2 = \left(\frac{1}{M_3 + \frac{P_1 M_2}{(M_1 P_1 + 1)}}\right) \tag{5.33}$$

We observe that (5.31) fits well on our stress aware HSPICE simulation data as shown in Fig. 5.7.

#### 5.5.1.3 Efficient stress aware ECSM characterization

In this sub-subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of 2-input NAND gate standard cell would need significantly lesser number of HSPICE simulations. We generated  $7 \times 7$  LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$ values for different cell sizes (represented by NF). Conventionally, this would require 343 HSPICE simulations for cell sizes corresponding to NF=1 to 7. However using our models only 68 HSPICE simulations (including simulations to extract the model coefficients) were needed to generate the same LUT. For computing the remaining values of  $t_{TCP60\%}$ , we used our model. In this way, we saved 275 HSPICE simulations to generate the 7 × 7 LUTs for NF=1 to 7. Therefore, proposed model can be used to save  $\simeq 80.18\%$  HSPICE simulations for all TCPs in Region I if  $V_{TCP} < V_{out}(T_R)$ . For all the TCPs having value  $V_{TCP} > V_{out}(T_R)$ , the proposed models (Region I and II models) can be used to save 97.38% HSPICE simulations.

## 5.5.2 TCP models considering temperature variability

In this subsection, we analytically model the coefficients of (5.7) and (5.16) as a function of temperature. We also model the region of validity of (5.7) and (5.16) in  $C_l$ ,  $T_R$  space as a function of temperature. In this work, we take a realistic range of temperature variation due to on-chip heating from 298K (room temperature) to 423K. We use an empirical expression suggested in [23, 29], to consider the impact of temperature variability on carrier mobilities. This expression is:

$$\mu(T) = \mu(T_0) \left(\frac{T}{T_0}\right)^{-\theta}$$
(5.34)

Where,  $\mu(T)$  is the temperature dependence of mobility, T is the temperature,  $T_0$  is the nominal temperature *i.e.* 298 K and  $\theta$  is technology dependent temperature coefficient. For our PTM CMOS technology we extract the value of  $\theta = 2.3$  by maximum transconductance  $(g_m)$  method. We use the empirical relation (given in [29]) between carrier saturation velocity and temperature as:

$$v_{sat}(T) = v_{sat}(T_0) - \eta (T - T_0)$$
(5.35)

Where,  $v_{sat}(T)$  is the temperature dependence of saturation velocity and  $\eta$  is the temperature coefficient. The threshold voltage of devices also gets affected by an increase in temperature due to change in fermi level location and band gap energy [96]. In [96], the temperature dependence of threshold voltage is given by:

$$V_{th}(T) = V_{th}(T_0) - \kappa (T - T_0)$$
(5.36)

Where,  $\kappa$  is the temperature dependence coefficient of threshold voltage. The value of  $\eta$  and  $\kappa$  can be extracted from simulated HSPICE I-V data for a given CMOS technology. We also verified the validity of (5.34), (5.35) and (5.36) relations using Sentaurus TCAD device simulations. In TCAD simulations, we use 25nm drawn gate length nMOS and pMOS devices. We now discuss our approach for deriving temperature variation aware  $t_{TCP}$  models.

#### 5.5.2.1 Impact of temperature variability in Region I

In this sub-subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and temperature (T) for Region I. In (5.9), (5.13) and 5.14,  $v_{sat}$ ,  $\mu$  and  $V_{th}$  are now given by (5.34)-(5.36). We derive a model for  $t_{TCP60\%}$  considering the impact of temperature variability in Region I. In this derivation, we again assume that  $(V_{dd} - V_{th})$  is independent of T, as in the previous section. From (5.13) and (5.34), (5.35), we obtain :

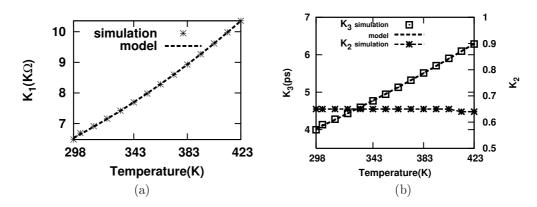


Figure 5.8: Case 1: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with temperature.

$$K_1 = \left(R_1 T^{2.3} + R_2 T + R_3\right) \tag{5.37}$$

Where,

$$R_{1} = \left[\frac{\left(\frac{L_{eff}}{W_{n}P_{l}}\right)}{\left(\mu(T_{0})\left(\frac{1}{T_{0}}\right)^{-2.3}\right)}\right]$$
(5.38)

$$R_{2} = \left[\frac{V_{dd}}{W_{n} P_{s} \left(V_{gs} - V_{th}\right)} \frac{\eta}{v_{sat} \left(T_{0}\right)^{2}}\right]$$
(5.39)

$$R_{3} = \left[\frac{V_{dd}}{W_{n} P_{s} \left(V_{gs} - V_{th}\right)} \frac{(1 - \eta T_{0})}{v_{sat} \left(T_{0}\right)^{2}}\right]$$
(5.40)

 $R_1$ ,  $R_2$  and  $R_3$  are the technology dependent constants obtained from the derivation of (5.13) using (5.34) and (5.35). We observe that (5.37) fits well on HSPICE simulated data as shown in Fig. 5.8a. Likewise solving (5.14), we find the relation between  $K_3$  and T as:

$$K_3 = C_p K_1 + \frac{a_2}{I_{ON}} = \left(R_4 T^{2.3} + R_5 T + R_6\right)$$
(5.41)

Where,  $R_4$ ,  $R_5$  and  $R_6$  are the technology dependent constants obtained after deriving the (5.14) using (5.34)-(5.36). Using HSPICE simulations, we find that the change in  $C_p$ with T varying from 298K to 423K is negligibly small. We observe that (5.41) fits well with HSPICE simulated data as shown in Fig. 5.8b. Thereafter, solving (5.9), we observe that  $K_2$  is independent of T as shown in Fig. 5.8b (because  $a_1$  and  $I_{ON}$  both are proportional to T).

#### 5.5.2.2 Impact of temperature variability in Region II

In this sub-subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and T for Region II. In (5.17) and (5.19),  $v_{sat}$ ,  $\mu$  and  $V_{th}$  are now given by (5.34)-(5.36). We derive a model for  $t_{TCP90\%}$  considering the impact of temperature variability in Region II. From (5.17), we observe that  $A_1$  is dependent on  $V_{th}$  only. From (5.36), we expect  $A_1$  to reduce linearly with

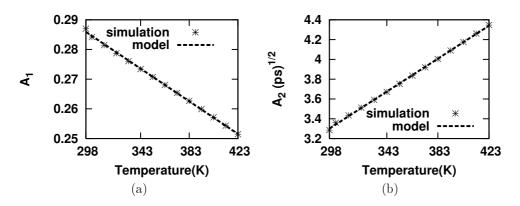


Figure 5.9: Case 1: Variation of  $A_1$  and  $A_2$  with temperature.

T, which we verify through HSPICE simulations in Fig. 5.9a. We obtain the relationship between  $A_2$  and T from (5.19) and (5.35):

$$A_2 = (R_7 T + R_8) \tag{5.42}$$

Where,  $R_7$  and  $R_8$  are technology dependent constants obtained from the derivation of (5.19) using (5.35). We observe that (5.42) fits well on our HSPICE simulation data with temperature variability as shown in Fig. 5.9b.

Therefore, we observe that our models in Region I and II are valid with temperature variability.

#### 5.5.2.3 Efficient temperature variation aware ECSM characterization

In this sub-subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of 2-input NAND gate standard cell would need significantly lesser number of HSPICE simulations. We generated  $7 \times 7$  LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$  values for different temperature values. Conventionally, this would require 343 HSPICE simulations for 7 different values of temperature T from 298K to 423K. However, using our models only 69 HSPICE simulations (including simulations to extract the model coefficients) were needed to generate the same LUT. For computing the remaining values of  $t_{TCP60\%}$ , we used our model. In this way, we saved 274 HSPICE simulations to generate the 7 × 7 LUTs for T = 298K to 423K. Therefore, proposed model can be used to save  $\simeq$  79.88% HSPICE simulations for all TCPs in Region I if  $V_{TCP} < V_{out}(T_R)$ . For all the TCPs having value  $V_{TCP} > V_{out}(T_R)$ , our models (Region I and II models) can be used to save 97.09% HSPICE simulations.

# 5.5.3 TCP models considering Supply Voltage Variability

In this subsection, we derive the power supply voltage variation aware  $t_{TCP}$  models which we use to reduce the re-characterization effort significantly. We consider the  $\pm 10\%$ change in power supply voltage ( $V_{dd}$ ) from the its nominal value of  $V_{dd} = 0.9V$  [99].

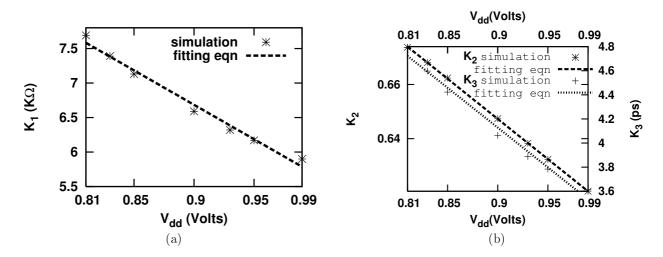


Figure 5.10: Case 1: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with supply voltage.

#### 5.5.3.1 Impact of supply voltage variability in Region I

In this sub-subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and  $V_{dd}$  for Region I. We derive a model for  $t_{TCP60\%}$  considering the impact of supply voltage variability in Region I. In (5.13), we observe that  $K_1$  decreases with an increase in supply voltage. We verify this observation in Fig. 5.10a.

We now discuss the variation of  $K_3$  with  $V_{dd}$ . In (5.14),  $C_p$  contains the voltage dependent junction capacitance which is given by [94] as  $C_j(V) = \frac{A \cdot C_{j0}}{\sqrt{\left(1+\frac{V}{\phi_0}\right)}}$ . Where, A indicates the junction area,  $C_{j0}$  is zero-bias junction capacitance per unit area, V is the reverse bias voltage and  $\phi_0$  is built-in potential. In (5.14), we observe that the behavior of  $K_3$  with supply voltage remains same as of  $K_1$ . From (5.9), we observe that  $K_2$  is inversely proportional to  $V_{dd}$ . We verify our observation related to  $K_2$  and  $K_3$  with  $V_{dd}$  in Fig. 5.10b.

#### 5.5.3.2 Impact of supply voltage variability in Region II

In this sub-subsection, we derive the relationship of  $t_{TCP}s$  with  $T_R$ ,  $C_l$  and  $V_{dd}$  for Region II. We derive a model for  $t_{TCP90\%}$  considering the impact of supply voltage variability in Region II. In (5.17),  $A_1$  is inversely proportional to supply voltage and it is verified through HSPICE simulations as shown in Fig. 5.11a. In (5.19), we can see that only  $C_p$  is supply voltage dependent term which decreases with supply voltage. Using this analysis, we observe that  $A_2^2$  is inversely proportional to  $V_{dd}$ . We verify this observation in Fig. 5.11b.

Thus, we observe that our model in Region I and Region II incorporates the effect of supply voltage variability quite satisfactorily.

#### 5.5.3.3 Efficient supply voltage variation aware ECSM characterization

In this sub-subsection, we show that using our  $t_{TCP}$  models, ECSM characterization of 2-input NAND gate standard cell would need significantly lesser number of HSPICE simulations. We generated 7×7 LUTs having  $t_{TCP60\%}$  values with varying  $C_l$  and  $T_R$  values

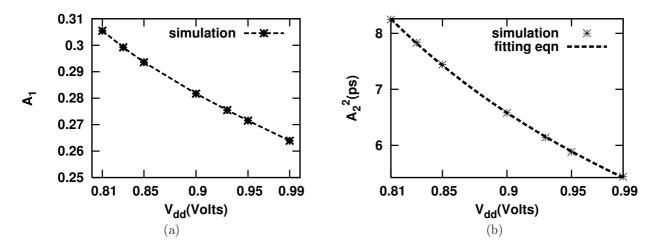


Figure 5.11: Case 1: Variation of  $A_1$  and  $A_2$  with supply voltage.

for different supply voltages. Conventionally, this would require 343 HSPICE simulations for 7 different values of supply voltage  $V_{dd}$  from 0.81V to 0.99V. However using our models only 69 HSPICE simulations (including simulations to extract the model coefficients) were needed to generate the same LUT. For computing the remaining values of  $t_{TCP60\%}$ , we used our model. In this way, we saved 274 HSPICE simulations to generate the 7 × 7 LUTs for  $V_{dd} = 0.81V$  to 0.99V. Therefore, proposed model can be used to save  $\simeq$  79.88% HSPICE simulations for all TCPs in Region I if  $V_{TCP} < V_{out}(T_R)$ . For all the TCPs having value  $V_{TCP} > V_{out}(T_R)$ , our models (Region I and II models) are used to save 95.92% HSPICE simulations.

# 5.6 Case 2: Derivation and Validation of $t_{TCP}$ model

In this section, we derive the  $t_{TCP}$  model for the switching of the lower nMOS transistor in the series stack of 2-input NAND gate. We derive the relationship of  $t_{TCP}s$  with the  $T_R$ ,  $C_l$  and cell size. We also derive the region of validity of these relationships in  $T_R$ ,  $C_l$ space. We derive the model for the case when  $V_{out}(T_R) \ge V_{dsat}$ . In this work, we ignore the negligibly small current flowing through pMOS transistor (max. current  $\approx 3\mu A$ ). We classify the TCPs into two regions:

- Region I: When  $V_{in} = V_{dd}$  (for  $t_{TCP}s > T_R$ )
- Region II: When  $V_{in} < V_{dd}$  (for  $t_{TCP} s < T_R$ )

In this section, we derive the timing model of  $TCP_{10\%}$  in Region I and timing model of  $TCP_{90\%}$  in Region II (as shown in Fig. 5.12b).

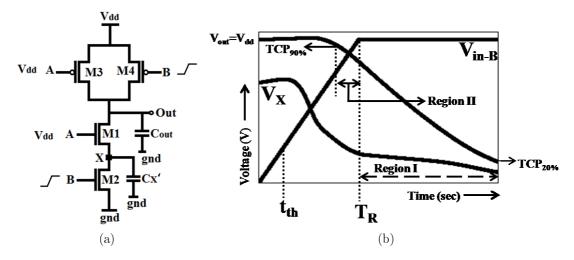


Figure 5.12: Case 2: (a) 2-input NAND gate schematic (b) its I/O waveform.

# 5.6.1 Derivation of the model in Region I

In this subsection, we derive the model for  $t_{TCPs}$  in Region I for the 2-input NAND gate shown in Fig. 5.12a. We first model the voltage transition at the intermediate node 'X' considering different operating regions of lower nMOS transistor. As a representative, we show the simulation results of  $t_{TCP_{60\%}}$ . This is because  $t_{TCP_{60\%}} > T_R$  is true in the whole  $T_R$ ,  $C_l$  space used in characterization LUTs, as we discuss later.

To derive the model for  $t_{TCP10\%}$ , we proceed as follows: The transistor  $M_1$  starts conducting at  $t = t_{th} = \frac{V_{th}}{V_{dd}}T_R$ . The transistor  $M_2$  operates in saturation region till  $V_X$  reaches  $V_{dsat}$  (corresponding time is represented as  $t_{xsat}$ ). We observe from simulation that within the whole  $T_R$ ,  $C_l$  space used in characterization LUTs,  $t_{xsat} < T_R$  (which we observe in our simulation). From  $t_{xsat}$  to  $t_{TCP}$ ,  $M_2$  operates in linear region. We first integrate the current through  $M_1$  from  $t_{th}$  to  $T_R$  and equate the integral to  $(C_l + C_p) (V_{dd} - V_{out}(T_R))$  to obtain the value of  $V_{out}(T_R)$ . If the  $V_{TCP} \ge V_{dsat}$ , we integrate the saturation current through  $M_1$  from  $t = T_R$  to  $t = t_{TCP}$ . We equate the sum of these integrals to  $(C_l + C_p) (V_{out}(T_R) - V_{TCP})$ to obtain  $t_{TCP}$ . Here  $C_l$  is the load capacitance,  $C_p$  is the parasitic capacitance. If the  $V_{TCP} < V_{dsat}$ , we integrate  $I_{ON}$  through  $M_1$  from  $t = T_R$  to  $t = t_{sat}$  (where  $t = t_{sat}$ represents the time at which  $V_{out} = V_{dsat}$ ). From  $t = T_R$  to  $t_{sat}$ , the lower nMOS transistor  $(M_2)$  operates in linear region, therefore we consider  $M_2$  as a linear resistor (represented as  $R_2$ ) which gives the value of intermediate node voltage  $V_X = I_{M1}R_2$ . This  $R_2$  results in the the lowering of saturation current of  $M_1$  by a constant value which is technology independent (since,  $I_{M1} = \frac{I_{ON}}{(1+\beta_s R_2)}$ ). Therefore, in our derivation we represent this saturation current  $I_{M1}$  by the symbol  $I_{ON}$  from  $t = T_R$  to  $t_{sat}$ . We equate the sum of these integrals to  $(C_l + C_p) (V_{out}(T_R) - V_{dsat})$  to obtain  $t_{sat}$ . From  $t = t_{sat}$  to  $t = t_{TCP}$ , both the series stacked nMOS devices operate in linear region. These devices act as a resistances  $R_1$  and  $R_2$  whose values can be obtained by equating  $V_{gs1} = V_{gs2} = V_{dd}$ . Therefore, the time duration from  $t_{sat}$  to  $t_{TCP}$  is proportional to time constant  $R_{eq}(C_l + C_p)$ . Where,  $R_{eq}$ represents an equivalent resistance of series stacked nMOS devices. As we discuss later in this section, for  $V_{TCP} < V_{dsat}$  the value of  $V_X$  is so low that the change in  $V_X$  during this

RC discharge need not to be considered.

Now we discuss in detail the derivation of  $t_{TCP10\%}$  model. Following the procedure as explained in the previous paragraph, we write an expression for the output voltage discharge as:

$$\int_{t_{th}}^{T_R} I_{M1} dt = (C_l + C_p) \left( V_{dd} - V_{out}(T_R) \right)$$
(5.43)

Taking L.H.S. and solving it :

$$\int_{t_{th}}^{T_R} I_{M1} dt = \beta_{s-M1} \int_{t_{th}}^{T_R} (V_{dd} - V_X(t) - V_{th1}) dt$$
(5.44)

In this derivation, we represent the threshold voltage of  $M_1$  as  $V_{th1}$  (threshold voltage of  $M_2$  as  $V_{th}$ ).

$$= \beta_{s-M1} \int_{t_{th}}^{T_R} (V_{dd} - V_{th1}) dt - \beta_{s-M1} \left[ \int_{t_{th}}^{t_{xsat}} V_X(t) dt + \int_{t_{xsat}}^{T_R} V_X(t) dt \right]$$
(5.45)

From  $t = t_{th}$  to  $t_{xsat}$ , both nMOS transistors operate in saturation region. To determine  $V_X$ , we apply KCL at node 'X' which gives an expression as follows:

$$I_{M2} = I_{M1} + I_{C_{CX}} + I_{C_X} (5.46)$$

$$I_{M2} = I_{M1} - (C'_X + C_{CX})\frac{dV_X}{dt} + C_{CX}\frac{dV_{in-B}}{dt}$$
(5.47)

Where,

$$V_{in-B} = V_{dd} \left(\frac{t}{T_R}\right) \text{ for } 0 < t < T_R$$
(5.48)

Where,  $I_{C_{CX}}$  is the current flowing through gate-to-drain coupling capacitance of  $M_2$ , it consists of the gate-to-drain overlap capacitance and a part of the gate-to-channel capacitance. The other symbols used in (5.46), have the same meaning as in Subsection 5.4.1 of this chapter. Taking  $(C'_X + C_{C1}) = C_X$ , we rewrite (5.46) as:

$$\beta_{s-M2}(V_{in-B} - V_{th}) = \beta_{s-M1}(V_{dd} - V_X(t) - V_{th1}) - C_X \frac{dV_X}{dt} + C_{CX} \frac{V_{dd}}{T_R}$$
(5.49)

This equation is true only if  $V_X(t)$  is a linear function of time since  $V_{in-B}$  is proportional to t. Therefore,

$$\int_{t_{th}}^{t_{xsat}} V_X(t) dt = \frac{1}{2} (t_{xsat} - t_{th}) (V_{dd} - V_{th1} - V_{dsat})$$
(5.50)

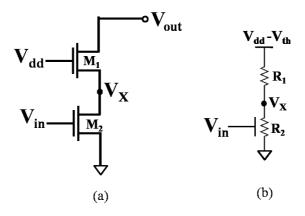


Figure 5.13: (a) Pull Down part of 2-input NAND gate (b) Its equivalent circuit looking at node 'X' when  $M_1$  operates in saturation region and  $M_2$  operates in linear region.

Where,

$$t_{xsat} = \left(\frac{V_{in,sat}}{V_{dd}}\right) T_R \tag{5.51}$$

$$t_{th} = \left(\frac{V_{th}}{V_{dd}}\right) T_R \tag{5.52}$$

Here,  $V_{in,sat}$  represents the rising input voltage at time  $t = t_{xsat}$ . From  $t = t_{xsat}$  to  $T_R$ ,  $M_1$  and  $M_2$  operates in saturation and linear region, respectively.

To find out  $\int_{t_{xsat}}^{T_R} V_X(t) dt$  in (5.45), we show with the help of figure (see Fig. 5.13) that the pull down part of NAND gate in Fig. 5.13 (a) and (b) are equivalent looking from the intermediate node 'X'. Here,  $R_1 = \frac{1}{\beta_{s-M1}}$ . We observe that the current through  $M_1$  is equal in Fig. 5.13 (a) and (b). Therefore, we obtain the value of  $V_X$  from Fig. 5.13 (b) as:

$$V_X = \frac{(V_{dd} - V_{th1})}{1 + \frac{\beta_{l,M2}}{\beta_{s,M1}}(V_{in-B} - V_{th})}$$
(5.53)

Using (5.53), we write the intermediate node voltage as:

$$\int_{t_{xsat}}^{T_R} V_X(t) dt = V_1 T_R \tag{5.54}$$

Where,

$$V_1 = \left[\frac{\beta_{s,M1}}{\beta_{l,M2}} \frac{(V_{dd} - V_{th1})}{V_{dd}} ln \left[\frac{V_{dd}}{V_{in,sat}}\right]\right]$$
(5.55)

Where,  $V_{in,sat}$  is the input voltage,  $V_{in-B}$  at  $t = t_{xsat}$ . In deriving the value of  $V_1$ , we use the following two points:

1. The value of  $V_{in-B}$  at  $t_{xsat}$  is a technology based constant and is independent of values of  $C_l$ ,  $T_R$  and cell size. We now explain the reason for this. The discharge of node 'X' from  $V_{dd} - V_{th1}$  to  $V_{xsat}$  (= $V_{dsat}$  of  $M_2$ ) happens linearly with time with the slope  $1/T_R$  as can be seen from (5.49).

- 2. Therefore, with an increase in  $T_R$ , the time duration of fall in voltage of node 'X' from  $V_{dd} V_{th1}$  to  $V_{xsat}$  is proportional to  $T_R$ . Since this discharge happens for input  $V_{in-B}$ 's value increasing from  $V_{in-B} = V_{th}$  to  $V_{in-B} = V_{insat}$ ,  $V_{insat}$  is independent of  $T_R$ .
- 3. From (5.53), we extracted the value of  $\left(\frac{\beta_{l,M2}}{\beta_{s,M1}}\right)$  and using this value, we find that the term  $\left(1 \frac{\beta_{l,M2}}{\beta_{s,M1}}V_{th}\right) << \frac{\beta_{l,M2}}{\beta_{s,M1}}V_{insat}$  (and therefore  $\frac{\beta_{l,M2}}{\beta_{s,M1}}V_{dd}$ ).

The value of  $\frac{V_{dd}}{V_{insat}}$  in 32nm PTM technology used by us is 1.28  $\left(\frac{V_{dd}}{V_{insat}}=x=1.28\right)$ . Therefore, the higher order terms in  $ln(x) = \left[\left(\frac{x-1}{x}\right) + \frac{1}{2}\left(\frac{x-1}{x}\right)^2 + \ldots\right]$  (valid for  $(x > \frac{1}{2})$ ) can be neglected. Using (5.45), (5.50) and (5.54), we obtain the expression for  $V_{out}(T_R)$  as:

$$V_{out}(T_R) = V_{dd} - \left(\frac{A_{11}T_R}{C_l + C_p}\right)$$
(5.56)

Where,  $A_{11}$  is the constant independent of  $W_n$ :

$$A_{11} = \frac{\beta_{s,M1}}{\beta_{l,M2}} \frac{(V_{dd} - V_{th1})}{V_{dd}} \left(\frac{V_{in,sat}}{V_{dd}} - 1\right)$$
(5.57)

Using the above discussed approach and (5.43), (5.45), (5.50) and (5.54), we get an expression for  $t_{TCP10\%}$  as:

$$t_{TCP10\%} = K_1 C_l + K_2 T_R + K_3 \tag{5.58}$$

Where,

$$K_1 = \frac{(V_{dd} - V_{dsat})}{I_{ON}} + R_{eq}$$
(5.59)

$$K_2 = -\frac{A_{11}}{I_{ON}} \tag{5.60}$$

$$K_3 = \left[\frac{(V_{dd} - V_{dsat})}{I_{ON}} + R_{eq}\right]C_p \tag{5.61}$$

The behavior of model coefficients of (5.58) remain same as of (5.7) with the cell size. As explained earlier, (5.58) is valid if  $V_{out}(T_R) \ge V_{dsat}$ , this imposes the following constraint on the region of validity:

$$\Delta Q(T_R) = (A_{11}T_R) \le (C_l + C_p)(V_{dd} - V_{dsat})$$
(5.62)

Where,  $\Delta Q(T_R)$  is the output discharge from 0 to  $T_R$  and  $V_{dd}$  is the power supply voltage.  $C_p$  is NAND gate's parasitic capacitance (due to gate-drain over-lap, drain-bulk

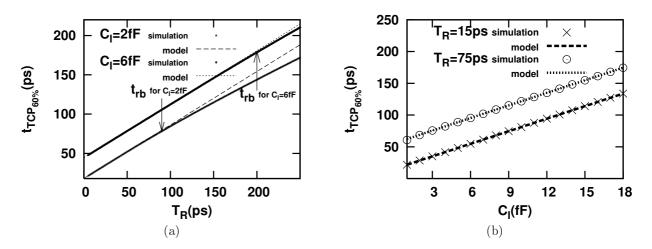


Figure 5.14: Case 2: Variation of  $t_{TCP60\%}$  with respect to  $T_R$  and  $C_l$  values.

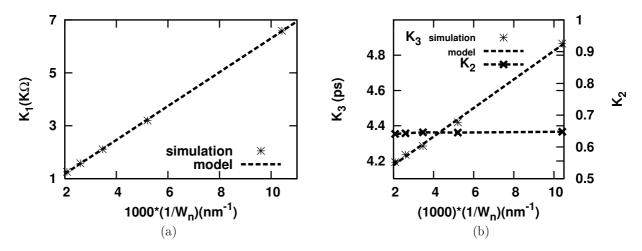


Figure 5.15: Case 2: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with cell size  $(W_n)$ .

junction capacitance etc.) present at the out node, which is a linear function of  $W_n$ . The maximum value of  $T_R$  which satisfies (5.62), will be represented as  $t_{rb}$ .

For all the  $t_{TCPs}$  which fall under Region I, (5.58) remain valid. The model of (5.58) in Region I has thus been verified using HSPICE simulated data. Using curve fitting (as shown in Fig. 5.14) on the simulated values of  $t_{TCP60\%}$ , we extracted the coefficients  $K_1$ ,  $K_2$ ,  $K_3$ of (5.58). We verify the coefficients ( $K_1$ ,  $K_2$  and  $K_3$ ) behavior with  $W_n$  (shown in Fig. 5.15). In this subsection, we observe that our approach in Region I remains valid with variation in cell size.

## 5.6.2 Derivation of the model in Region II

In this subsection, we derive the relationship of  $t_{TCP}s$  with  $T_R$ ,  $C_l$  and cell size for Region II. Region II contains all the TCPs having values  $V_{TCP} > V_{out}(T_R)$ , as we depict in Fig. 5.12b. In this derivation, we consider that the discharging nMOS transistor  $(M_1)$ always operates in velocity saturation (since  $V_{ds}(M_1) > V_{dsat}$ ) and  $M_2$  operates in saturation and linear region depending on the intermediate node voltage  $(V_X)$ , when  $V_{out}(T_R) \geq V_{dsat}$ constraint is followed. We consider that the nMOS transistor  $M_2$  remains in saturation region till  $t = t_{xsat}$ , beyond this  $M_2$  operates in linear region from  $t > t_{xsat}$  to  $t_{TCP}$ . As a representative, we show the simulation results of  $t_{TCP_{90\%}}$ . This is true because  $t_{TCP_{90\%}} < T_R$ in the whole  $T_R$ ,  $C_l$  space used in characterization LUTs. To find the  $t_{TCP90\%}$  which lies in Region II, we proceed as follows:

First, we integrate the saturation current through  $M_1$  from  $t = t_{th}$  to  $t_{TCP}$ . We equate the sum of these integrals to  $(C_l + C_p) (V_{dd} - V_{TCP})$  to obtain the expression for  $t_{TCP}$ . Following the procedure as explained above, we write an expression for the output voltage discharge as:

$$\int_{t_{th}}^{t_{TCP}} I_{M1}dt = (C_l + C_p) \left( V_{dd} - 0.9 V_{dd} \right)$$
(5.63)

Taking L.H.S. and solving it :

$$\int_{t_{th}}^{t_{TCP}} I_{M1}dt = \beta_{s-M1} \int_{t_{th}}^{t_{TCP}} (V_{dd} - V_X(t) - V_{th1}) dt$$
(5.64)

$$=\beta_{s-M1}\int_{t_{th}}^{t_{TCP}} (V_{dd} - V_{th1}) dt - \beta_{s-M1} \left[\int_{t_{th}}^{t_{xsat}} V_X(t) dt + \int_{t_{xsat}}^{t_{TCP}} V_X(t) dt\right]$$
(5.65)

The intermediate node voltage expression remains same as given in (5.50), when lower transistor operates in saturation region (since,  $t_{xsat} < t_{TCP}$ ). From  $t = t_{xsat}$  to  $t_{TCP}$ , we find the expression for  $V_X$  as:

$$\int_{t_{xsat}}^{t_{TCP}} V_X(t) dt = V_1 T_R$$
(5.66)

Where,

$$V_1 = \left[\frac{\beta_{s,M1}}{\beta_{l,M2}} \frac{(V_{dd} - V_{th1})}{V_{dd}} ln \left[\frac{t_{TCP}}{t_{xsat}}\right]\right]$$
(5.67)

The value of  $\frac{t_{TCP}}{t_{xsat}}$  in 32nm PTM technology used by us is 1.33 ( $\frac{t_{TCP}}{t_{xsat}} = x = 1.33$ ). Therefore, the higher order terms in  $ln(x) = \left[\left(\frac{x-1}{x}\right) + \frac{1}{2}\left(\frac{x-1}{x}\right)^2 + \ldots\right]$  (valid for  $(x > \frac{1}{2})$ ) can be neglected. Using (5.65), (5.50) and (5.66), we find the expression for  $t_{TCP90\%}$  as follows:

$$t_{TCP90\%} = A_1 T_R + A_2 + \sqrt{(A_3 T_R + A_2^2)}$$
(5.68)

Where,

$$A_{1} = \left[\frac{1}{2V_{dd}}\left(\frac{V_{th1}}{2} + \frac{V_{in,sat}}{V_{dd}}\frac{\beta_{s,M1}}{\beta_{l,M2}}\right)\right]$$
(5.69)

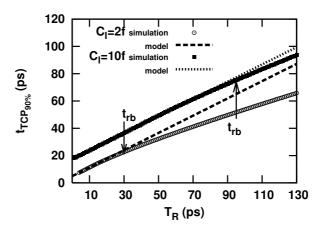


Figure 5.16: Case 2: Variation of  $t_{TCP90\%}$  with respect to  $T_R$ .

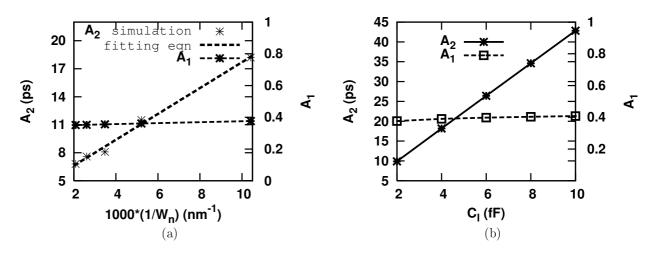


Figure 5.17: Case 2: Variation of  $A_1$  and  $A_2$  with cell size  $(W_n)$  and load capacitance  $(C_l)$ .

$$A_2 = \frac{0.05 \, V_{dd} (C_l + C_p)}{\beta_{s, M1} (V_{dd} - V_{th1})} \tag{5.70}$$

$$A_{3} = \left(\frac{0.05 \left(C_{l} + C_{p}\right)}{\beta_{s,M1}(V_{dd} - V_{th1})}\right) \left[\frac{1}{V_{dd}} \left(\frac{V_{th1}}{2} + \frac{V_{in,sat}}{V_{dd}} \frac{\beta_{s,M1}}{\beta_{l,M2}}\right)\right]$$
(5.71)

For all the  $t_{TCPs}$  which fall under Region II, (5.68) remains valid. The model of (5.68) in Region II has thus been verified using HSPICE simulated data. Using curve fitting (as shown in Fig. 5.16) on the simulated values of  $t_{TCP90\%}$ , we extracted the coefficients  $A_1$ ,  $A_2$ ,  $A_3$  of (5.68).

The following observations have been made from the derivation of (5.68):

- Observation 4:  $A_1$  is independent of  $1/W_n$
- Observation 5:  $A_2$  and  $A_3^2$  are linear function of  $1/W_n$

The model of (5.68) remain valid, if  $V_{out}(T_R) \ge V_{dsat}$ , this imposes the following constraint on the region of validity:

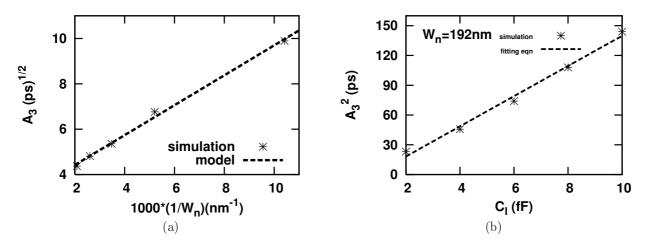


Figure 5.18: Case 2: Variation of  $A_3$  with cell size  $(W_n)$  and load capacitance  $(C_l)$ .

$$\Delta Q(T_R) = (A_{11}T_R) > (C_l + C_p)(V_{dd} - V_{TCP})$$
(5.72)

Please note that the Region II Model can be used to find  $t_{TCPs}$  only if  $T_R > t_{rb}$ , but if  $T_R \leq t_{rb}$  then Region I Model can be used depending on the  $C_l$ ,  $T_R$  values used in characterization of LUT's. Therefore, it saves the maximum number of HSPICE simulations in ECSM (or CCSM) characterization.

In Fig. 5.17-5.18, we verify the coefficient's behavior with  $W_n$  and  $C_l$ .

# 5.6.3 Efficient ECSM Characterization

In this subsection, we use the models derived in Subsection 5.6.1 and 5.6.2 to save the number of HSPICE simulations in ECSM (or CCSM) characterization of 2-input NAND gate standard cell. Using (5.58) and (5.68), within the region of validity, we get the values of all TCPs directly directly from our model, thus, saving upon the characterization effort. On the other hand, the  $t_{TCP}$  values which are out of validity bound in Region I and II, would be obtained from HSPICE simulations. For a 2-input NAND standard cell, we first extract the values of  $K_1$ ,  $K_2$  and  $K_3$  for  $t_{TCP}s$  in Region 1 using 7 HSPICE simulations and  $A_1, A_2, A_3$  using 5 HSPICE simulations. We then calculate the values of  $t_{TCP60\%}$  (entries shown by numeric values in Table 5.4) for  $C_l$ ,  $T_R$  values lying within the region of validity of (5.58). For 2-input NAND gate standard cells of other sizes, all TCPs (within the region of validity of (5.58) and (5.68)) are obtained using Observation 4-6. In Table 5.4,  $t_{TCP}$  values shown by 'HSPICE', it corresponds to the data points (*i.e.*  $t_{TCP60\%}$  values) of  $C_l$ ,  $T_R$  values which are out of region of validity of (5.58). In Table 5.5,  $t_{TCP}$  values are shown which are fully generated through HSPICE simulations. Table 5.6 shows the percentage error in  $t_{TCP}$  values, generated using our approach (described above) with respect to the  $t_{TCP}$ values generated using conventional approach (*i.e.* fully HSPICE generated) for  $TCP_{60\%}$ of 2-input CMOS NAND gate.

We observe that the minimum percentage saving in HSPICE simulations using our

$C_l(fF)$				$T_R(p$	s)		
$O_l(JT)$	2.20	4.84	10.66	23.46	51.62	113.60	250.00
1.51	16.32	18.12	22.07	30.77	49.92	HSPICE	HSPICE
2.28	21.41	23.20	27.16	35.86	55.01	HSPICE	HSPICE
3.45	29.10	30.90	34.85	43.55	62.70	104.85	HSPICE
5.22	40.72	42.52	46.47	55.18	74.33	116.47	HSPICE
7.88	58.29	60.08	64.04	72.74	91.89	134.04	226.79
11.91	84.83	86.63	90.58	99.29	118.44	160.58	253.34
18.00	124.95	126.74	130.70	139.40	158.55	200.70	293.45

Table 5.4: Case 2: LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate using our model.

Note: Entries shown by 'HSPICE' can be obtained by HSPICE simulation whereas entries shown by numeric values are obtained using our model

Table 5.5: Case 2: ECSM LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate obtained using HSPICE simulations.

$C_{i}(fF)$	$T_R(ps)$									
$C_l(fF)$	2.20	4.84	10.66	23.46	51.62	113.60	250.00			
1.51	16.34	18.19	22.18	30.88	49.86	88.59	165.32			
2.28	21.44	23.29	27.29	35.99	55.05	95.27	175.34			
3.45	29.14	30.99	34.99	43.69	62.78	104.15	187.97			
5.22	40.76	42.62	46.62	55.33	74.43	116.27	203.93			
7.88	58.33	60.19	64.19	72.89	92.01	133.93	224.61			
11.91	84.87	86.73	90.73	99.44	118.56	160.54	252.51			
18.00	124.98	126.84	130.8	139.55	158.68	200.69	292.87			

Table 5.6: Case 2: Percentage error in proposed model's LUT with respect to fully HSPICE generated ECSM LUT of  $TCP_{60\%}$  for 2-input CMOS NAND gate.

$C_l(fF)$	$T_R(ps)$								
$C_l(JT)$	2.20	4.84	10.66	23.46	51.62	113.60	250.00		
1.51	0.12	0.38	0.50	0.36	0.12	×	×		
2.28	0.14	0.39	0.48	0.36	0.07	×	×		
3.45	0.14	0.29	0.40	0.32	0.13	0.67	×		
5.22	0.10	0.23	0.32	0.27	0.13	0.17	×		
7.88	0.07	0.18	0.23	0.21	0.13	0.08	0.97		
11.91	0.05	0.12	0.17	0.15	0.10	0.02	0.33		
18.00	0.02	0.08	0.11	0.11	0.08	0.00	0.20		

Note: Entries shown by ' $\times$ ' correspond to the values we obtain using HSPICE simulations in Table 5.4 (not through our models)

method of generating LUTs (as explained above) is 67.35% and 75.51% (for  $7 \times 7$  matrix size) for  $TCP_{60\%}$  and  $TCP_{90\%}$ , respectively. We find that the values of  $t_{TCP}s$  in our LUTs differ by a maximum of 0.97% (for  $7 \times 7$  matrix size) from those in fully HSPICE generated conventional LUTs. Therefore, we observe that standard cell characterization can be done with a significantly lesser number of HSPICE simulations (approximately 67% reduction in HSPICE simulations). For the  $t_{TCP} < T_R$ , both the Region I and II models are used.

# 5.7 Case 2: Variation aware TCP models

In this section, we consider layout dependent effects due to mechanical stress in deriving the model coefficients. We also derive the relationships of the model coefficients with the temperature (T) and supply voltage  $(V_{dd})$ . We have already discussed the motivation towards the analysis of variation aware (considering process induced mechanical stress, supply voltage and temperature variability) TCP models in Chapter 4 of the thesis. Here, we derive and validate the behavior of model coefficients with PVT variations. Later, we use the model and the derived relationships to reduce the number of HSPICE simulations significantly.

## 5.7.1 TCP models considering stress variability

In this subsection, we derive the change in model coefficients of (5.58) and (5.68) as a function of NF in a stress enabled 45nm CMOS technology. We follow the same procedure, as we did in Section 5.5.1.

#### 5.7.1.1 Impact of stress induced variability in Region I

In this sub-subsection, we derive the relationship of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and NF for Region I and II in stress enabled technologies. In (5.59)-(5.61) and (5.69)-(5.71),  $\mu$ ,  $v_{sat}$ ,  $I_{ON}$ , and  $V_{th}$  are now stress dependent values, given as (5.21)-(5.24). We derive the model for  $t_{TCP60\%}$  considering the impact of channel stress in Region I. We assume that  $(V_{dd} - V_{th})$  is independent of NF (as explained in Subsection 5.5.1). Using the stress dependent parameters in (5.59)-(5.61) (as we told earlier), we obtain the relation between model coefficients and NF as:

$$K_1 = (NF + M_3) \left(\frac{D_1}{NF + D_2}\right)$$
 (5.73)

Where,  $D_1$  and  $D_2$  are the technology dependent constants, given in Subsection 5.5.1 as:

$$D_1 = \frac{(V_{dd} - V_{dsat})}{((M_1 P_1 P_2 + 1) I_{ON})}$$
(5.74)

$$D_2 = M_3 + \frac{M_2 P_1 P_2}{(M_1 P_1 P_2 + 1)}$$
(5.75)

We observe that (5.73) fits well with HSPICE simulated data as shown in Fig. 5.19a. In

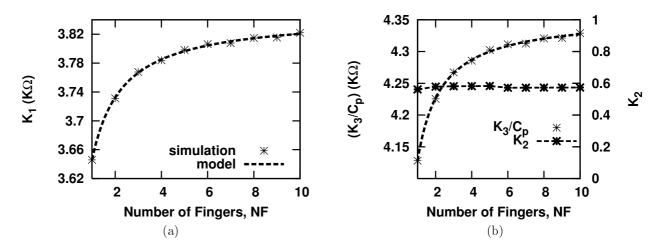


Figure 5.19: Case 2:  $K_1$ ,  $K_2$  and  $K_3$  as a function of NF (which also represents to channel stress).

these HSPICE simulation MULU0 and DELVT0 vary with NF in accordance with (5.25) (*i.e.* the PTM model incorporates channel stress variability effects). From (5.61), the relation between  $K_3$  and NF is:

$$K_{3} = C_{p}(K_{1}) = C_{p}\left[(NF + M_{3})\left(\frac{D_{1}}{NF + D_{2}}\right)\right]$$
(5.76)

We observe that (5.76) fits well with HSPICE simulated data as shown in Fig. 5.19b. Thereafter, we observe that  $K_2$  is independent of NF (because  $A_{11}$  and  $I_{ON}$  are both proportional to NF) as shown in Fig. 5.19b.

#### 5.7.1.2 Impact of stress induced variability in Region II

In this sub-subsection, we derive a model for  $t_{TCP90\%}$ , considering the impact of channel stress in Region II. Using stress dependent parameters in (5.69) and (5.25), we obtain that  $A_1$  is independent of  $V_{th}(\sigma)$ . Where,  $V_{th}(\sigma)$  with NF is negligibly small [94]. Therefore,  $A_1$  is independent of  $\sigma(NF)$  as shown in Fig. 5.20a. Using stress dependent parameters in (5.70) and (5.25), We find the relationship between  $A_2$  and NF as:

$$A_2 = \left(\frac{S_1(NF + M_3)}{(NF + S_2)}\right)$$
(5.77)

Where,

$$S_1 = \frac{1}{(M_1 P_1 + 1)} \left( \frac{0.05 \, V_{dd}(C_l + C_p)}{\beta_{s, M1}(V_{dd} - V_{th1})} \right)$$
(5.78)

$$S_2 = \left(M_3 + \frac{P_1 M_2}{(M_1 P_1 + 1)}\right) \tag{5.79}$$

We observe that (5.77) fits well on our stress aware HSPICE simulation data as shown in Fig. 5.20a. Likewise, from (5.71) and (5.25), We find the relationship between  $A_3$  and NF as:

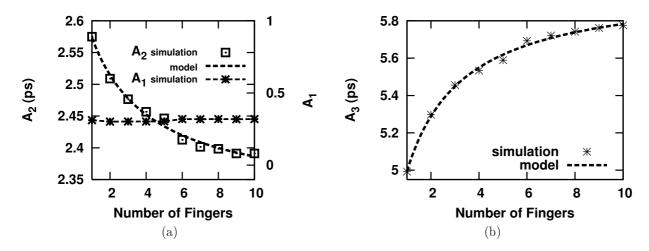


Figure 5.20: Case 2:  $A_1$ ,  $A_2$  and  $A_3$  as a function of NF.

$$A_3 = \left(\frac{S_3(NF + M_3)}{(NF + S_2)}\right)$$
(5.80)

Where,

$$S_{3} = \frac{1}{(M_{1}P_{1}+1)} \left( \frac{0.05 \, V_{dd}(C_{l}+C_{p})}{\beta_{s,\,M1}(V_{dd}-V_{th1})} \right) \left[ \frac{1}{V_{dd}} \left( \frac{V_{th1}}{2} + \frac{V_{in,sat}}{V_{dd}} \frac{\beta_{s,\,M1}}{\beta_{l,\,M2}} \right) \right]$$
(5.81)

We observe that (5.80) fits well on our stress aware HSPICE simulation data as shown in Fig. 5.20b.

#### 5.7.1.3 Efficient stress aware ECSM characterization

In this sub-subsection, we make use of relationships of model coefficients with stress as a function of NF, derived in previous sub-subsection (as described in Subsection 5.5.1) to reduce the number of HSPICE simulations required for ECSM characterization when the lower input of the series nMOS stack of 2-input NAND gate standard cell switches. The LUT size is  $7 \times 7$  matrix. Using our model (5.58) for  $V_{TCP} < V_{out}(T_R)$ , 47 HSPICE simulations and using model (5.58) and (5.68) for  $V_{TCP} > V_{out}(T_R)$  only 14 HSPICE simulations, were needed to generate the LUT, whereas a conventional procedure would require 343 HSPICE simulations. Saving in number of HSPICE simulations using Region I model (for  $V_{TCP} < V_{out}(T_R)$ ) is  $\simeq 86\%$  and using both the models corresponding to Region I and II (for  $V_{TCP} > V_{out}(T_R)$ ) is 96% (compared to conventional approach).

## 5.7.2 TCP models considering temperature variability

In this subsection, we derive the temperature variation aware  $t_{TCP}$  models, which we later use to reduce the re-characterization effort significantly. In this work, we consider a realistic range of temperature variation due to on-chip heating, from 298K (room temperature) to 423K.

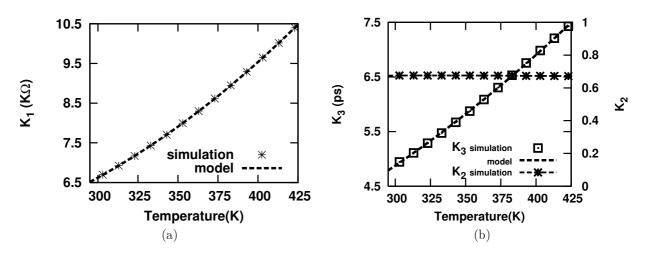


Figure 5.21: Case 2: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with temperature.

#### 5.7.2.1 Impact of temperature variability in Region I

In this sub-subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and temperature (T) for Region I and II. In (5.59)-(5.61) and (5.69)-(5.71),  $v_{sat}$ ,  $\mu$  and  $V_{th}$  are now given by (5.34)-(5.36). We derive a model for  $t_{TCP60\%}$ , considering the impact of temperature variability in Region I. In this derivation, we assume that  $(V_{dd} - V_{th})$  is independent of T. This is justified since  $V_{th}$  is much smaller than  $V_{dd}$ . From (5.59)-(5.61), we obtain :

$$K_1 = \left(R_1 T^{2.3} + R_2 T + R_3\right) \tag{5.82}$$

Where  $R_1$ ,  $R_2$  and  $R_3$  are technology dependent constants obtained after deriving the (5.59) using temperature dependent parameters. We observe that (5.82) fits well on HSPICE simulated data as shown in Fig. 5.21a. Likewise solving (5.61), we find the relation between  $K_3$  and T as:

$$K_3 = C_p K_1 = C_p \left( R_1 T^{2.3} + R_2 T + R_3 \right)$$
(5.83)

We observed using HSPICE simulations that change in  $C_p$  with T varying from 298K to 423K is negligibly small. We observe that (5.83) fits well with HSPICE simulated data as shown in Fig. 5.21b. Thereafter, solving (5.60), we find that  $K_2$  is independent of T as shown in Fig. 5.21b (because  $A_{11}$  and  $I_{ON}$  both are the function of T).

#### 5.7.2.2 Impact of temperature variability in Region II

We derive a model for  $t_{TCP90\%}$ , considering the impact of temperature variability in Region II. From (5.69), we observe that  $A_1$  is independent of T. From (5.70), we obtain that  $A_2$  is proportional to T, which we verify through HSPICE simulations in Fig. 5.22a. We obtain the relationship between  $A_2$  and T as:

$$A_2 = (R_4 T + R_5) \tag{5.84}$$

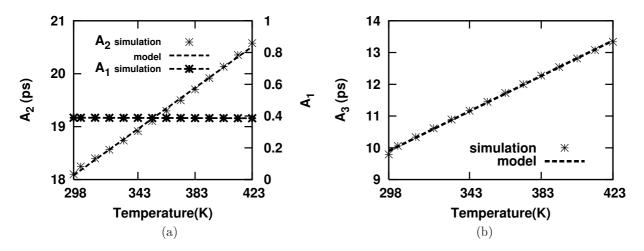


Figure 5.22: Case 2: Variation of  $A_1$ ,  $A_2$  and  $A_3$  with temperature.

Where,  $R_4$  and  $R_5$  are technology dependent constants obtained after deriving the (5.70). We observe that (5.84) fits well on our HSPICE simulation data with temperature variability as shown in Fig. 5.22a. Likewise, solving (5.71), we find that  $A_3$  increases linearly with T as shown in Fig. 5.22b.

#### 5.7.2.3 Efficient temperature variation aware ECSM characterization

In this sub-subsection, we use the relationships of model coefficients with temperature, to reduce the number of HSPICE simulations required for ECSM characterization, when the lower input of the series nMOS stack of 2-input NAND gate standard cell switches. The LUT size is  $7 \times 7$  matrix. Using our model (5.58) for  $V_{TCP} < V_{out}(T_R)$ , 50 HSPICE simulations and using model (5.58) and (5.68) for  $V_{TCP} > V_{out}(T_R)$  only 13 HSPICE simulations, were needed to generate the LUT, whereas a conventional procedure would require 343 HSPICE simulations. Saving in number of HSPICE simulations using Region I model (for  $V_{TCP} < V_{out}(T_R)$ ) is  $\simeq 85\%$  and using both the models corresponding to Region I and II (for  $V_{TCP} > V_{out}(T_R)$ ) is 96% (compared to conventional approach).

# 5.7.3 TCP models considering Supply Voltage Variability

In this subsection, we derive a power supply voltage variation aware  $t_{TCP}$  models, which we later use to reduce the re-characterization effort significantly. We consider the  $\pm 10\%$ change in power supply voltage  $(V_{dd})$  from the its nominal value of  $V_{dd} = 0.9V$ .

#### 5.7.3.1 Impact of supply voltage variability in Region I

In this sub-subsection, we derive the relationships of  $t_{TCPs}$  with  $T_R$ ,  $C_l$  and  $V_{dd}$  for Region I. We derive a model for  $t_{TCP60\%}$ , considering the impact of supply voltage variability in Region I. In (5.59), we observe and later verify that  $K_1$  decreases with an increase in supply voltage as shown in Fig. 5.23a.

We now discuss the variation of  $K_3$  with  $V_{dd}$ . From (5.61), we observe that the behavior of  $K_3$  with supply voltage remains same as of  $K_1$ . We verify this observation in Fig. 5.23b.

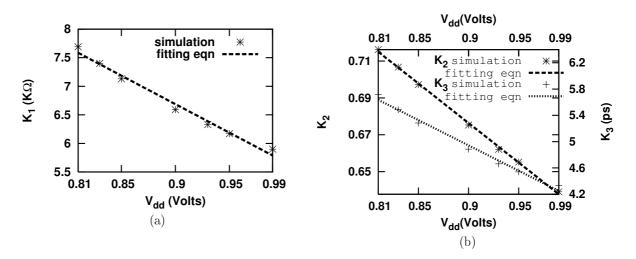


Figure 5.23: Case 2: Variation of  $K_1$ ,  $K_2$  and  $K_3$  with supply voltage.

In (5.60), we observe that  $K_2$  is inversely proportional to  $V_{dd}$ . We verify this observation in Fig. 5.23b.

#### 5.7.3.2 Impact of supply voltage variability in Region II

In this sub-subsection, we derive a model for  $t_{TCP90\%}$ , considering the impact of supply voltage variability in Region II. In (5.69),  $A_1$  is inversely proportional to supply voltage and it is verified through HSPICE simulations as shown in Fig. 5.24a. In (5.70) and (5.71), we observe that  $A_2$  and  $A_3$  both decreases with supply voltage. We verify this observation in Fig. 5.24b and 5.24c.

#### 5.7.3.3 Efficient supply voltage variation aware ECSM characterization

In this sub-subsection, we use the relationships of model coefficients with supply voltage, to reduce the number of HSPICE simulations required for ECSM characterization, when the lower input of the series nMOS stack of 2-input NAND gate standard cell switches. The LUT size is  $7 \times 7$  matrix. Using our model (5.58) for  $V_{TCP} < V_{out}(T_R)$ , 48 HSPICE simulations and using model (5.58) and (5.68) for  $V_{TCP} > V_{out}(T_R)$  only 14 HSPICE simulations, were needed to generate the LUT, whereas a conventional procedure would require 343 HSPICE simulations. Saving in number of HSPICE simulations using Region I model (for  $V_{TCP} < V_{out}(T_R)$ ) is  $\simeq 86\%$  and using both the models corresponding to Region I and II (for  $V_{TCP} > V_{out}(T_R)$ ) is 96% (compared to conventional approach).

# 5.8 Summary

In this chapter, we proposed models for  $t_{TCPs}$  of output voltage transition for 2-input NAND gate standard cell, for Case 1 and 2. First, we derived the model for the switching of upper nMOS transistor in the series stack of the NAND gate (represented as Case 1), second, we derived the model for the switching of lower nMOS transistor in the series stack of the NAND gate (represented as Case 2). In this work, we considered the impact of the voltage transition at the intermediate node in the series stack of nMOS transistors in the

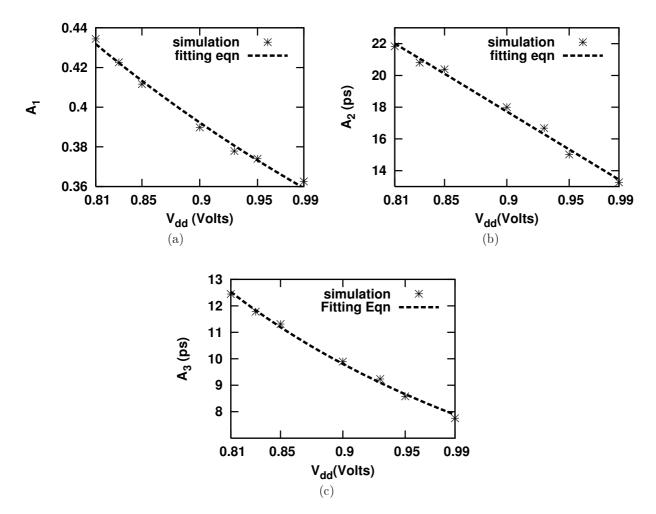


Figure 5.24: Case 2: Variation of  $A_1$ ,  $A_2$  and  $A_3$  with supply voltage.

NAND gate. The  $t_{TCP}$  values are derived in terms of  $T_R$  and  $C_l$ . We also derived the region of validity of these models in  $C_l$ ,  $T_R$  space. Later, we used these models in reducing the number of HSPICE simulations in ECSM characterization of 2-input NAND gate standard cell by  $\approx 67\%$ . We also derived the relationship of the model coefficients with the NAND gate size,  $V_{dd}$ , carrier mobility, threshold voltage and temperature. While considering layout dependent effects due to mechanical stress, we derived the relationship of the model coefficients with stress as a function of NF. We later used these relationships to reduce the number of HSPICE simulations by about 80.18% and 86% in ECSM characterization of a 2-input NAND gate standard cell having a different value of NF for Case 1 and 2, respectively. Further, we included the effect of temperature variation in our  $t_{TCP}$  models to reduce the number of HSPICE simulations by  $\simeq 79.88\%$  for Case 1 and 85% for Case 2. We also included the effect of supply voltage variation in our  $t_{TCP}$  models to reduce the number of HSPICE simulations by  $\simeq 79.88\%$  for Case 1 and 85% for Case 2.

We thus proposed the comprehensive models capturing all the timing information regarding the output transition of a 2-input NAND gate for the switching of one of its inputs. These models relate all the  $t_{TCP}s$  with circuit/layout level parameters such as  $T_R$ ,  $C_l$ ,  $W_n$ , NF, T and  $V_{dd}$ . We also derived the region of validity of these models with respect to each of these circuit/layout level parameters. Further, we apply all this work in reducing the number of HSPICE simulations required for ECSM characterization of 2-input NAND gate significantly (about 67-96%).

# Chapter 6

# Overshoot Timing Model for CMOS Inverter and NAND Gate Standard Cells

# 6.1 Overview

In this chapter, we propose an analytical model to estimate overshoot time for CMOS inverter and NAND gate standard cells. We separately model the over-shoot time period for switching of each of the inputs of a 2-input NAND gate standard cell. We observe that the duration of the overshoot is significantly (about 40%) larger for NAND gates compared to inverter for a given fan-out for the case when the lower nMOS device in the series stack switches. To model the overshoot time period for this case, we show that considering the impact of the intermediate node of nMOS series stack is critical. Therefore, we first model the voltage transition at this node in our work, which we further use to derive overshoot time period for the lower transistor switching case. We observe and explain that the overshoot timing model of a CMOS inverter remains valid for the case when the upper nMOS device in the series stack is ON and only adds a resistance to the source of the upper nMOS device. The model also considers the influence of  $T_R$ ,  $C_l$  and cell size on overshoot time which makes it useful in standard cell characterization. The proposed model is in good agreement with HSPICE simulations with a maximum error of 2.5%.

The chapter is organized as follows. In Section 6.2, we describe our simulation setup. In Section 6.3, we derive the relationship of overshoot time  $(t_{crit})$  with  $T_R$ ,  $C_l$  for CMOS inverter standard cell. We then verify the model with respect to  $T_R$ ,  $C_l$  values and cell size of CMOS inverter. In Section 6.4, we derive the relationship of  $t_{crit}$  with  $T_R$ ,  $C_l$  for 2-input NAND gate standard cell. We then verify the model with respect to  $T_R$ ,  $C_l$  values and cell size of NAND gate.

# 6.2 Simulation Setup

In this Chapter, we use HSPICE simulations at 32nm CMOS technology node. In these simulations, we use BSIM 4.0 Predictive Technology device Model (PTM) [87]. We use a CMOS inverter (shown in Fig. 6.1a) and a 2-input NAND gate standard cells (shown in Fig. 6.2a) for the overshoot timing model derivation. The widths of pMOS transistor and those of nMOS transistors are kept in such a way that the output rising and falling transition times are equal for both inverter and NAND gate standard cells as described in [22]. The minimum transistor widths for inverter and NAND gate standard cells are  $W_p/W_n = \frac{120nm}{48nm}$ and  $W_p/W_n = \frac{120nm}{96nm}$ , respectively. The channel lengths are kept at their minimum allowed value for all the transistors (*i.e.* 32nm). Since the  $W_p/W_n$  ratio for standard cell of a given type (say, 2-input NAND gate are fixed), the value of  $W_n$  also represents the cell size. Throughout this work, we consider the case of rising input transition: The case of falling input transition can be handled in similar manner. Please note that we have not considered

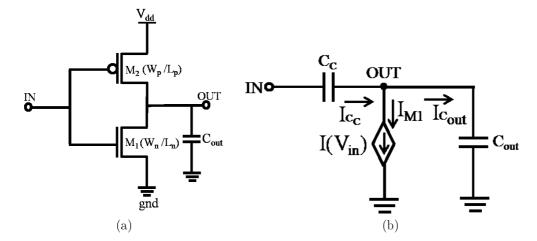


Figure 6.1: (a) CMOS inverter schematic (b) its equivalent circuit during overshoot period.

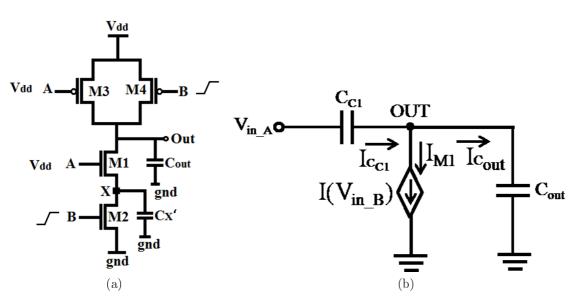


Figure 6.2: (a) 2-input NAND gate Schematic (b) its equivalent circuit during overshoot period.

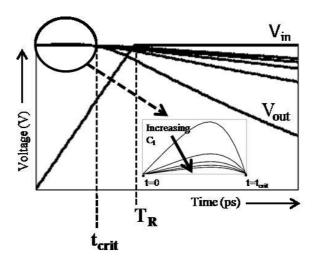


Figure 6.3: I/O waveform of standard cell CMOS inverter.

the inverse narrow width effects in the proposed work. Since, the threshold voltage  $V_{th}$  is the parameter considered in the derivation, narrow width effects can be considered in the model.

# 6.3 Our approach towards CMOS inverter overshoot modeling

To derive the overshoot time for CMOS inverter standard cell (shown in Fig. 6.1), we use the following assumptions and observations :

- The pMOS transistor  $(M_2)$  is operating in deep triode region and negligibly small current is flowing through it (*i.e.*  $\approx 5\mu A$ ). Therefore, we ignore this negligible pMOS current in our derivation.
- The time at which the overshoot reaches its peak value  $V_p$ , is  $t_p$ . We assume that  $t_p = \frac{V_{th}}{V_{dd}}T_R$ , because the nMOS device  $(M_1)$  is in OFF state for  $V_{in} < V_{th}$ . The increase in output voltage till this time is only because of capacitive coupling between nodes IN and OUT. Therefore,  $t_p$  is also independent of  $C_l$  and  $W_n$ . This assumption is validated by our results that we discuss later in the paper.
- We observe from HSPICE simulations that the overshoot period  $t_{crit}$  is independent of  $C_l$  (as shown in Fig. 6.3). We explain this as follows:

For a given value of  $T_R$ , the charging current through the coupling capacitance  $C_C$  during the input transition t = 0 to  $T_R$  has a value  $C_C \frac{V_{dd}}{T_R}$ , therefore the total charge that contributes to the overshoot at the output is independent of  $C_l$  and  $T_R$ . This charge is now discharged through the nMOS such that  $V_{out}$  reduces to a value  $V_{out} = V_{dd}$ . During the discharge of the overshoot the nMOS operates in saturation region and therefore, its drain current is independent of the value of  $V_{out}$  (this is also because, the  $V_{ds}$  of nMOS almost doesn't vary and has a value  $V_{out} \approx V_{dd}$  during the overshoot period).

# 6.3.1 Model for Overshoot Time $t_{crit}$

In this subsection, we derive the relationship between  $t_{crit}$  and  $T_R$ ,  $C_l$  values. We consider the rising input transition for the derivation of overshoot time (shown in Fig. 6.3). As we explained earlier that  $t_p$  is the time after which transistor  $M_1$  starts to conduct. Till  $t_p$ , there will be only capacitive coupling at 'OUT' node. To find the  $t_p$ , we apply KCL at node 'OUT'. Therefore, we have the expression:

$$I_{C_C} = I_{C_{out}} + I_{M_1} \tag{6.1}$$

 $I_{C_C}$  is current flowing through gate-to-drain capacitance of  $M_1$  and  $M_2$ , since  $M_1$  is operating either in cut-off (for  $t < t_p$ ) or in saturation for  $(t \ge t_p)$ , it consists of the overlap capacitance component only. Whereas, since  $M_2$  operates in linear region during the overshoot period so its gate-to-drain overlap capacitance consists of both channel and overlap components.  $I_{C_{out}}$  is current flowing through the load capacitance and parasitic capacitance (other than  $C_C$ ) at the output node.  $I_{M_1}$  is the saturation current flowing through  $M_1$  which is non-zero for  $t \ge t_p$ . Therefore, we have an equivalent circuit as shown in Fig. 6.1b. At  $t = t_p$  solving KCL at node 'OUT', we rewrite (6.1) as:

$$C_C \frac{dV_{in}}{dt} = I_{M_1} \text{where } V_{in} = V_{dd} \frac{t}{T_R} \text{for } 0 \le t \le T_R$$
(6.2)

And,  $I_{M_1}$  is given by alpha power law model as [9]:

$$I_{M1} = I_{ON} = \nu_{sat} W_n P_s (V_{gs} - V_{th})^m \tag{6.3}$$

We assume  $\beta_s = \nu_{sat} W_n P_s$ , where  $\nu_{sat}$  is saturation velocity,  $W_n$  is width of nMOS device,  $P_s$  is technology dependent parameter and exponent m is velocity saturation index. In our case, we have used m = 1 and it is verified through HSPICE simulations. Solving (6.2), we get an expression for  $t_p$  as follows:

$$t_p = \frac{C_C}{\beta_s} + \frac{V_{th}}{V_{dd}} T_R \tag{6.4}$$

To obtain the  $t_{crit}$ , we first integrate (6.1) from 0 to  $t_p$  and find an expression as follows:

$$C_C \frac{V_{dd}}{T_R} (t_p - 0) = (C_{out} + C_C)(V_p - V_{dd}) + \int_0^{t_p} I_{M1} dt$$
(6.5)

Where,  $\int_0^{t_p} I_{M1} dt \simeq 0$  as we explained earlier that from 0 to  $t_p$  negligibly small current

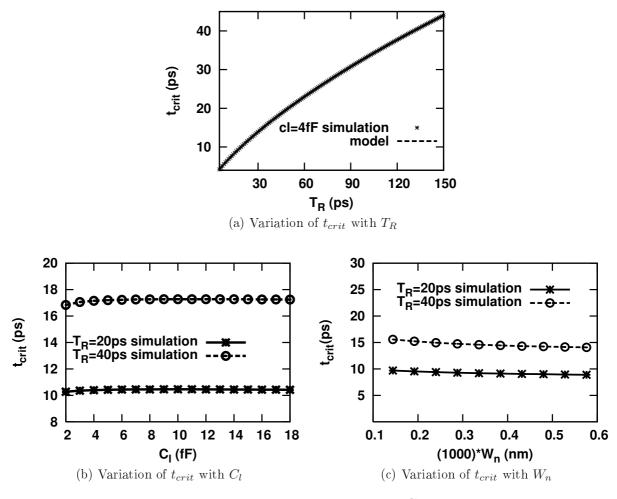


Figure 6.4: Variation of  $t_{crit}$  with  $T_R$ ,  $C_l$  and  $W_n$ .

is flowing. Now, we integrate (6.1) from  $t_p$  to  $t_{crit}$  and find an expression as follows:

$$C_C \frac{V_{dd}}{T_R} (t_{crit} - t_p) = -(C_{out} + C_C)(V_p - V_{dd}) + \int_{t_p}^{t_{crit}} I_{M1} dt$$
(6.6)

Using (6.3), (6.4), (6.5) and (6.6), we get final expression for  $t_{crit}$  as follows:

$$t_{crit} = \left(\frac{C_C}{2\beta_s} + \frac{V_{th}}{V_{dd}}T_R\right) + \sqrt{\left(\frac{5C_C^2}{4\beta_s^2} + \frac{C_C}{\beta_s}\frac{V_{th}}{V_{dd}}T_R\right)}$$
(6.7)

We observe that the  $t_{crit}$  is independent of  $C_l$  and  $W_n$  from the derivation of (6.7). The later is because both  $C_c$  and  $\beta_s$  are proportional to  $W_n$ .

The model of (6.7) has been verified using HSPICE simulation data as shown in Fig. 6.4. As observed in (6.7), the coefficients of the model are the constants for a given CMOS technology and can be extracted from HSPICE simulations/measurements. Once these coefficients are extracted, (6.7) can be used to obtain  $t_{crit}$  for any value of  $T_R$  and inverter cell size. The (6.7) can therefore be used in standard cell library characterization to obtain overshoot time period.

# 6.4 NAND gate overshoot modeling

In this section, we derive the relationships of  $t_{crit}$  with  $T_R$ ,  $C_l$  values and  $W_n$  for a 2-input NAND gate standard cell. We derive the models for the case where input is rising, a similar approach can be used for falling input transition case too. Since typically single input switching would be more frequent compared to multiple input switching, we consider single input switching for our derivation. There are two possibilities for 2-input NAND gate single input switching.

- Case 1: When  $V_{in-B} = V_{dd}$  and  $V_{in-A} = V_{dd} \frac{t}{T_R}$  (for  $0 \le t \le T_R$  *i.e.* when upper nMOS device  $(M_1)$  in the series stack switches) (refer to Fig. 6.5a)
- Case 2: When  $V_{in-A} = V_{dd}$  and  $V_{in-B} = V_{dd} \frac{t}{T_R}$  (for  $0 \le t \le T_R$  *i.e.* when lower nMOS device  $(M_2)$  in the series stack switches) (refer to Fig. 6.7a)

We derive the model of  $t_{crit}$  for the above 2 cases of 2-input NAND gate in the following subsections.

# 6.4.1 NAND gate overshoot modeling for Case 1

To derive the model of  $t_{crit}$  for 2-input NAND gate (for Case 1) standard cell, shown in Fig. 6.5, we use the following assumptions and observations :

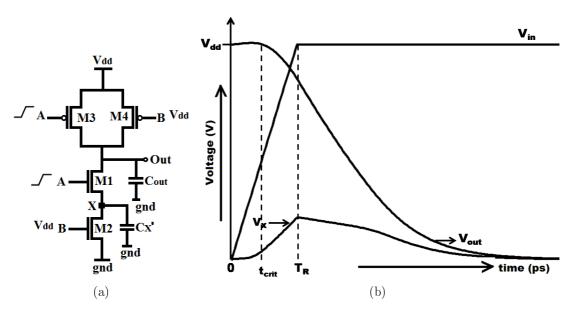


Figure 6.5: Case 1: (a) NAND gate schematic (b) its I/O waveform.

- The pMOS transistor  $(M_4)$  is in OFF state whereas  $M_3$  is in deep triode region and negligibly small current is flowing through it. Therefore, we ignore this negligible pMOS current in our derivation.
- The nMOS transistor  $M_1$  will be ON at  $\frac{V_{th1}}{V_{dd}}T_R$  whereas  $M_2$  is in deep triode region during overshoot period.
- Expression for  $t_{crit}$  remains same as for CMOS inverter (given in (6.7)), because in Case 1 behavior of NAND gate remains same as of CMOS inverter except that the lower nMOS transistor in the series stack adds some resistance to the source of upper nMOS transistor.

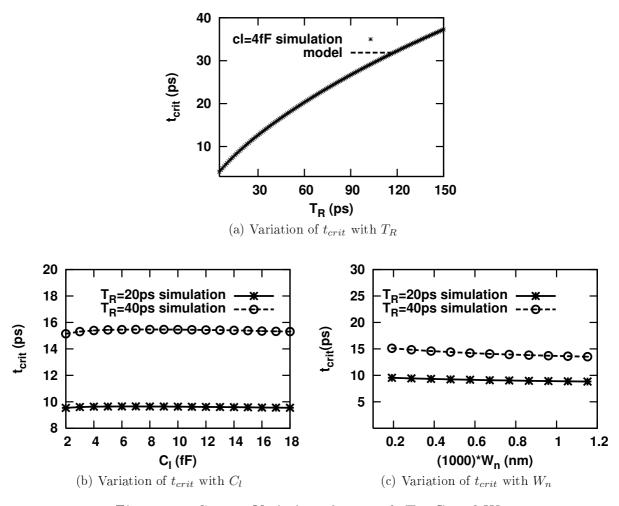


Figure 6.6: Case 1: Variation of  $t_{crit}$  with  $T_R$ ,  $C_l$  and  $W_n$ .

The proposed model of (6.7) for  $t_{crit}$  has been verified using HSPICE simulated data for Case 1. Figure 6.6 shows the verification of  $t_{crit}$  model with respect to  $T_R$ ,  $C_l$  values and cell size for Case 1 of NAND gate.

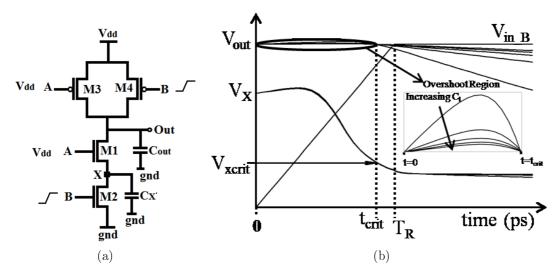


Figure 6.7: Case 2: NAND gate schematic and its I/O waveform.

#### 6.4.2 NAND gate overshoot modeling for Case 2

To derive the model of  $t_{crit}$  for 2-input NAND gate (for Case 2), shown in Fig. 6.5, we use the following assumptions and observations :

- The pMOS transistor  $(M_3)$  is in OFF state whereas  $M_4$  is in linear region and negligibly small current is flowing through it. Therefore, we ignore that negligible pMOS current throughout overshoot modeling.
- Threshold voltage of  $M_1$  is always somewhat larger than  $M_2$ , because of potential difference between source and bulk of  $M_1$  (*i.e.*  $V_{sb(M1)} \neq 0$ ).
- The nMOS transistor  $M_2$  will be ON at  $t = \frac{V_{th}}{V_{dd}}T_R$  whereas  $M_1$  starts to conduct later for a technology dependent value of  $V_X = V_{Xa}$ .  $V_{Xa}$  is the value of the source voltage of an nMOS of the the given CMOS technology having its  $V_g = V_d = V_{dd}$ .
- In this work,  $V_X = V_{Xa}$  at time  $t = t_{Xa}$ . Till  $t_{Xa}$ , current through  $M_1$  is almost zero. And output voltage will be increased by capacitive coupling only. When  $t \ge t_{Xa}$ , current starts to flows through  $M_1$  and then equivalent circuit of NAND can be represented as shown in Fig. 6.2b.
- Overshoot time (denoted as  $t_{crit}$  in our case) is independent of  $C_l$  as shown in Fig.6.8. We explain this as follows:

For a given value of  $T_R$ , the charging current through the coupling capacitance  $C_{C1}$  during the input transition t = 0 to  $T_R$  has a value  $C_{C1} \frac{V_{dd}}{T_R}$ , therefore the total charge that contributes to the overshoot at the output is independent of  $C_l$  and  $T_R$ . This charge is now discharged through the nMOS such that  $V_{out}$  reduces to a value  $V_{out} = V_{dd}$ . During the discharge of the overshoot the nMOS operates in saturation region and therefore its drain

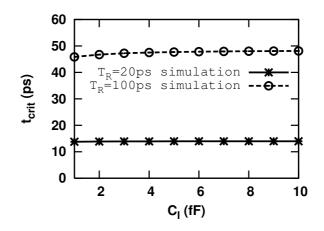


Figure 6.8: Case 2:  $t_{crit}$  is independent of  $C_l$ .

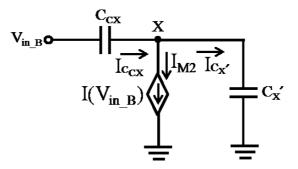


Figure 6.9: Case 2: NAND gate equivalent circuit at node 'X'.

current is independent of the value of  $V_{out}$  (this is also because of the value  $V_{ds}$  of nMOS almost doesn't vary and has a value  $V_{out} \approx V_{dd}$  during the overshoot period). To derive the  $t_{crit}$  model, first we need to model the  $t_{Xa}$ .

#### 6.4.2.1 Proposed Model for $t_{Xa}$

In this sub-subsection, we derive the relationship between  $t_{Xa}$  and  $T_R$ ,  $C_l$  values. To find the  $t_{Xa}$ , we apply KCL at 'X' node for  $t < t_{Xa}$  (refer to Fig. 6.9):

$$I_{C_{CX}} + I_{M2} = I_{C_X} \tag{6.8}$$

 $I_{C_{CX}}$  is current flowing through gate-to-drain coupling capacitance of  $M_2$ , it consists of the gate-to-drain overlap capacitance and may also consist a part of the gate-to-channel capacitance (as we elaborate later in this paper). We use the symbol  $C'_X$  for the parasitic capacitance (of  $M_1$  and  $M_2$ ) between node 'X' and 'gnd'.  $I_{C'_X}$  is current flowing out of this parasitic capacitance. And  $I_{M_2}$  is saturation current flowing through  $M_2$  given in (6.3).

Now, we rearrange (6.8) as:

$$C_{CX}\frac{dV_{in-B}}{dt} + I_{M2}(t) = (C'_X + C_{CX})\frac{dV_X}{dt}$$
(6.9)

Where,

$$V_{in-B} = V_{dd} \left(\frac{t}{T_R}\right) \text{ for } 0 \le t \le T_R$$
(6.10)

In this derivation, we are taking  $(C'_X + C_{CX}) = C_X$ , to simplify the expression. To find the  $t_{Xa}$ , integrate (6.9) from  $t = t_{th}$  to  $t_{Xa}$ . Where  $t_{th}$  is time at which lower nMOS transistor  $M_2$  starts to conduct (*i.e.*  $t_{th} = \frac{V_{th}}{V_{dd}}T_R$ , when  $V_{in-B}=V_{th}$ ). Before  $t_{th}$ , node 'X' gets charged only through capacitive coupling as  $M_1$  and  $M_2$  are both OFF. At  $t = t_{th}$ , value of  $V_X$  is given as :

$$V_{Xth} - V_{X0} = \left(\frac{C_{CX}}{C_X}\right) V_{th} \tag{6.11}$$

Where,  $V_{Xth}$  is voltage at node 'X' when  $V_{in-B}$  reaches threshold voltage of  $M_2$  and  $V_{X0}$  is the voltage at node 'X' when t = 0 (since,  $V_{X0} \approx V_{dd} - V_{th}$ ). Using (6.3), (6.10), (6.11) and solve for  $t_{Xa}$  by integrating (6.9), we have the expression as:

$$\left(\frac{C_{CX}}{C_X}\frac{V_{dd}}{T_R} + \frac{\beta_{M2}V_{th}}{C_X}\right)(t_{Xa} - t_{th}) - \left(\frac{\beta_{M2}V_{dd}}{2C_XT_R}\right)(t_{Xa}^2 - t_{th}^2) + \left(\frac{C_{CX}}{C_X}V_{th} + \Delta V_{Xa}\right) = 0 \quad (6.12)$$

Where,

$$(V_{Xa} - V_{Xth}) = \{(V_{Xa} - V_{X0}) - (V_{Xth} - V_{X0})\} = \left(\triangle V_{Xa} - \frac{C_{CX}}{C_X}V_{th}\right)$$
(6.13)

Where,  $\Delta V_{Xa} = -(V_{Xa} - V_{X0})$  is a positive value since  $V_{Xa} < V_{X0}$ . After solving (6.12), we get the final equation of  $t_{Xa}$  as:

$$t_{Xa} = \frac{C_{CX}}{\beta_{M2}} + \frac{V_{th}}{V_{dd}}T_R + \sqrt{\left[\frac{C_{CX}}{\beta_{M2}}\left(\frac{C_{CX}}{\beta_{M2}} + \left(\frac{6\,V_{th}}{V_{dd}} + \frac{2\,\triangle V_{Xa}}{V_{dd}}\right)T_R\right)\right]} \tag{6.14}$$

It can be observed from (6.14) that  $t_{Xa}$  is independent of  $C_l$  and  $W_n$ . The independence of  $t_{Xa}$  with  $W_n$  is because  $C_{CX}$  and  $\beta_{M2}$  are both proportional to  $W_n$ .

The proposed model of (6.14) has been verified using HSPICE simulated data for  $t_{Xa}$ . Figure 6.10, shows the validation of  $t_{Xa}$  model with respect to  $T_R$ ,  $C_l$  values and cell size.

#### 6.4.2.2 Proposed Model for $t_{crit}$

In this sub-subsection, we derive the relationship between  $t_{crit}$  and  $T_R$ ,  $C_l$  values for 2-input NAND gate standard cell. Till  $t_{Xa}$ , the transistor  $M_1$  is OFF and node 'OUT' charges through capacitive coupling (through the  $C_{gd}$  of pMOS transistor ( $M_4$ ) in Fig. 6.7). For  $t > t_{xa}$ , the node 'OUT' also discharges through the drain current of  $M_1$  ( $I_{M1}$ ). To find  $I_{M1}$ , we apply KCL at node 'X'. We integrate  $I_{M1}$  from  $t_{Xa}$  to  $t_{crit}$  to account for the overshoot. We explain this approach to derive  $t_{crit}$  in detail in the following paragraph. We model the  $t_{crit}$  for the large values of  $T_R$  (from 15ps to 250ps).

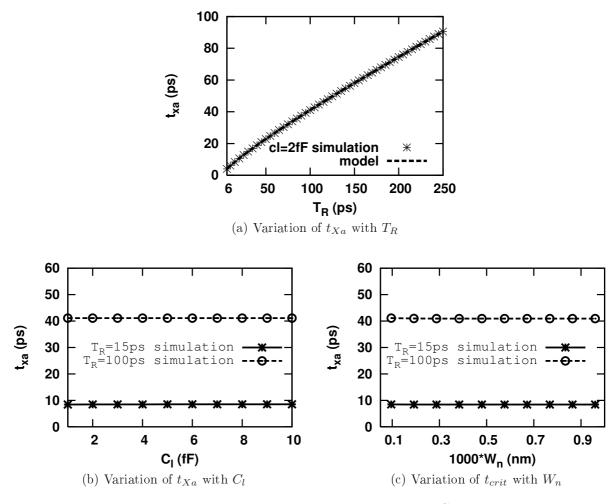


Figure 6.10: Case 2: Variation of  $t_{Xa}$  with  $T_R$ ,  $C_l$  and  $W_n$ .

As the minimum FO1 delay of CMOS inverter and NAND gate is 11ps and 14ps respectively. In general, it is very rare to get the real input signal having transition time equal to or less than the FO1 delay of CMOS inverter. Therefore, we consider the range of  $T_R$  (from 15ps to 250ps) which is very practical in standard cell characterization. Within this range of  $T_R$ ,  $V_{x,crit} \ge V_{dsat}$  and, at  $t = t_{crit}$ , both nMOS transistors operate in velocity saturation region. Here,  $V_{x,crit}$  is the voltage at node 'X' when  $t = t_{crit}$  and  $V_{dsat}$  is the saturation drain source voltage of  $M_2$  transistor. We assume that the value of  $V_{dsat}$  is weakly dependent on the values of  $V_{ds}$ , as in (given in [9]). For our PTM CMOS technology, we extract the value of  $V_{dsat} = 0.28V$  from  $I_d - V_{ds}$  characteristics (as done in [9]).

During overshoot period, NAND gate equivalent circuit consists of coupling capacitance  $(C_{C1})$ , total output capacitance  $(C_{out})$  and a dependent current source  $(I_{M1})$  having a nonzero current from  $t_{Xa}$  to  $t_{crit}$  (as shown in Fig. 6.2b). To obtain the value of  $I_{M1}$ , We apply KCL at node 'X':

$$I_{M2} = I_{C_{CX}} + I_{C'_{Y}} + I_{M1} \tag{6.15}$$

We can write (6.15) as:

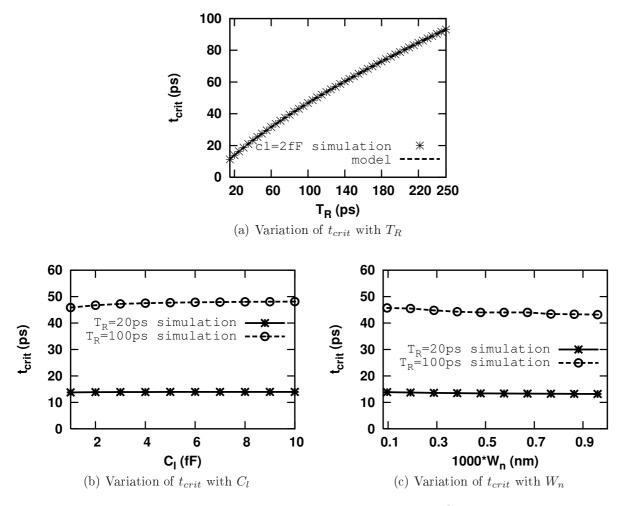


Figure 6.11: Case 2: Variation of  $t_{crit}$  with  $T_R$ ,  $C_l$  and  $W_n$ .

$$\beta_{M2}\left(\frac{V_{dd}}{T_R}t - V_{th}\right) = C_{CX}\frac{dV_{in-B}}{dt} - C'_X\frac{dV_X}{dt} + \beta_{M1}\left(V_{dd} - V_X - V_{th1}\right)$$
(6.16)

At  $t = t_{crit}$ , we can write (6.16) as:

$$\beta_{M2}\left(\frac{V_{dd}}{T_R}t_{crit} - V_{th}\right) = C_{CX}\frac{V_{dd}}{T_R} + C_X'\frac{dV_{Xcrit}}{dt} + \beta_{M1}\left(V_{dd} - V_{Xcrit} - V_{th1}\right)$$
(6.17)

At  $t = t_{Xa}$ , we can write (6.16) as:

$$\beta_{M2} \left( \frac{V_{dd}}{T_R} t_{Xa} - V_{th} \right) = C_{CX} \frac{V_{dd}}{T_R} + C'_X \frac{dV_{Xa}}{dt} + \beta_{M1} \left( V_{dd} - V_{Xa} - V_{th1} \right)$$
(6.18)

Subtracting (6.18) from (6.17) to get the value of  $t_{crit}$ . As  $M_1$  and  $M_2$  transistors are of same size and both are operating in saturation region, therefore  $\beta_{M1} = \beta_{M2}$ . Now, we have the expression of  $t_{crit}$  as:

$$t_{crit} = \left(\frac{V_{Xa} - V_{Xcrit}}{V_{dd}}\right) T_R + t_{Xa} \tag{6.19}$$

In this derivation, we ignore the current  $I_{C'_X}$  (refer to (6.15)), as its value is very small compared to the ON current of  $M_1$ . It can be observed from (6.19) that  $t_{crit}$  is independent of  $C_l$  and  $W_n$ .

The proposed model of (6.19) has been verified using HSPICE simulated data for  $t_{crit}$ . Figure 6.11 shows the validation of  $t_{crit}$  model with respect to  $T_R$ ,  $C_l$  values and cell size.

### 6.5 Summary

In this chapter, we proposed  $t_{crit}$  model for CMOS inverter and 2-input NAND gate. We then verified the relationships of proposed model with  $T_R$ ,  $C_l$  and cell size (in terms of  $W_n$ ). The model equation as well as simulation results shows that  $t_{crit}$  is independent of  $C_l$  and  $W_n$ . The model covers a wide range of  $T_R$  values (from 15ps to 150ps). The proposed models are in good agreement with HSPICE simulation with maximum error of 2.5%.

## Chapter 7

## **Conclusion and Future Scope**

In this chapter, a summary of the research work carried along with the conclusions. The future scope in this area of study is also pointed out.

The problem addressed in this thesis is briefly defined here. Standard cell library characterization in nanometer range CMOS technologies, consumes huge time because of numerous cells of different sizes, layout dependent effects, temperature and supply voltage variation and frequent device model updates. To address this issue, delay/timing models with clearly defined regions of validity in transition time  $(T_R)$ , load capacitance  $(C_l)$ space and which also consider cell size, layout parameters, temperature and supply voltage variation are needed.

### 7.1 Conclusions

The major contributions and conclusions from this work are summarized below.

In the first stage of the work, we proposed an analytical model for the Timing values of Threshold Crossing Point  $(t_{TCP}s)$  of output voltage transition as a function of  $T_R$  and  $C_l$  for a standard cell CMOS inverter. Subsequently, the region of validity of the model in  $T_R$ ,  $C_l$  space used in characterization Lookup Tables (LUTs) is derived. We developed the relationships of the model coefficients with the cell size. Further, the impact of technology scaling on these model coefficients is investigated. The results show that the proposed model is in good agreement with HSPICE simulations with a maximum error of 2.5%. Later, we use this model to reduce the number of HSPICE simulations in ECSM characterization by nearly half. We then obtained the relationships of the model coefficients with process induced mechanical stress as a function of Number of Fingers (NF), temperature and power supply voltage ( $V_{dd}$ ) variability. We later expand this model for different values of NF and include the impact of temperature and supply voltage variations, to reduce the number of SPICE simulations. We observed that the model helps to reduce the number of HSPICE simulations by about 50% in ECSM characterization of standard cell CMOS inverter.

In the next phase of the work, we proposed the  $t_{TCP}$  model for 2-input NAND gate standard cell, for Case 1 and 2, which we now discuss. First, we developed the model for the case (Case 1) when the upper nMOS transistor in the series stack of the NAND gate switches. After this, we developed the model for the case (Case 2) when the lower nMOS transistor in the series stack of the NAND gate switches. In this work, we considered the impact of the voltage transition at the intermediate node in the series stack of nMOS transistors in the NAND gate. For this, we considered the input to intermediate node capacitive coupling effect, parasitic capacitances at the intermediate node and the regions of operation of the two nMOS devices placed in series stack. The  $t_{TCP}$  models are derived as a function of  $T_R$  and  $C_l$ . We also derived the region of validity of these models in  $C_l$ ,  $T_R$  space. Later, we used these models in reducing the number of HSPICE simulations in ECSM characterization of 2-input NAND gate standard cell by  $\approx 67\%$ . We then developed the relationship of the model coefficients with the cell size, power supply voltage  $(V_{dd})$ and temperature. While considering layout dependent effects due to mechanical stress, we developed the relationship of the model coefficients with stress as a function of NF. We later used these relationships to reduce the number of HSPICE simulations by about 80.18% and 86% in ECSM characterization of a 2-input NAND gate standard cell having a different value of NF for Case 1 and 2, respectively. Further, we included the effect of temperature variation in our  $t_{TCP}$  models to reduce the number of HSPICE simulations by  $\simeq 79.88\%$  for Case 1 and 85% for Case 2. We also included the effect of supply voltage variation in our  $t_{TCP}$  models to reduce the number of HSPICE simulations by  $\simeq 79.88\%$ for Case 1 and 86% for Case 2.

Further, we developed an analytical model to estimate overshoot time considering the influence of  $T_R$ ,  $C_l$  and cell size, for CMOS inverter and NAND gate standard cells. In nanometer range technologies, the parasitic capacitances would increase thereby increasing the importance on the overshoot time period. However, in 32nm CMOS technology node we considered, the overshoot time period is important only for the TCP coming immediately after the overshoot. We separately model the overshoot time for switching of each of the inputs of a 2-input NAND gate standard cell. In this regard, we first model the voltage transition at this node in our work, which we later use to derive overshoot time period for the lower transistor's switching case. We observed that the overshoot timing model of a CMOS inverter remains valid for the case when the upper nMOS device in the series stack is ON and only adds a resistance to the source of the upper nMOS device. We observed that the proposed models are in good agreement with HSPICE simulations with a maximum error of 2.5%.

Hence, we conclude that the standard cell characterization effort can be reduced significantly (nearly 50% for CMOS inverter and 67% for 2-input NAND gate) using our models while maintaining the accuracy close to HSPICE. The validation of these model's coefficients with the cell size, process parameters,  $V_{dd}$  and temperature variations, minimizes the re-characterization effort significantly in standard cell libraries.

### 7.2 Scope for Future Research

In this section, we concisely discuss some future/prospective directions for further research in the same area:

- 1. The work can be generalized by developing standard cell library and hence, timing models for other cells like 2-stage buffer, AND and OR gate can be derived. To reduce the re-characterization effort in standard cell library, the relationships of model coefficients with the cell size, process parameters,  $V_{dd}$  and temperature variations can be derived.
- 2. Timing model for inverter followed by transmission gate can be derived on the lines of our NAND gate timing model.
- 3. For accurate timing model, an overshoot timing model can be used in ECSM characterization of standard cell libraries. This will ensure that even the  $\simeq 5\%$  error (for NAND gate) seen in  $t_{TCP}$  estimation for the TCP closest to the overshoot can also be reduced significantly.
- 4. This work can be used in improving the efficiency of standard cell characterization EDA tools significantly.

## LIST OF PUBLICATIONS

Based upon the research work carried out, following papers are published or communicated for publication :

- 1. B. Kaur, N. Alam, S. K. Manhas, and B. Anand, "Efficient ECSM Characterization Considering Voltage, Temperature and Mechanical Stress Variability", *IEEE Transactions on Circuits and Systems-I*, (in Press).
- B. Kaur, S. Vundavalli, S. K. Manhas, S. Dasgupta, and B. Anand, "An Accurate Current Source Model for CMOS Based Combinational Logic Cell", in 13th ISQED'12, pp. 561-565, 2012.
- B. Kaur, S. Miryala, S. K. Manhas, and B. Anand, "An Efficient Method for ECSM Characterization of CMOS Inverter in Nanometer Range Technologies", in 14th ISQED'13, pp. 665-669, 2013.
- S. Miryala, B. Kaur, B. Anand, and S. K. Manhas, "Efficient Nanoscale VLSI Standard Cell Library Characterization Using a Novel Delay Model", in 12th ISQED'11, pp. 458-463, 2011.
- B. Kaur, A. Sharma, N. Alam, S. K. Manhas, and B. Anand, "A Variation Aware Timing Model for a 2-Input NAND Gate and Its Use in Sub-65nm CMOS Standard Cell Characterization-Part I", *IEEE Transactions on Circuits and Systems-I*, (Communicated).
- B. Kaur, A. Sharma, N. Alam, S. K. Manhas, and B. Anand, "A Variation Aware Timing Model for a 2-Input NAND Gate and Its Use in Sub-65nm CMOS Standard Cell Characterization-Part II", *IEEE Transactions on Circuits and Systems-I*, (Communicated).

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